

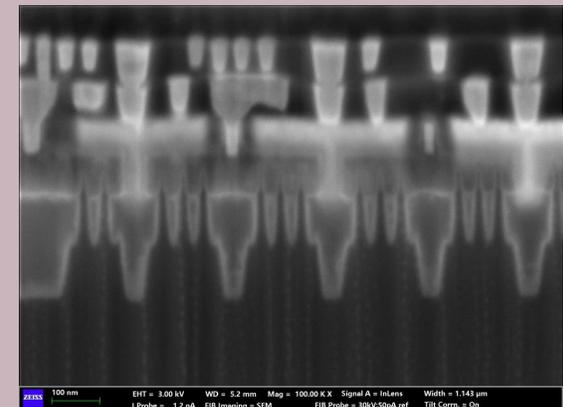
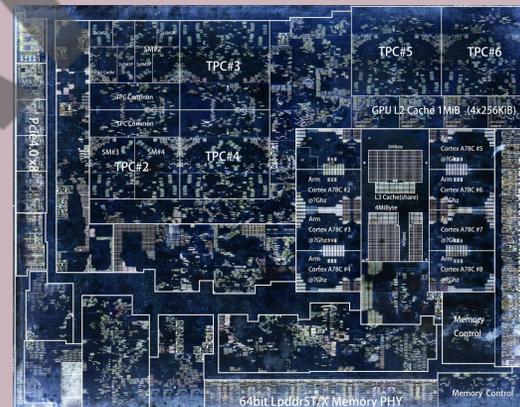
Nintendo Switch 2

Chip and Process analyze

V1.1



@Kurnal



Version	Date	Updates	Author
V0	2025/04/23	Working	Kurnal
VI	2025/05/07 22:51	Finish ?	Kurnal
VI.1	2025/05/08 20:53	修改了语法（感谢雪球老师！）	Kurnal/雪球
B站工坊			

This report is not for commercial use



This Report is made From @Kurnal
Copyright @Kurnal

BiliBili: @Kurnal

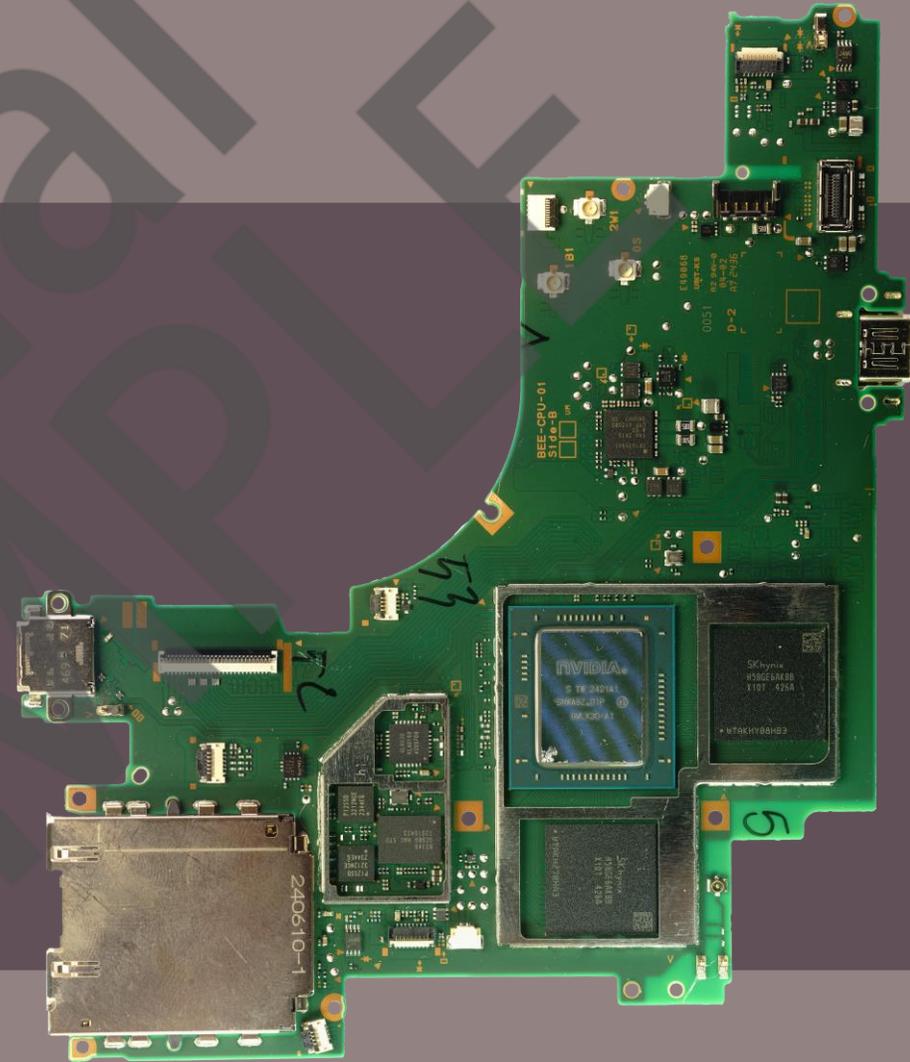
X: @Kurnalsalts

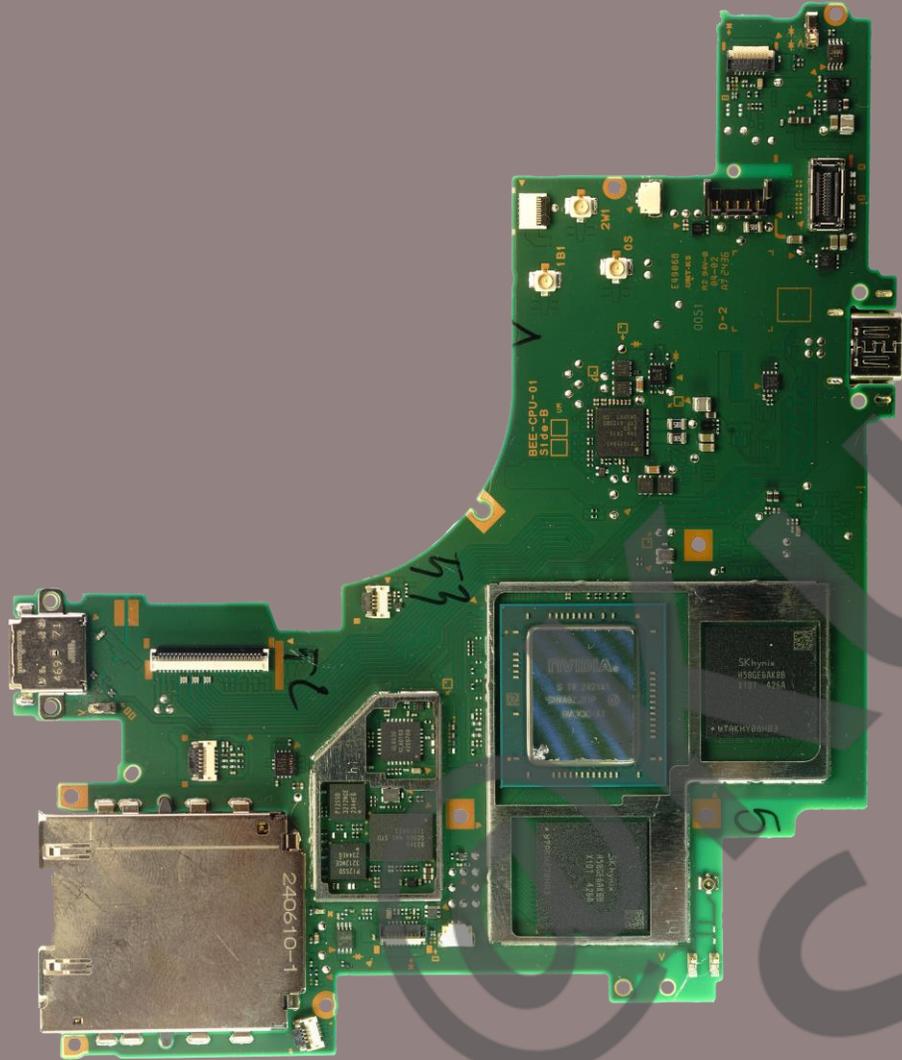
WeChat: KurnalWeChat

This report is not for commercial use

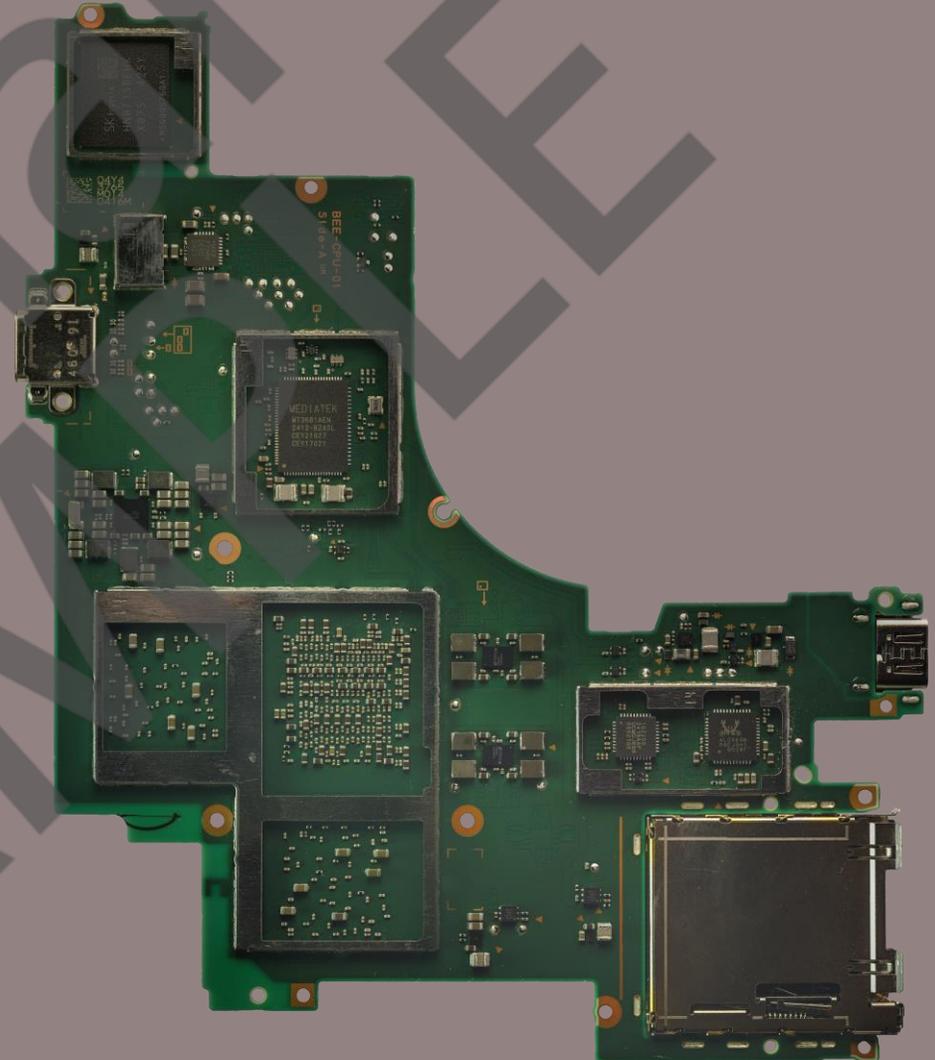
Mother board

Component analyze

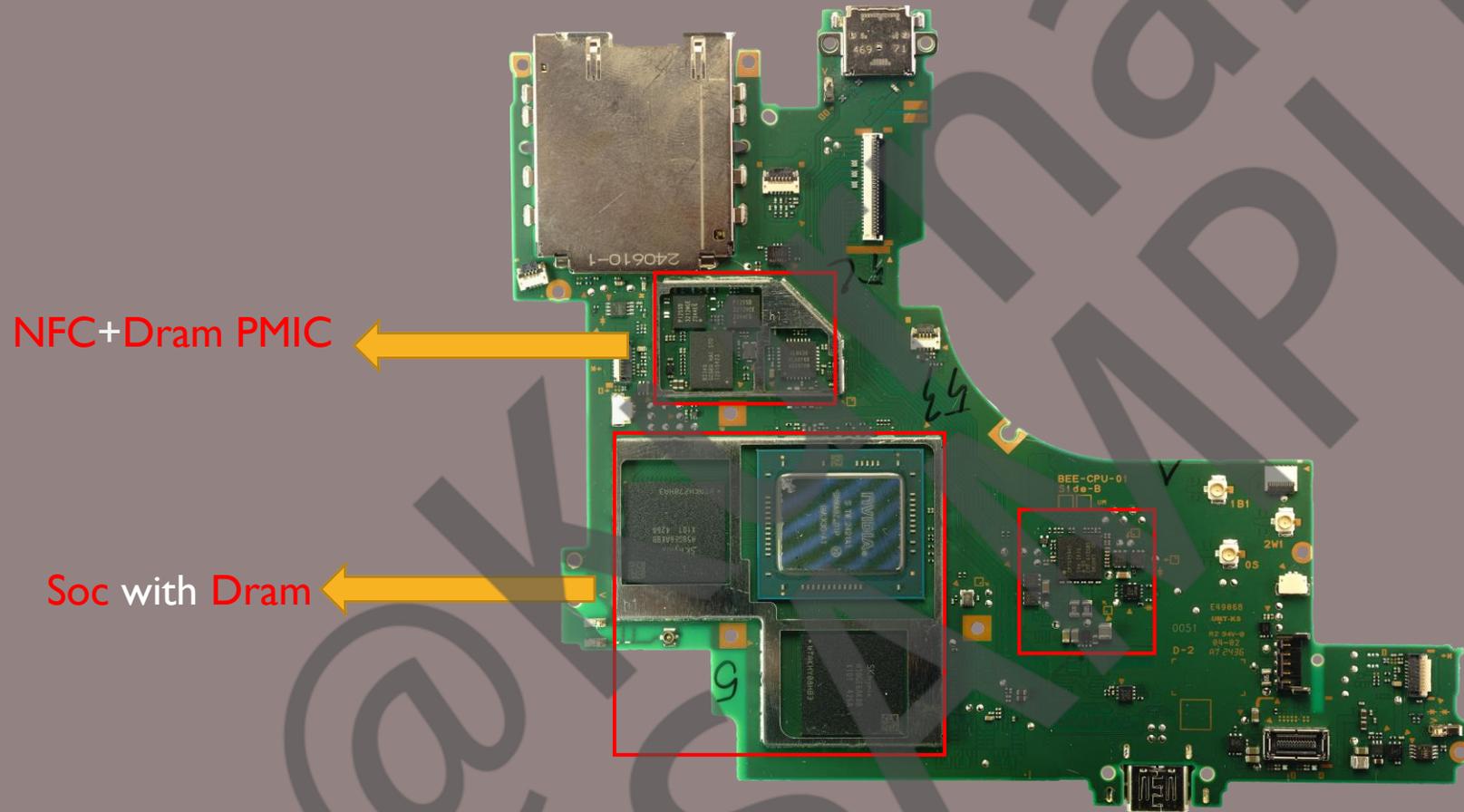




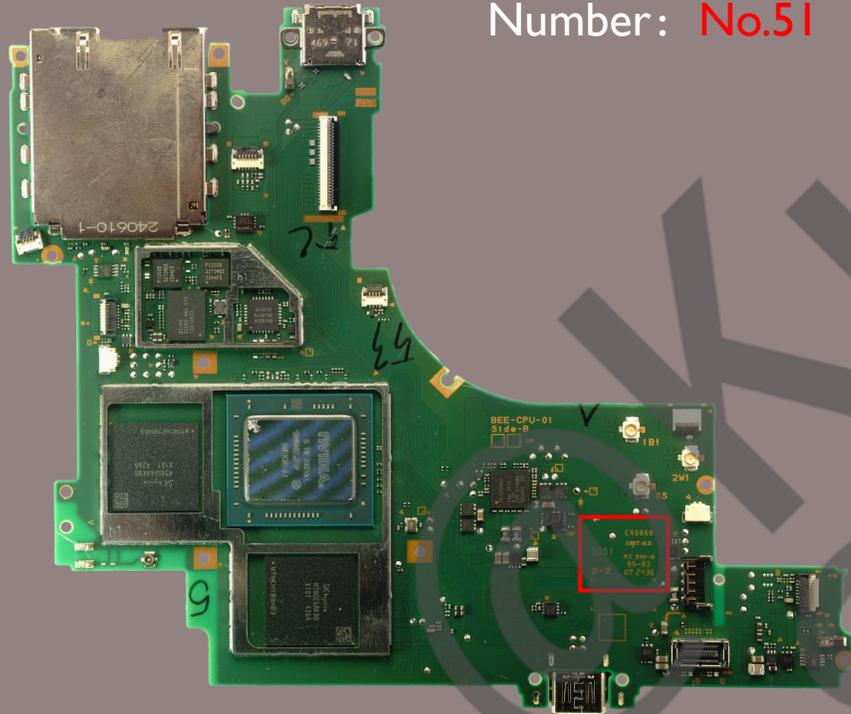
PCB frontside photo



PCB backside photo



PCB frontside photo



PCB frontside photo

Number: No.51



PCB made From **Unimicron**
欣兴电子

PCB made on **2024-Week36**

PCB-Backside



UFS/ROM



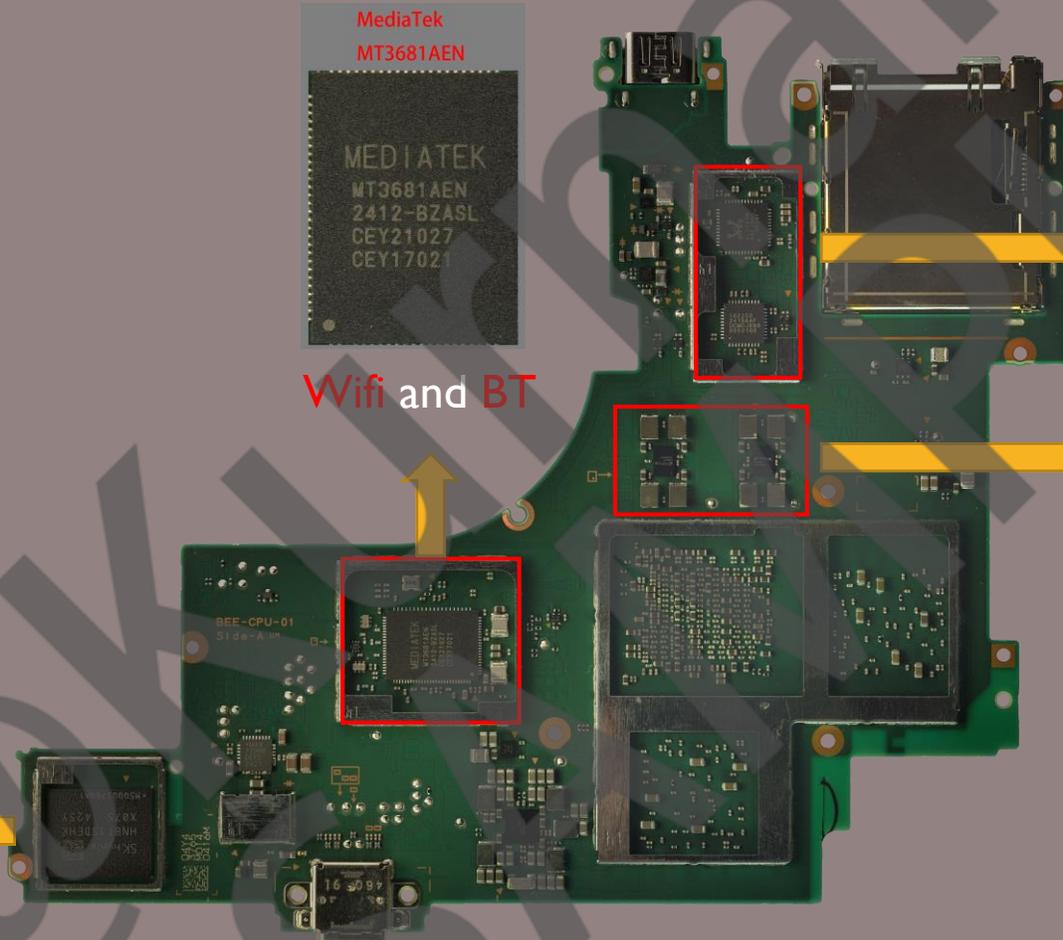
Wifi and BT



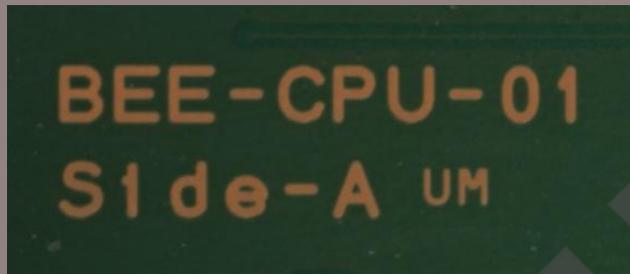
Audio Codec



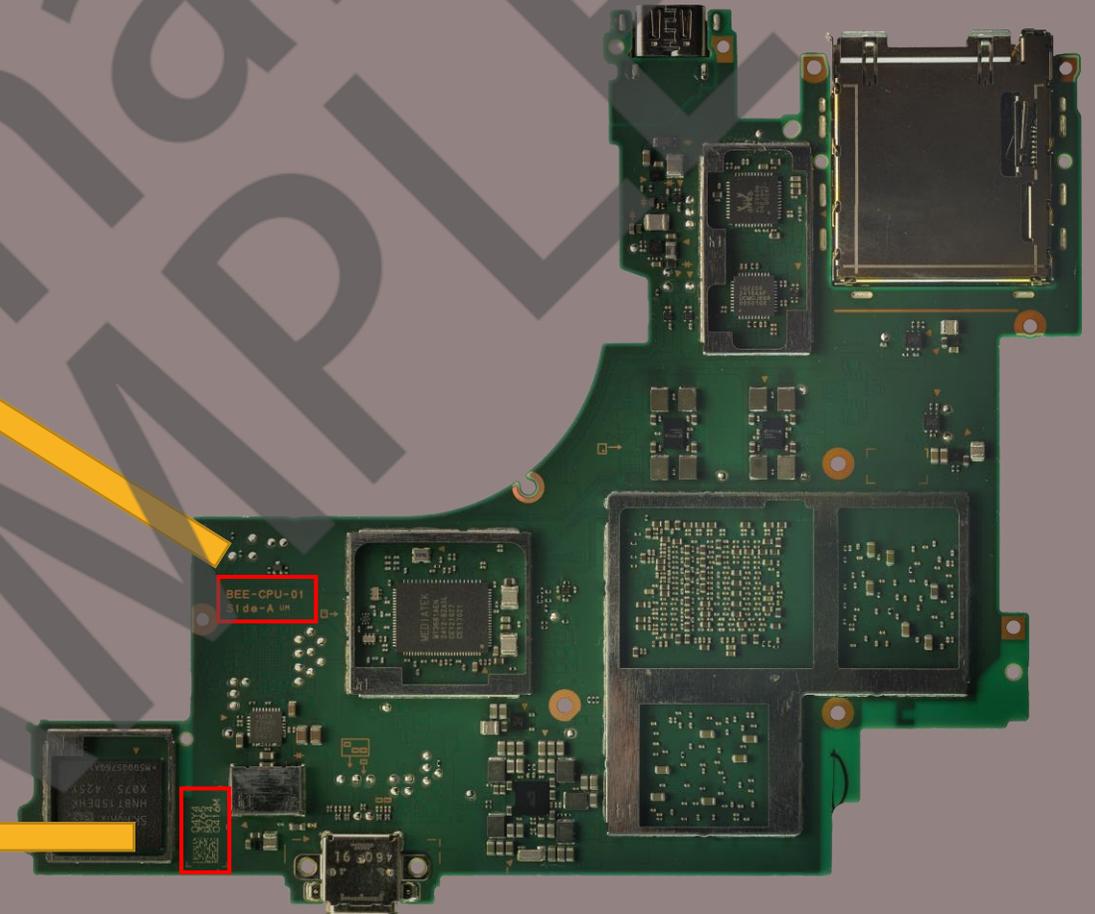
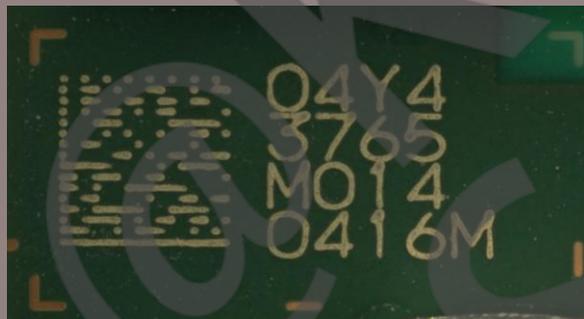
PMIC



PCB backside photo



Running code



PCB backside photo



Dram From Sk hynix



ROM From Sk hynix



Dram From Sk hynix

<input type="checkbox"/> H58GE6AK8PX107N	6GB	1.8V / 1.05V / 0.5V	8533Mbps	441Ball	MP
<input type="checkbox"/> H58GE6AK8QX107N	6GB	1.8V / 1.05V / 0.5V	8533Mbps	441Ball	MP
<input type="checkbox"/> H58GE6AK8VX107N	6GB	1.8V / 1.05V / 0.5V	8533Mbps	441Ball	MP

H58GE6AK8B X107

LPDDR5T/5X

8533MT/s 4266MHz/s

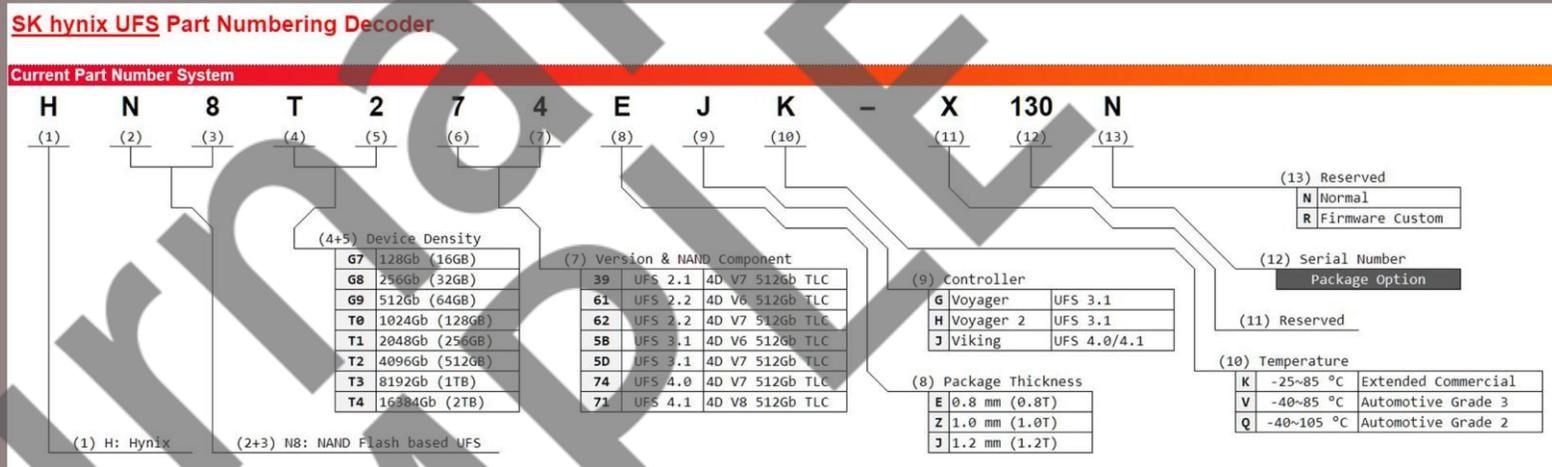
Pkg Density: 6GB

DIE: 12Gb A-die

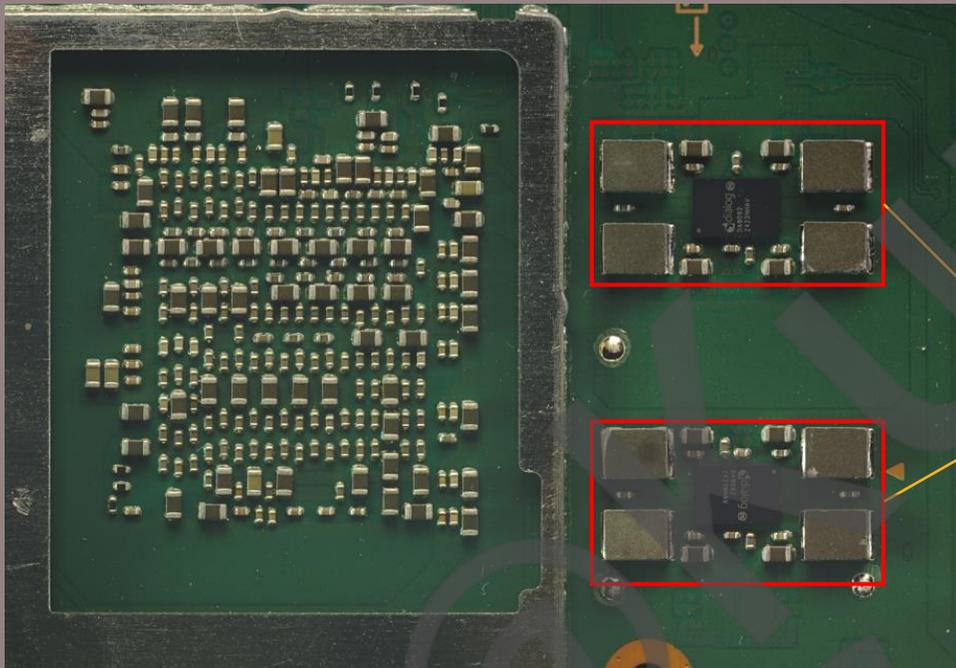
PKG: BGA-441



ROM From Sk Hynix



Hynix **UFS 3.1**
2048Gb/256GB
4D v7 512Gb TLC
 Package Thickness : **0.8mm**
 Controller: **Voyager2**
Extended commercial



Soc PMIC



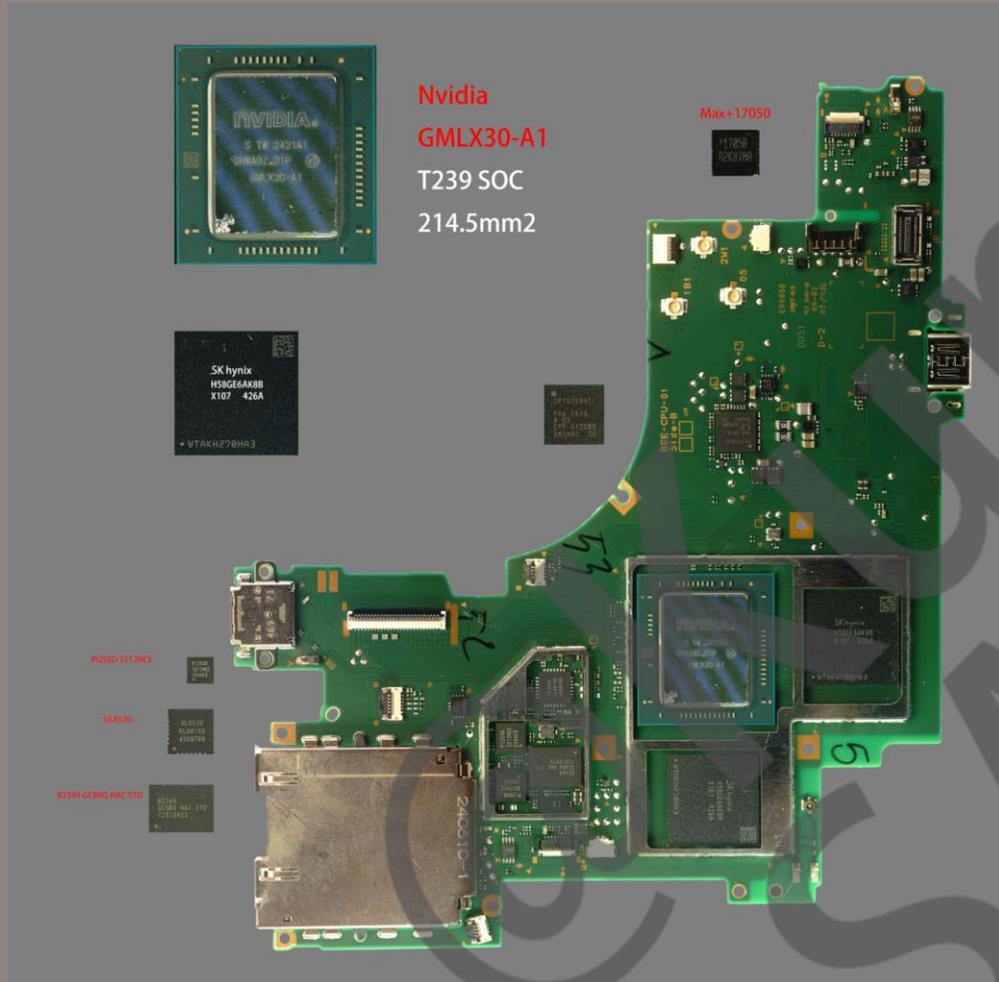
Dialog
DA9092

Key Features

- Input voltage 2.8 V to 5.5 V
- Four buck converters with dynamic voltage control:
 - Buck1: 0.3 V to 1.57 V, 2.5 A
 - Buck2: 0.3 V to 1.57 V, 2.5 A (can be used in dual-phase configuration with Buck1)
 - Buck3: 0.8 V to 3.34 V, 2 A
 - Buck4: 0.53 V to 1.8 V, 1.5 A (can be used as DDR VTT supply)
- 3 MHz switching frequency (enables low profile inductors)
- Four LDO regulators:
 - LDO1: 0.9 V to 3.6 V, 100 mA
 - LDO2, LDO3, LDO4: 0.9 V to 3.6 V, 300 mA
- Programmable power mode sequencer
- System supply and junction temperature monitoring
- Watchdog timer
- Five GPIOs
- Coin cell/super-capacitor charger
- Ultra-low power RTC with alarm
- 32 kHz oscillator with external crystal
- -40 °C to +125 °C junction temperature range
- 40-pin QFN 6 mm × 6 mm package, 0.5 mm pitch (exposed paddle)
- Automotive AEC-Q100 Grade 2 version available

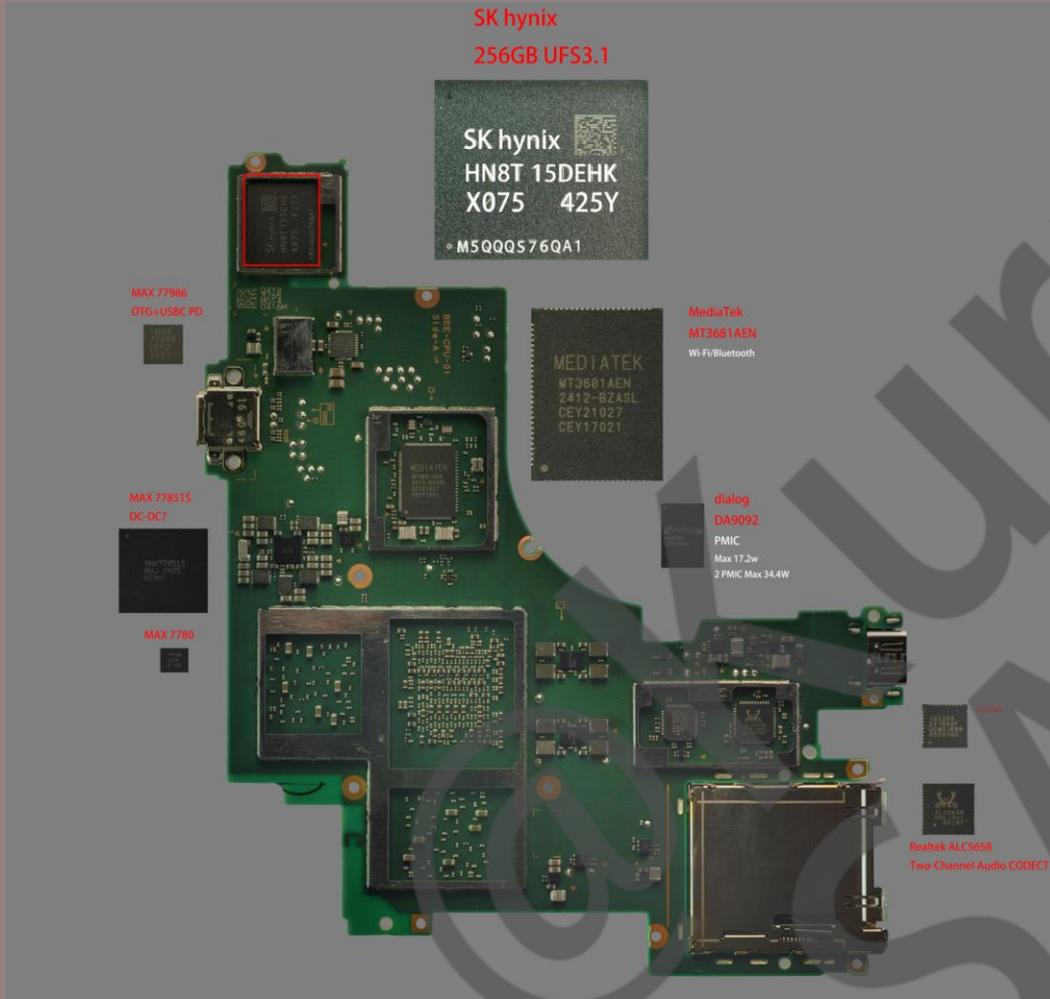
One PMIC Maximum **17.2w**
 Total Power Maximum **34.4w**

PCB total chip



Top side chip	
T239 SOC	Nvidia GMLX30-A1
LPDDR	SK Hynix H58GE6AK8B X107 426A
?	PI2SSD 3212NCE
?	GL852G
?	B2349 GECBRG HAC STD
?	CP10359AT
Battery?	Max+17050

PCB total chip



Back side chip	
UFS3.1 256GB	SK Hynix HN8T 15DEHK X075 425Y
WIFI/BT	MediaTek MT3681AEN
PMIC	Dialog DA9092
Audio	Realtek ALC5658
?	IG2200
USB DC-DC?	MAX 77851S
	MAX7780
OTG/USB PD	MAX 77986

Switch2 soc analyze

Package Analysis

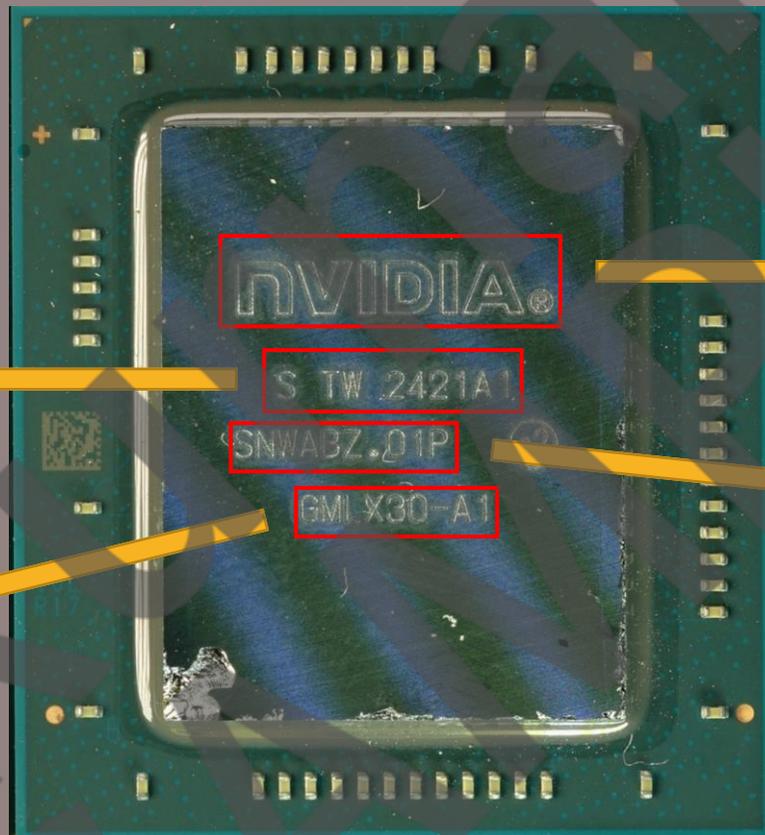




GMLX30 topside photo



GMLX30 bottom side photo



The chip is from **Nvidia**

S: Packaged From ASE Group
TW: Packaged in **Taiwan**
2421: Made on **2024-Week 21**

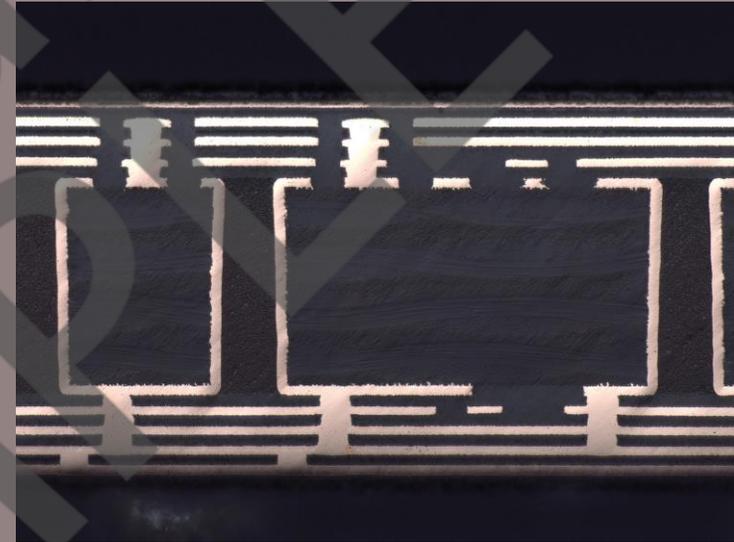
Traceability Code

Code named **GMLX30-A1**

GMLX30 topside photo



GMLX30 topside photo

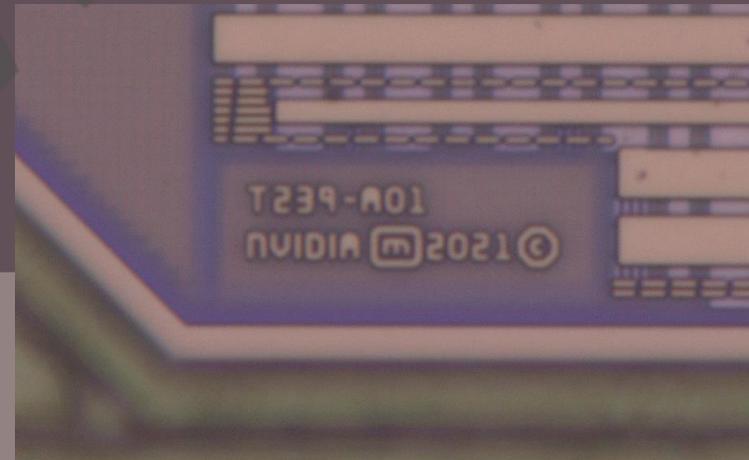
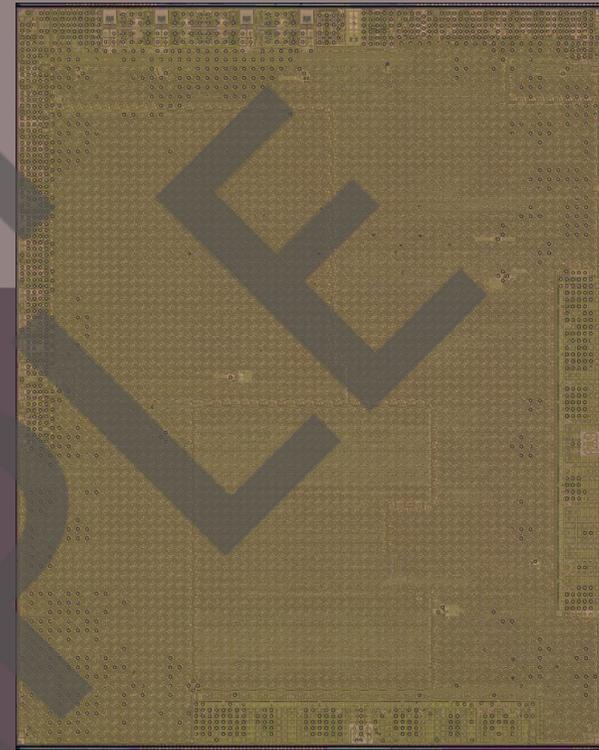


Interposer PCB layers: 10 Layers

The GMLX30 SOC used package named Filp-Chip Fan Out Package (FCFOP/FCBGA)

Switch2 soc analyze

Die-AnalySIS





GMLX30 topside photo

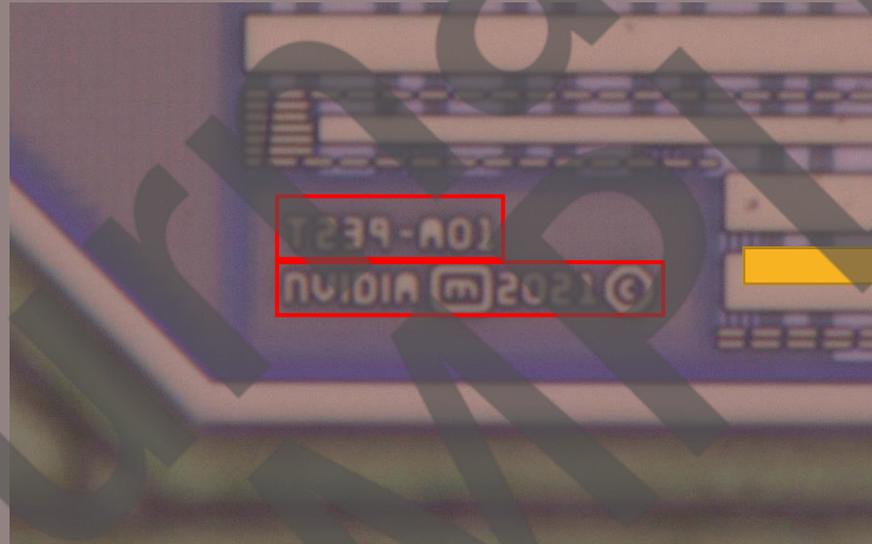
Decapped



GMLX30 metal layer Views



GMLX30 metal Views



Diemark

Chip name: T239-A01
Tap out : Nvidia M 2021 C

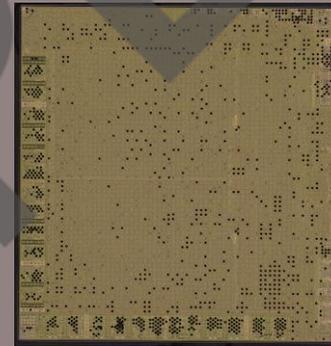
GDS Freeze in 2021?



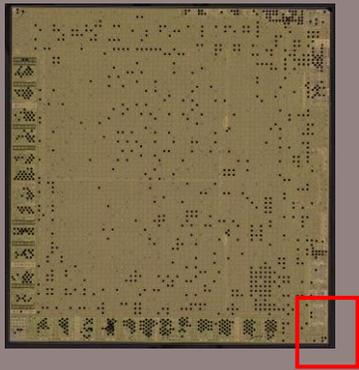
GA107 topside photo

This is a similar chip to
Nvidia GA107
(RTX 3050)

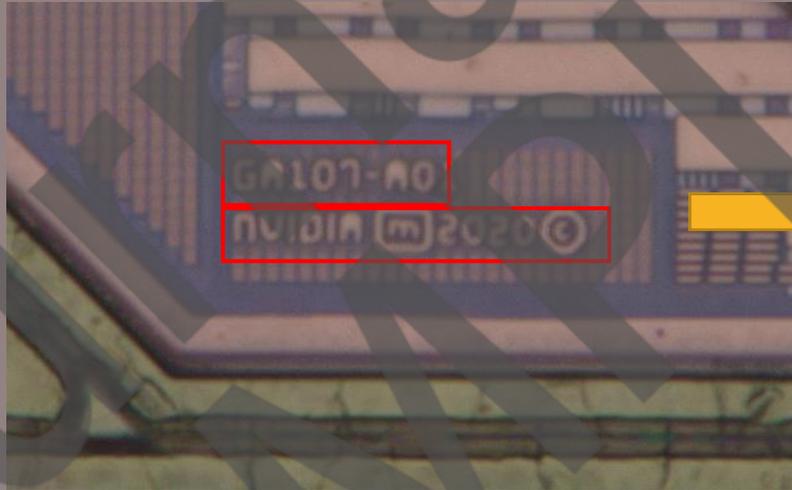
Decapped



GA107 metal layer Views



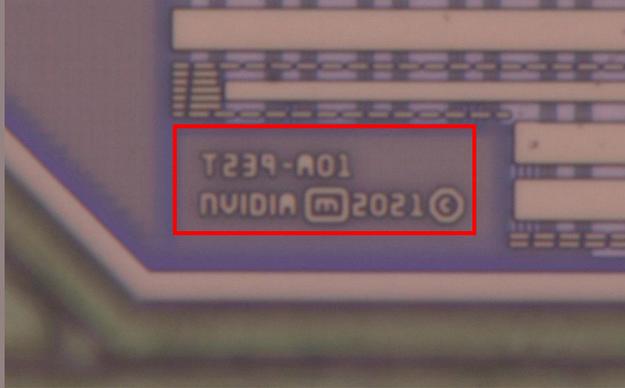
GA107 metalViews



Diemark

Chip name: **GA107-A0**
Tap out : **Nvidia M 2020 C**

GDS Freeze in **2020?**



Switch2 soc Diemark

Chip code: **T239-A01**
Freeze date : **Nvidia M 2021 C**



In **Nintendo Switch2**
Release date: **2025/6/05**

4years later



GA107 GPU Diemark

Chip code: **GA107-A01**
Freeze date : **Nvidia M 2020 C**



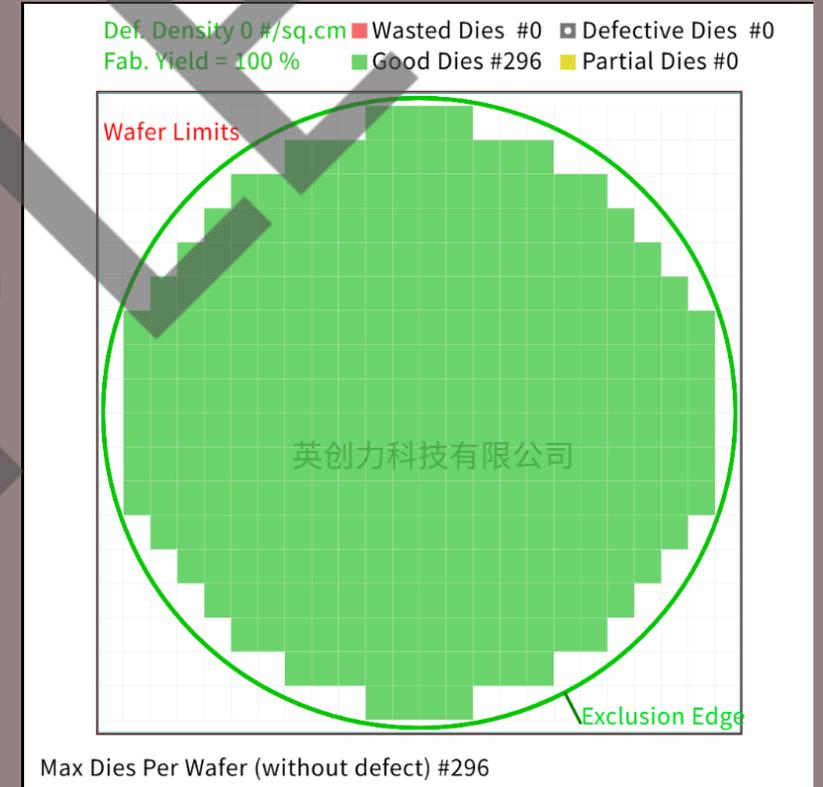
In **Nvidia A2 GPU**
Release date: **2021/11/10**

1years later



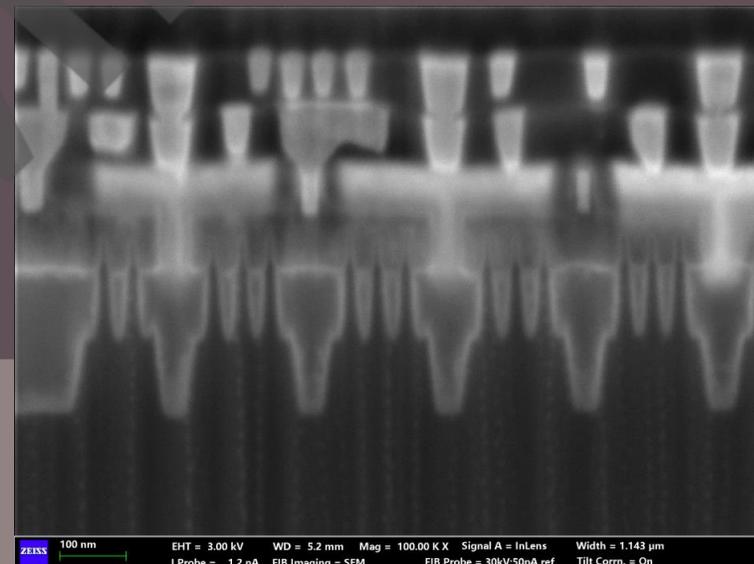
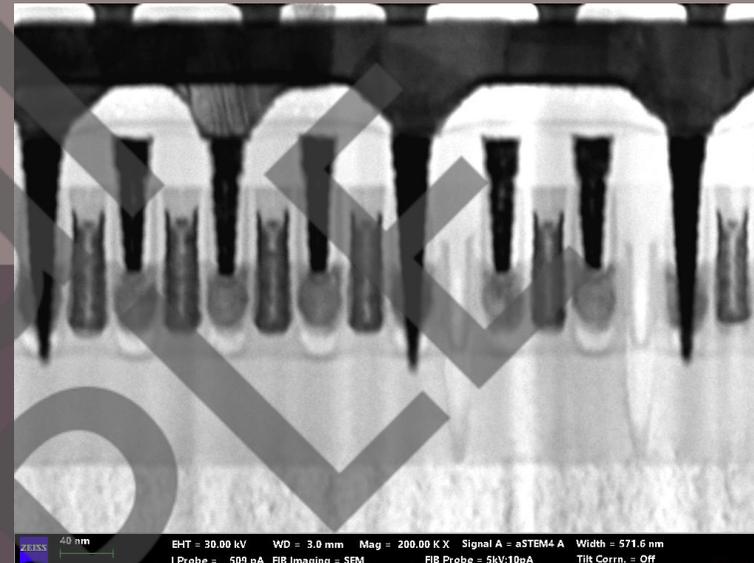
Diesize: **207.35mm²**
(12.76mm x 16.25mm)

DPW Nb: **296**



Switch2 soc analyze

Process analysis



How to know the Process for Switch2 T239?

We need to do **Process analyze**

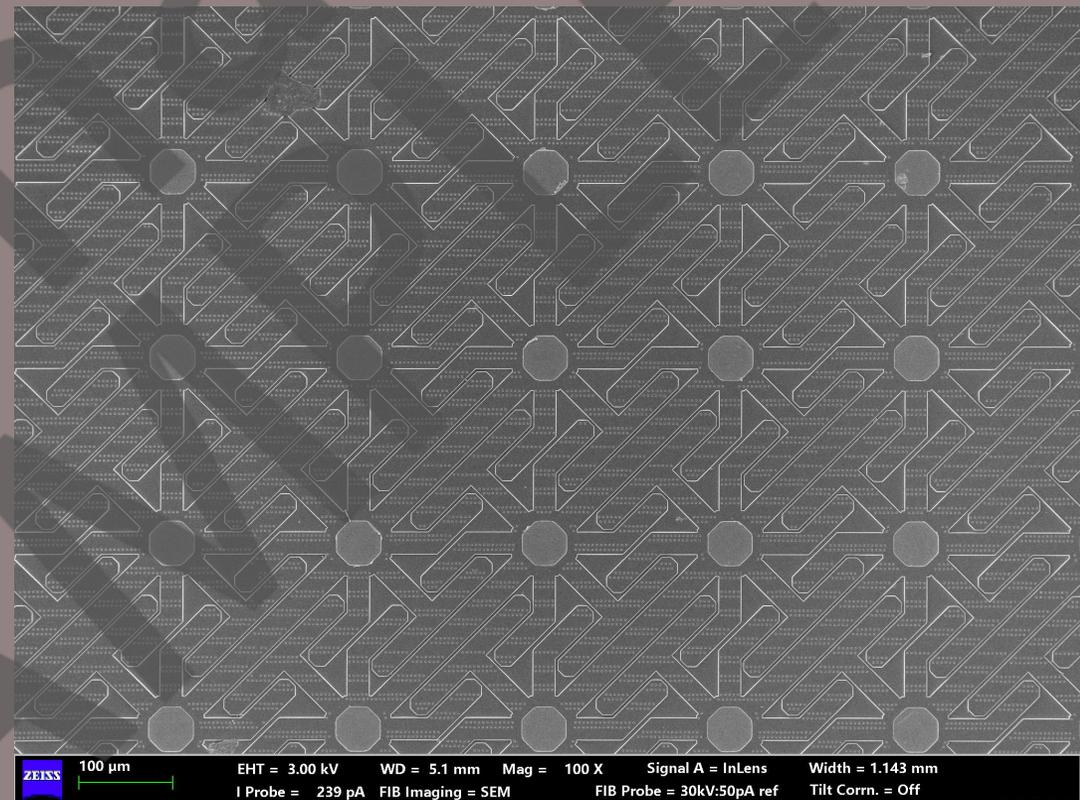
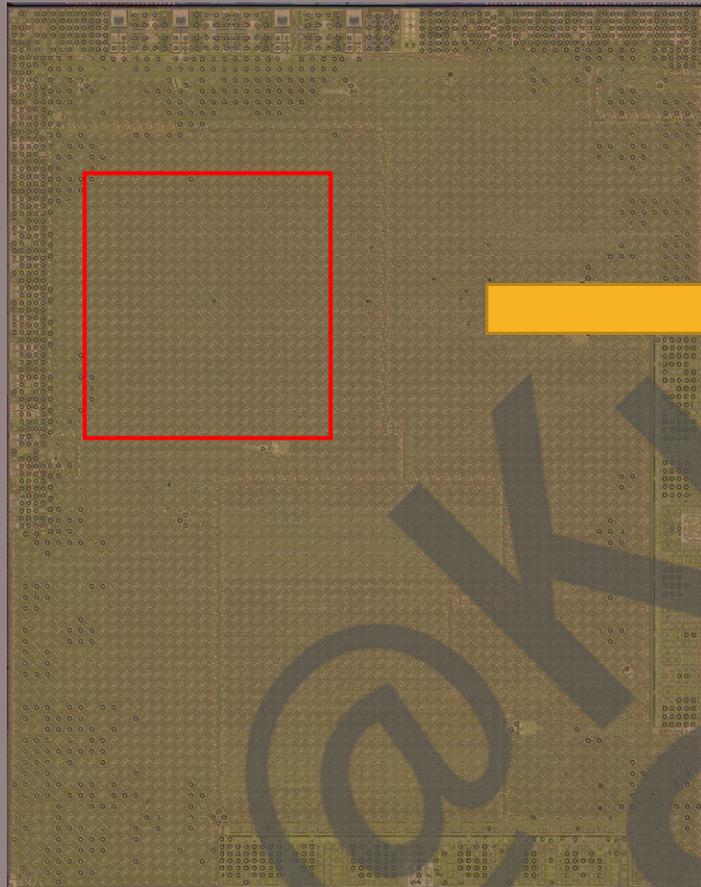
Samsung ?nm: NDS Nvidia T239

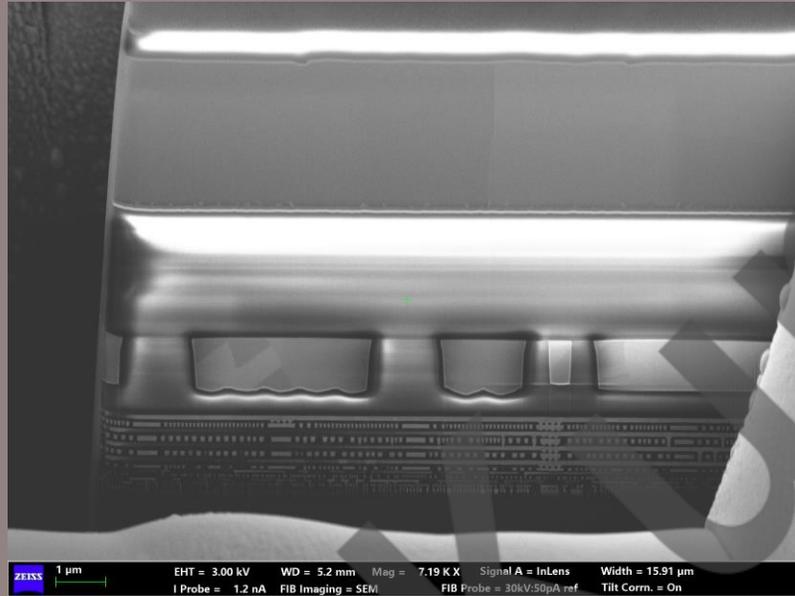
Samsung 8nm: Nvidia GA107

Samsung 5nm: Qualcomm SM8350(Snapdragon 888) **(making)**

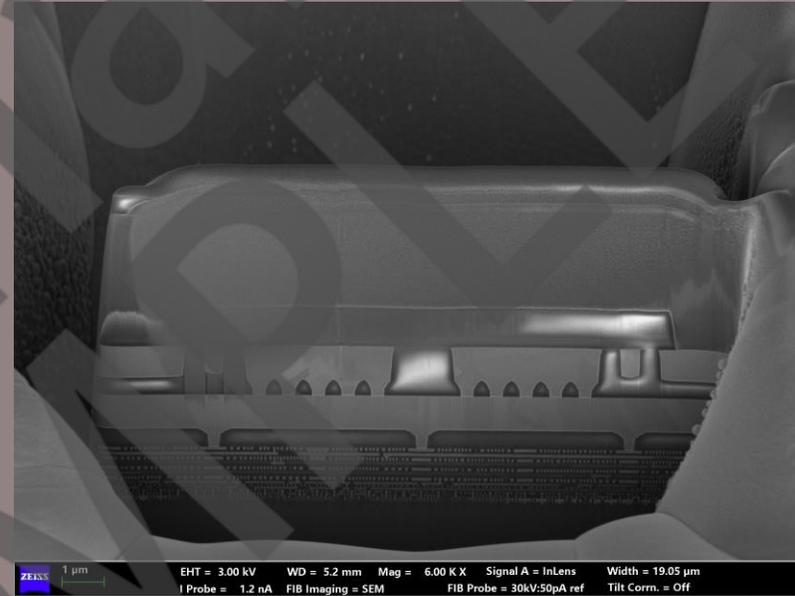
Switch2 soc analyze

Process analyze-**Nvidia T239**

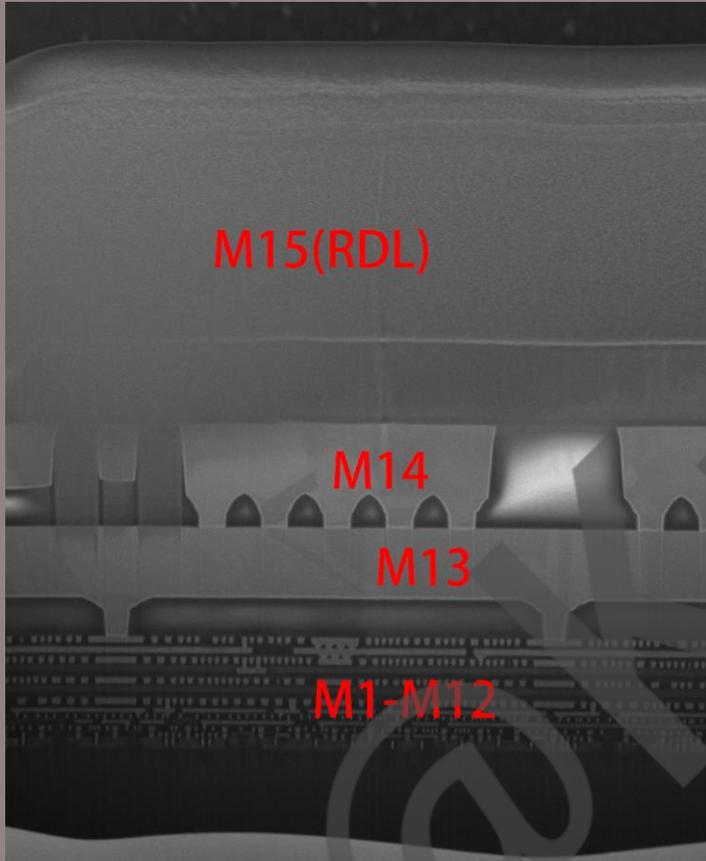




Data from (T239 1-04)
X-Cut(1)



Data from(T239 2-02)
Y-Cut(2)

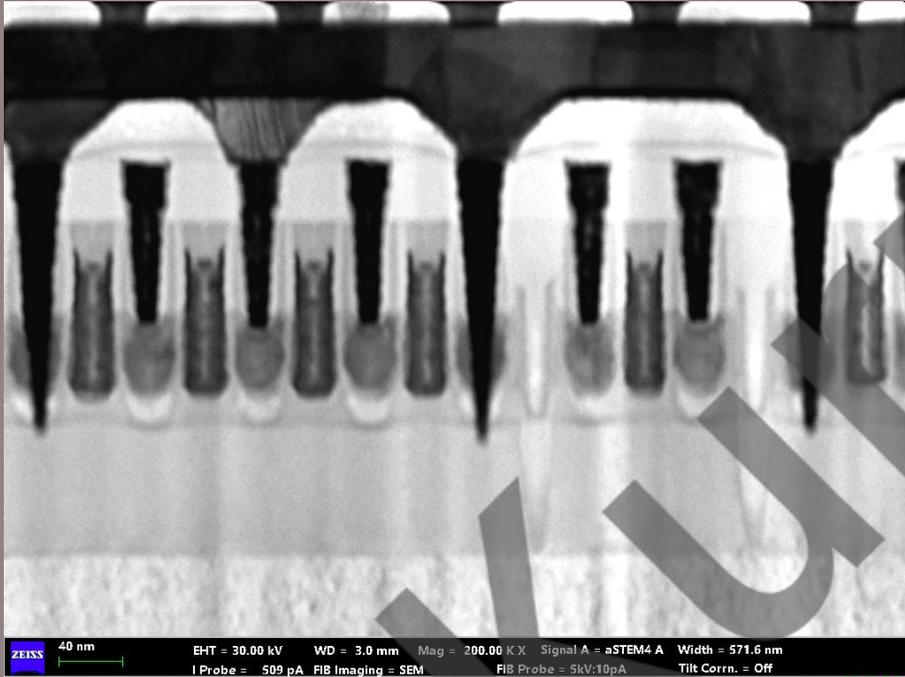


Data from(T239 2-02)



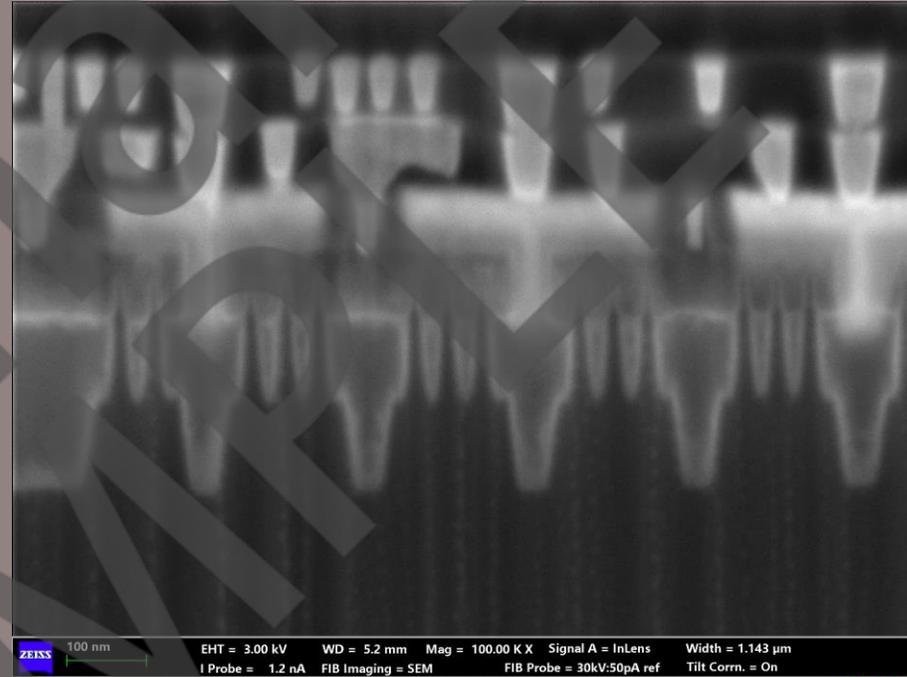
Data from(T239 2-03)

In the Nvidia T239
Total have **IP I5Metal** (I4Metal+IRDL)



Data from(T239 1-16)

X-Cut(1) Gate cut



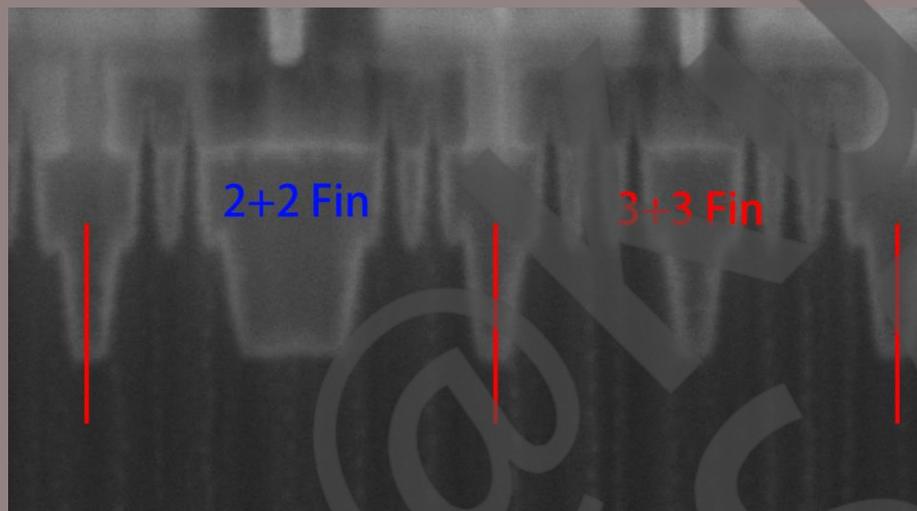
Data from(T239 2-07)

Y-Cut(2) Fin cut

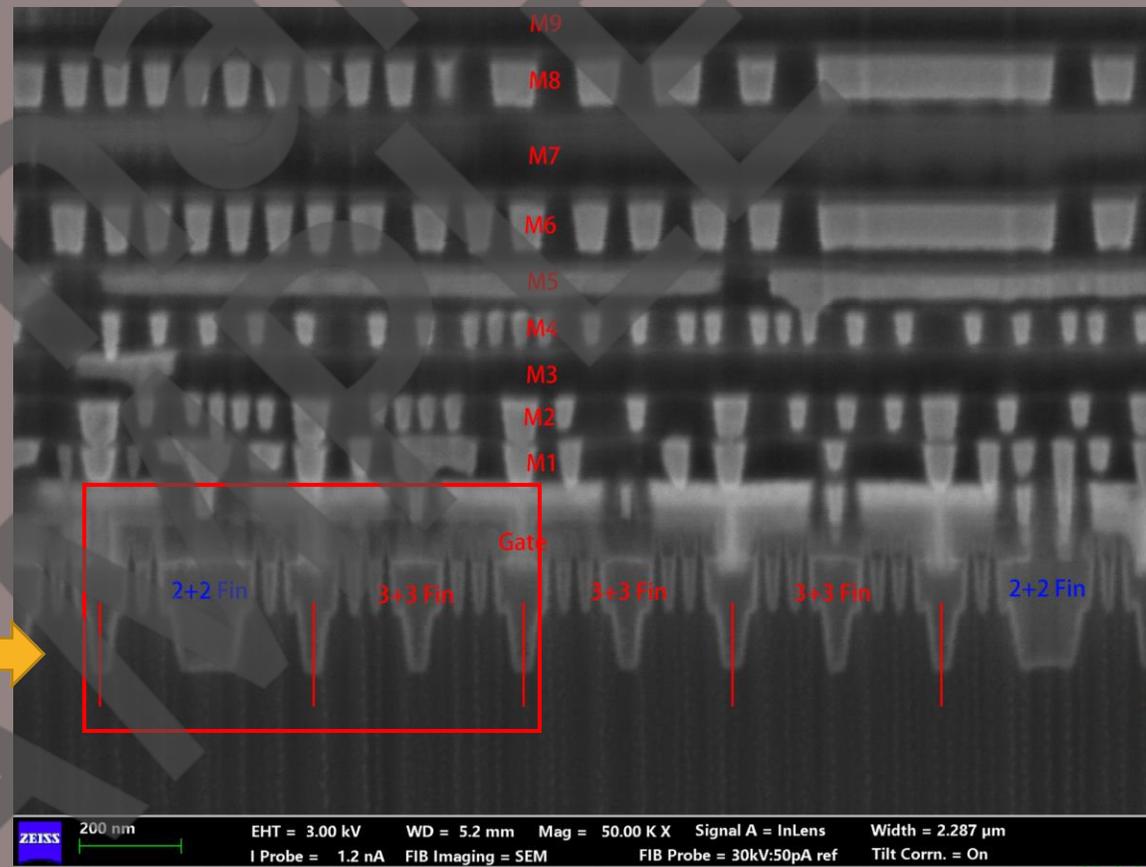
Analyze **Fincut** First



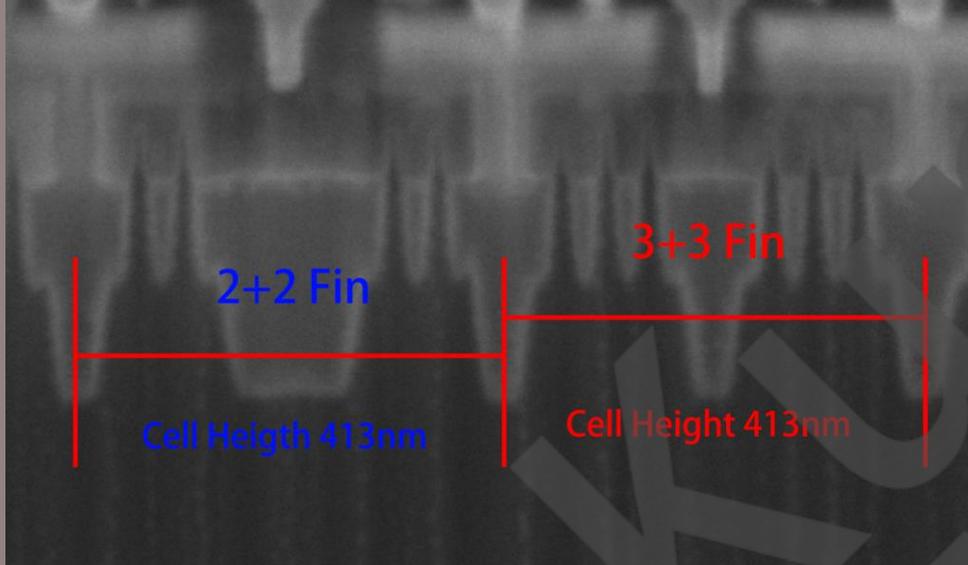
In the T239 GPU area
There are 2 type of Fin number
2+2 Fin and **3+3 Fin**



Data From (T239 2-06)



Data From (T239 2-06)

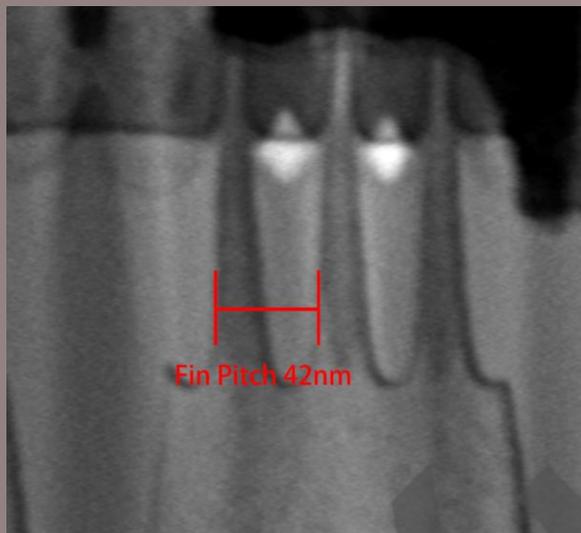


Data From (T239 2-06)

In the Nvidia Switch2 T239

Both 3+3 and 2+2 cells share the same cell height

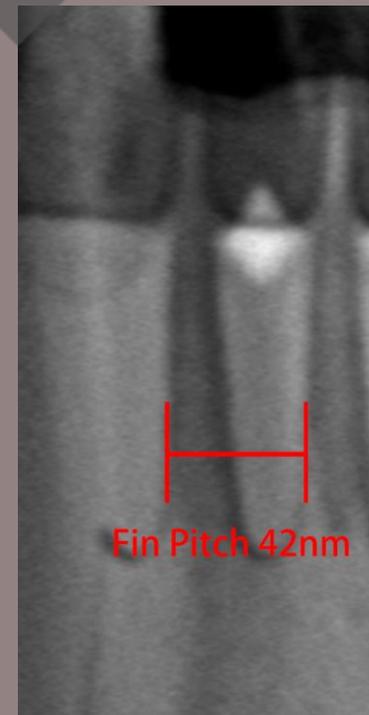
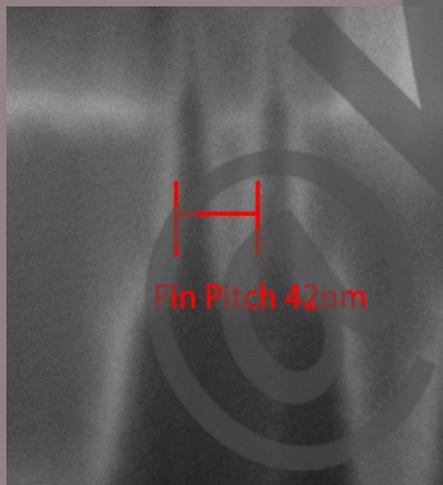
3+3 Fin



In the Nvidia T239

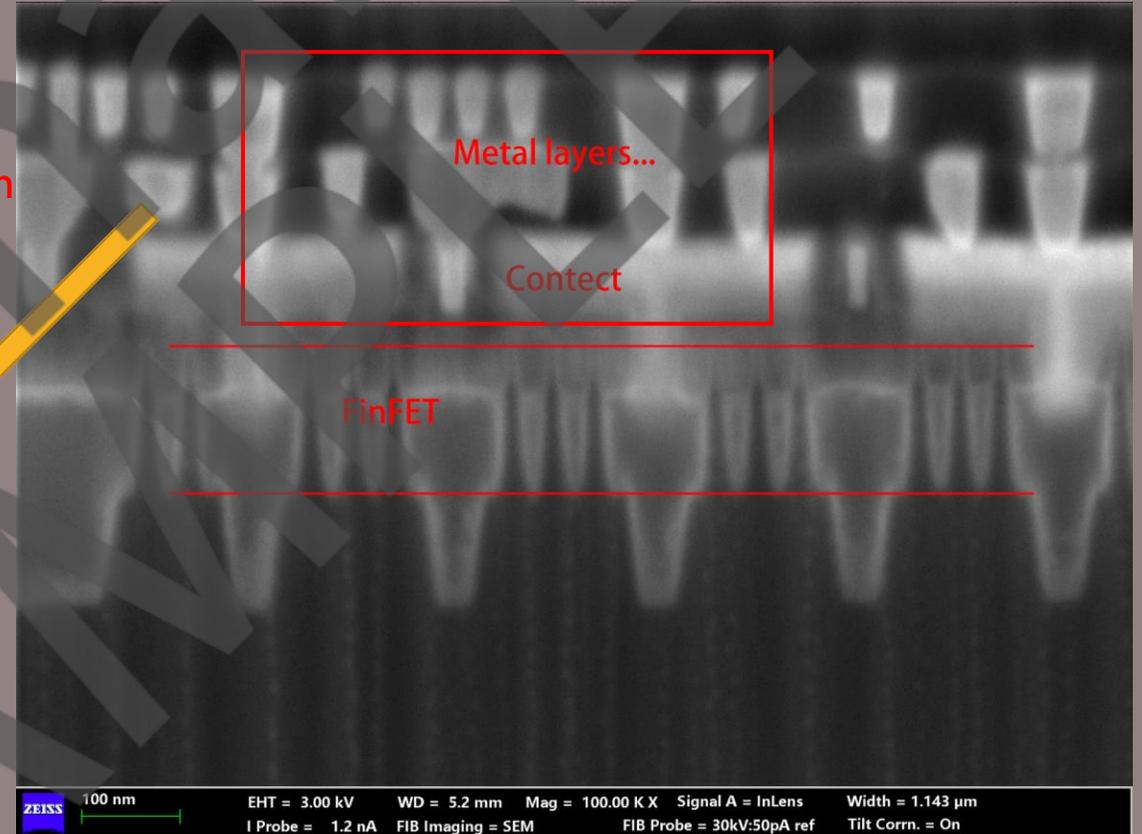
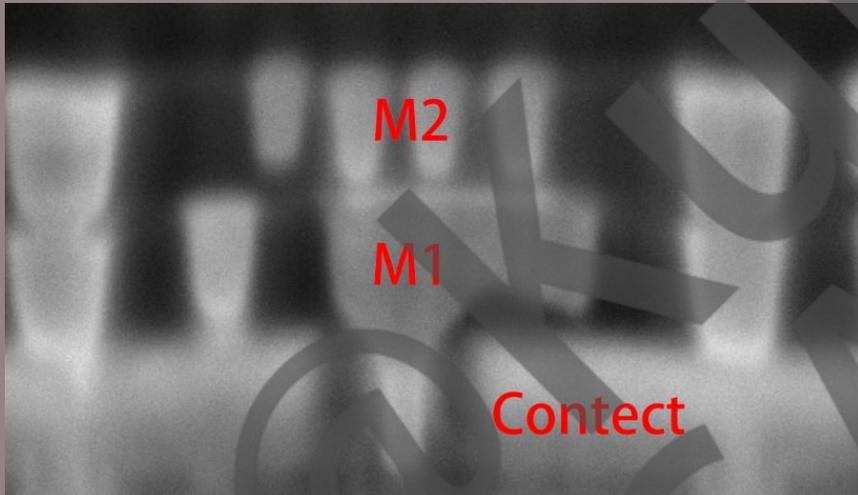
This 2 libs Fin Pitch both 42nm

2+2 Fin



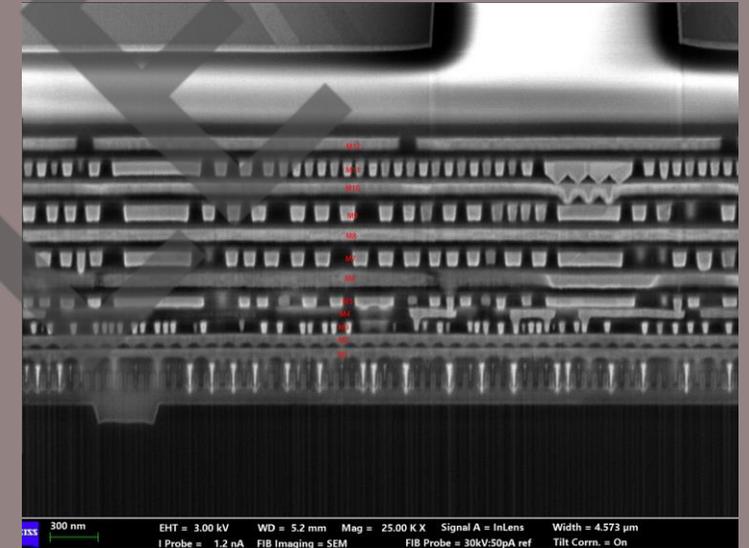
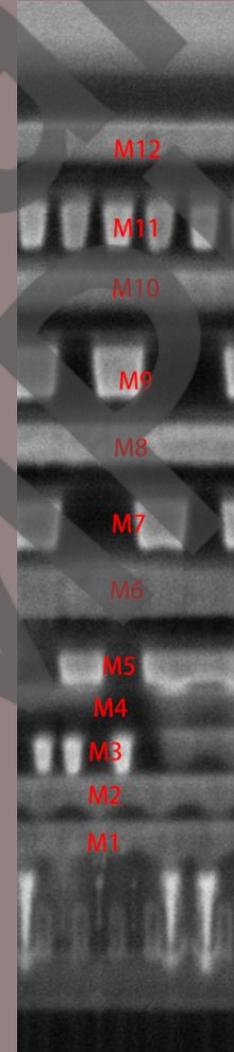
Data From (T239 2-10)

On the top of the Fin, there are **Metal layers**
We need to know the **minimum metal pitch**, and **metal 2 pitch**

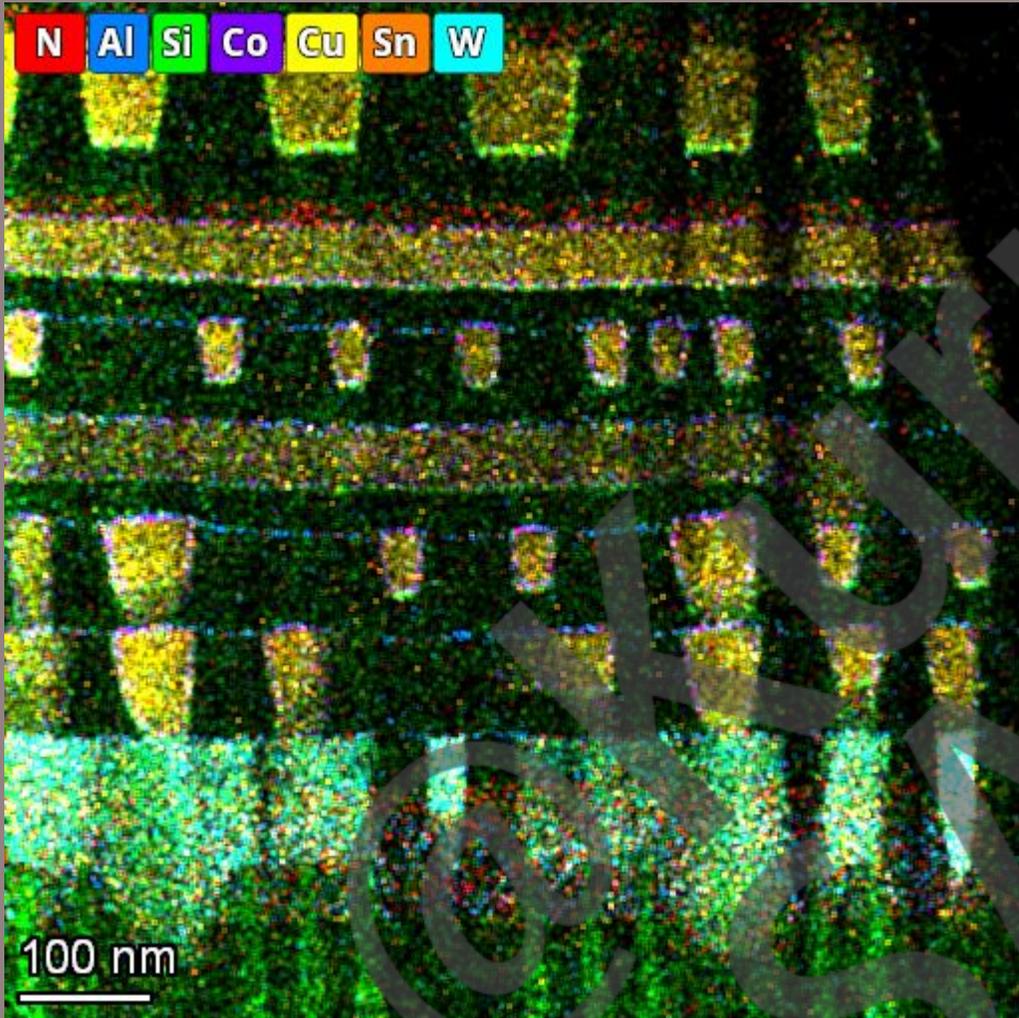


Data From (T239 2-07)

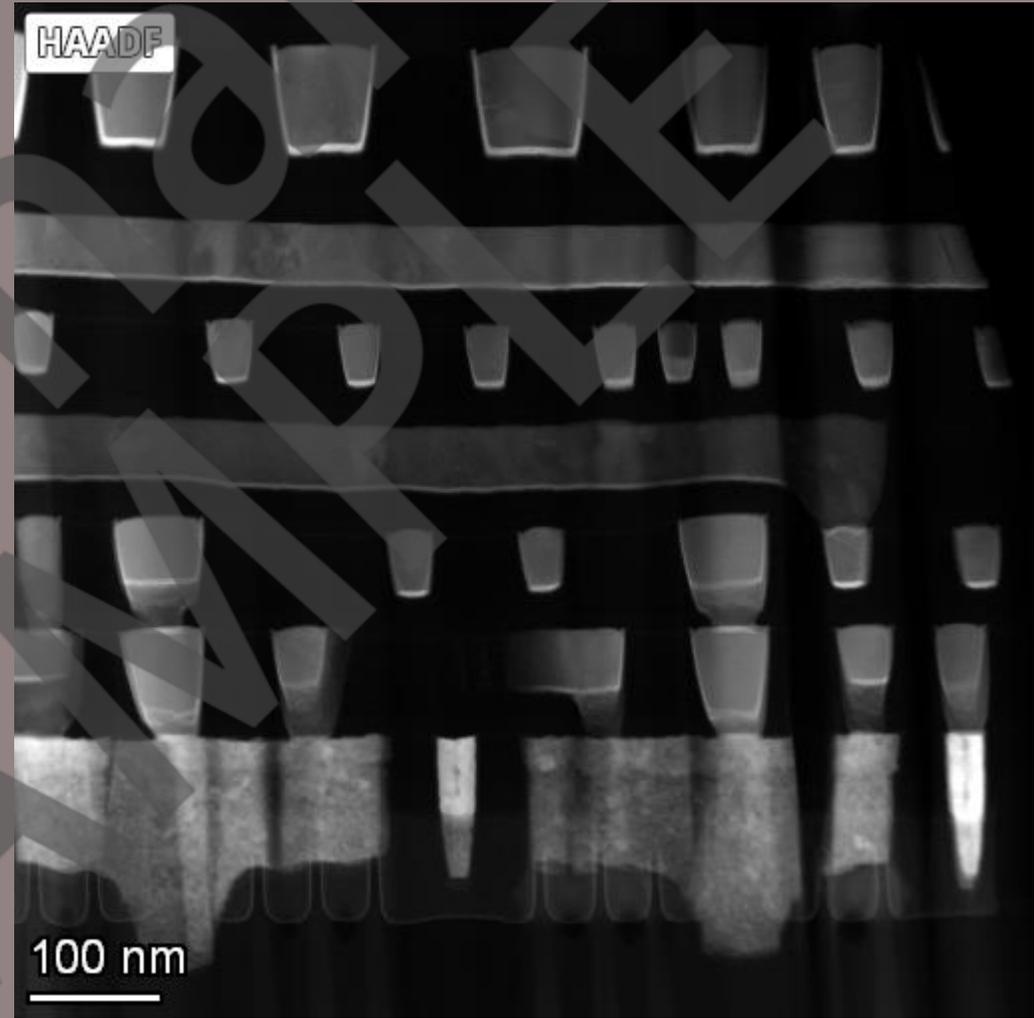
	Pitch	MMP	Element	Isolation(down)
M1	68nm	Gate Pitch	eCu	Aluminium?
M2	48nm	1x	eCu	Aluminium?
M3	48nm	1x	eCu	Aluminium?
M4	48nm	1x	eCu	Aluminium?
M5	80nm	1.66x	eCu	Aluminium?
M6	80nm	1.66x	Cu	Nitride
M7	80nm	1.66x	Cu	Nitride
M8	80nm	1.66x	Cu	Nitride
M9	80nm	1.66x	Cu	Nitride
M10	80nm	1.66x	Cu	Nitride
M11	80nm	1.66x	Cu	Nitride
M12	80nm	1.66x	Cu	Nitride



Data From (T239 I-07)

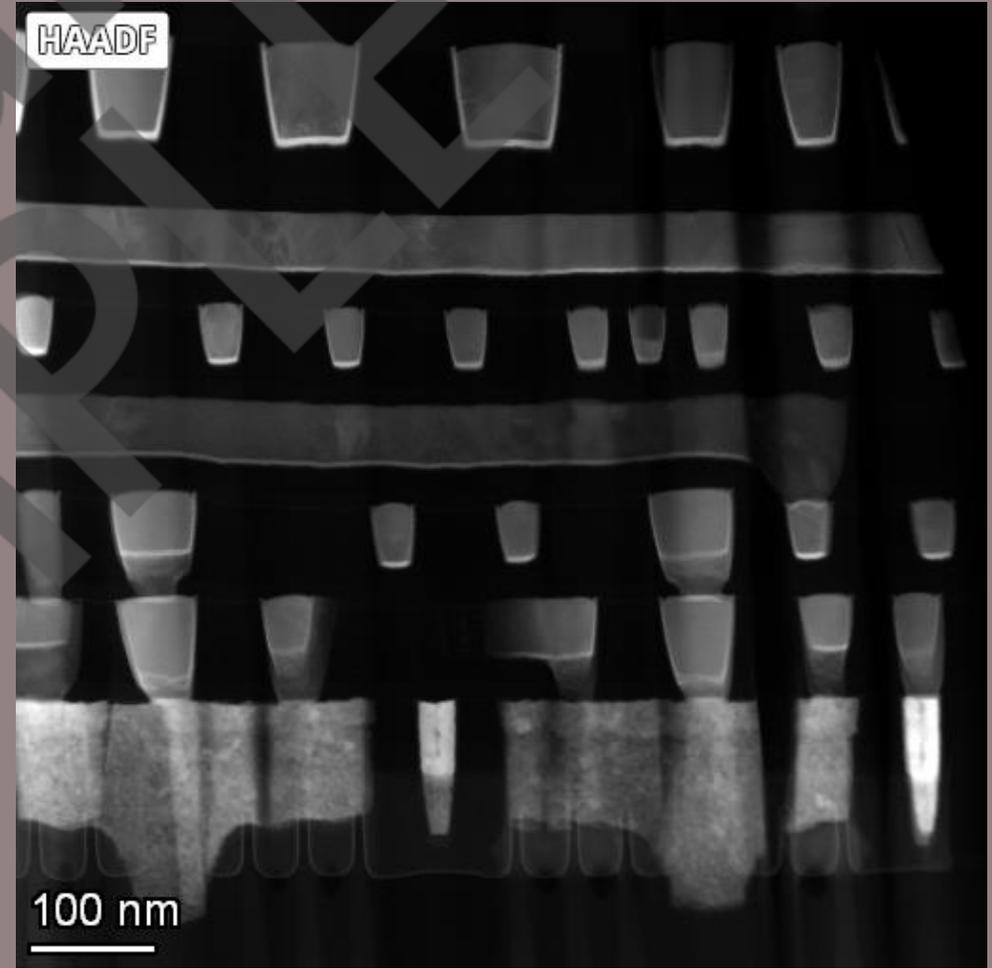
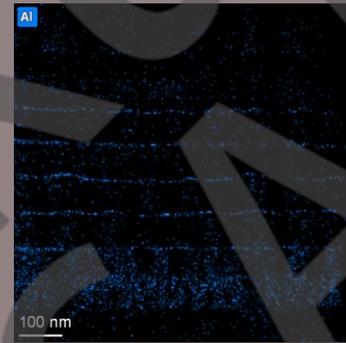
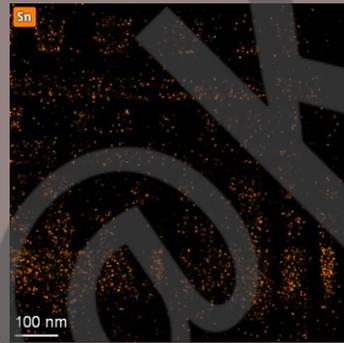
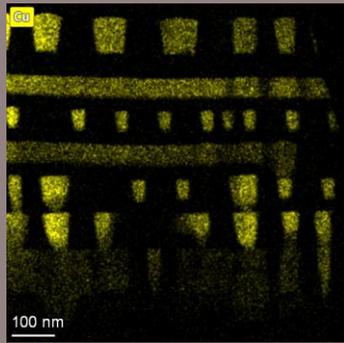
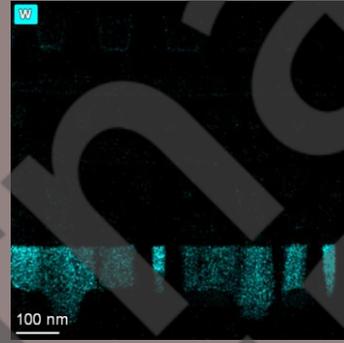
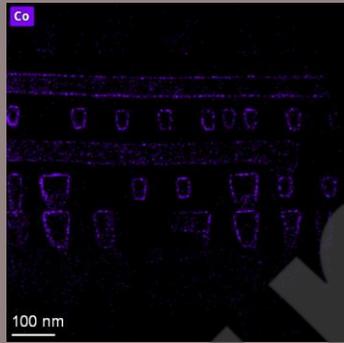
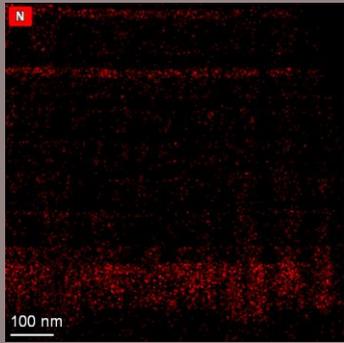
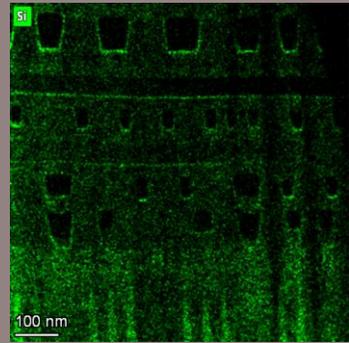


Data From (T239 EDSY ILA 1040 SI 130 kx ColorMix-net)

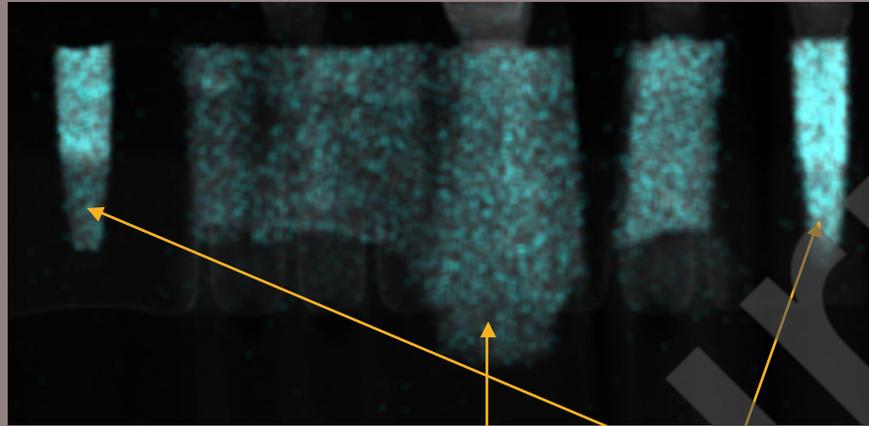


Data From (T239 EDSY ILA 1040 SI 130 kx HAADF)

Process analyze-Nvidia T239-Fin cut-EDS



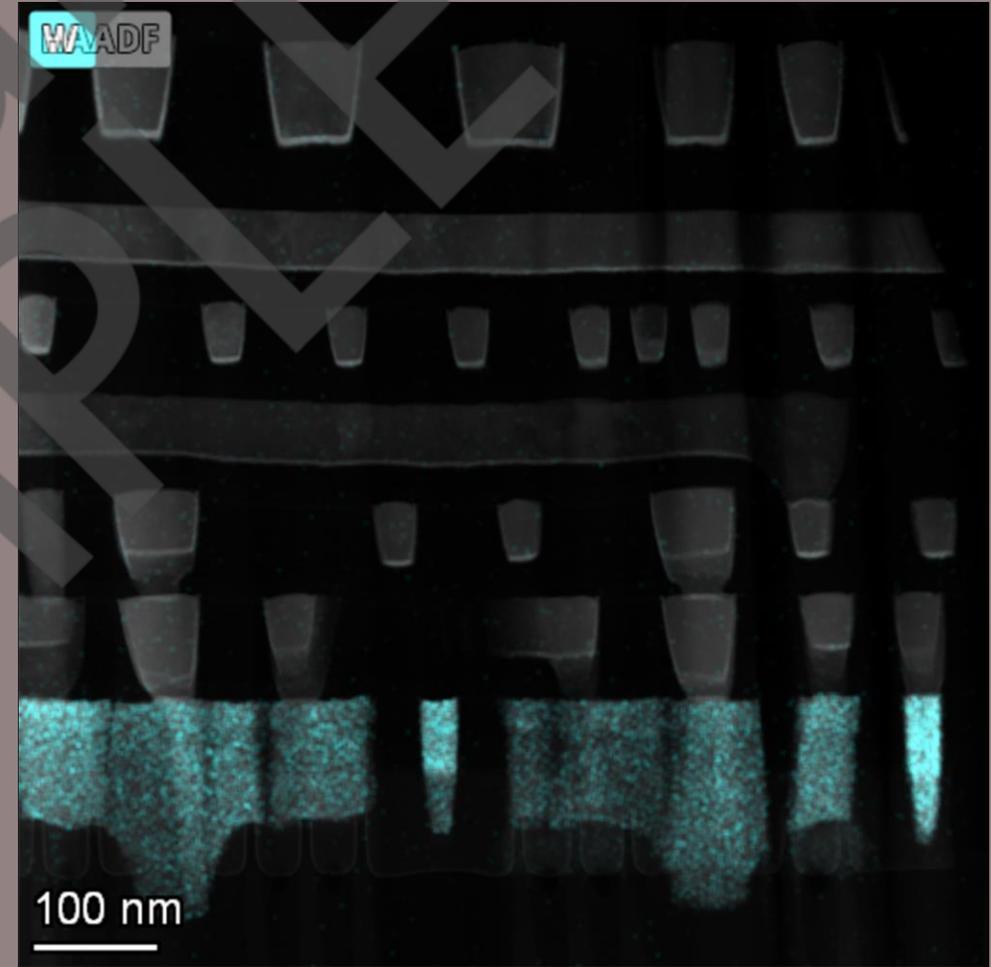
Data From (T239 EDSY ILA I040 SI I30 lx HAADF)



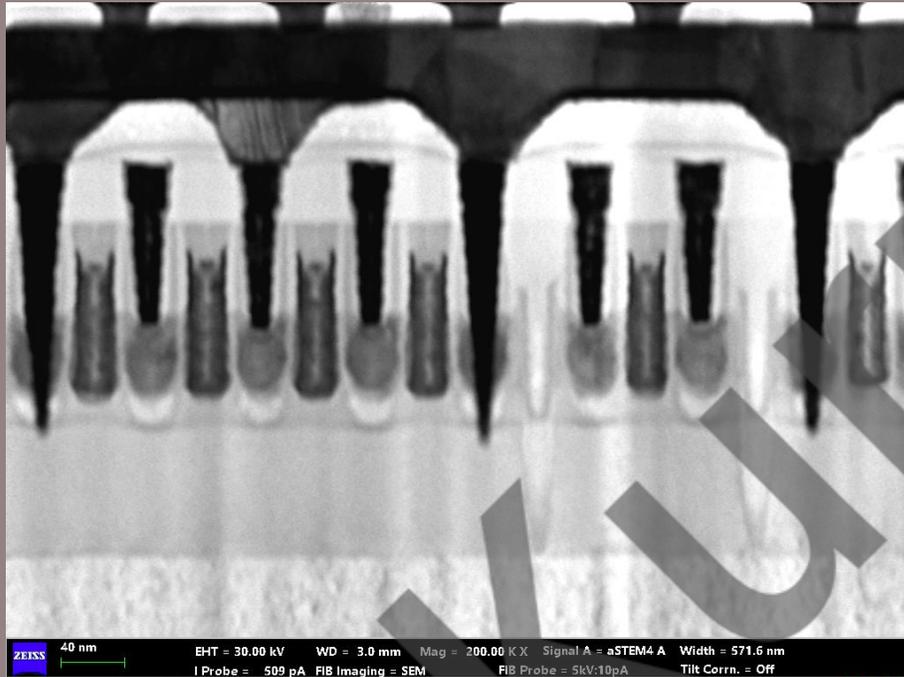
Used the **W** for **Gate** and **contact plug**



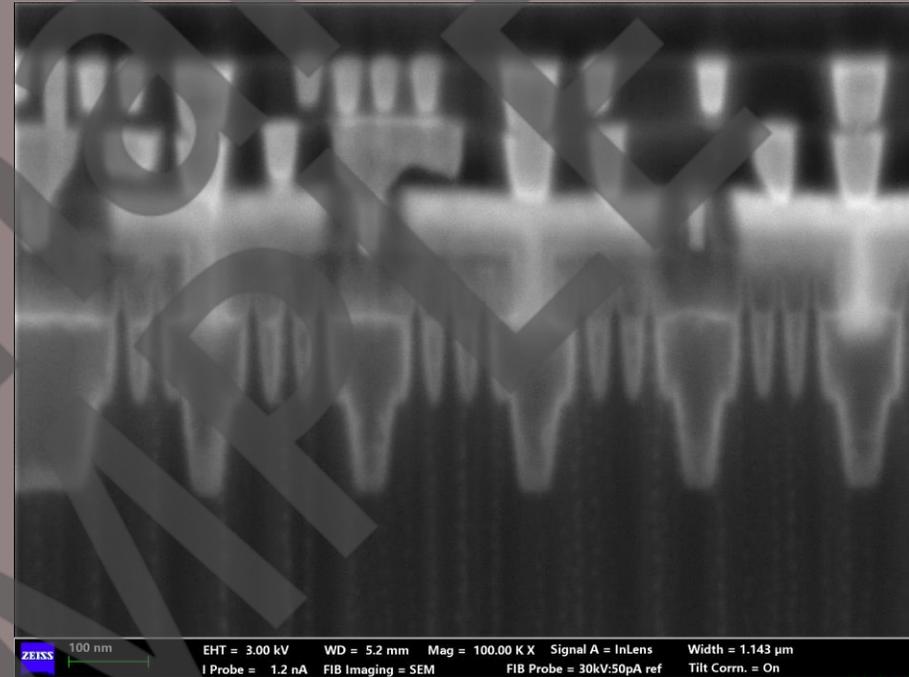
Used the **N** for **Fin isolation**



Data From (T239 EDSY ILA I040 SI I30 lx HAADF)



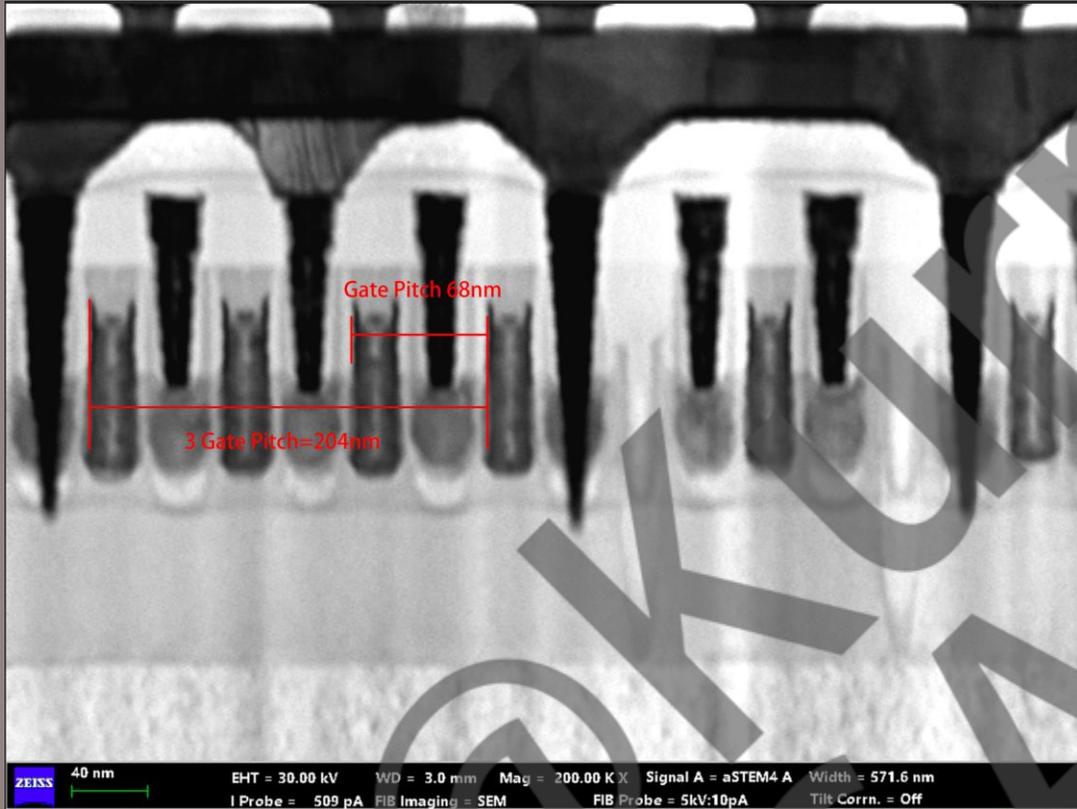
X-Cut(1) Gate cut



Y-Cut(2) Fin cut

Analyze Gate cut



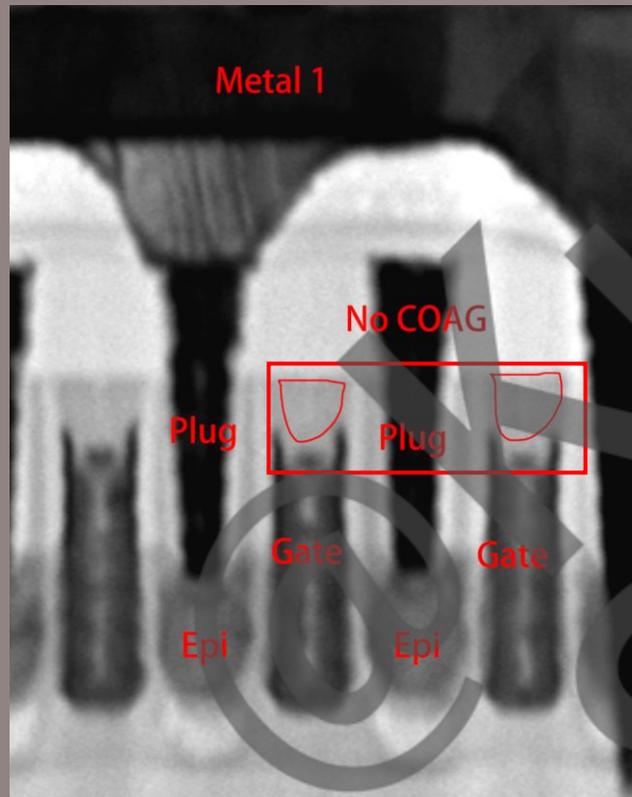


The Gate Pitch= 68nm

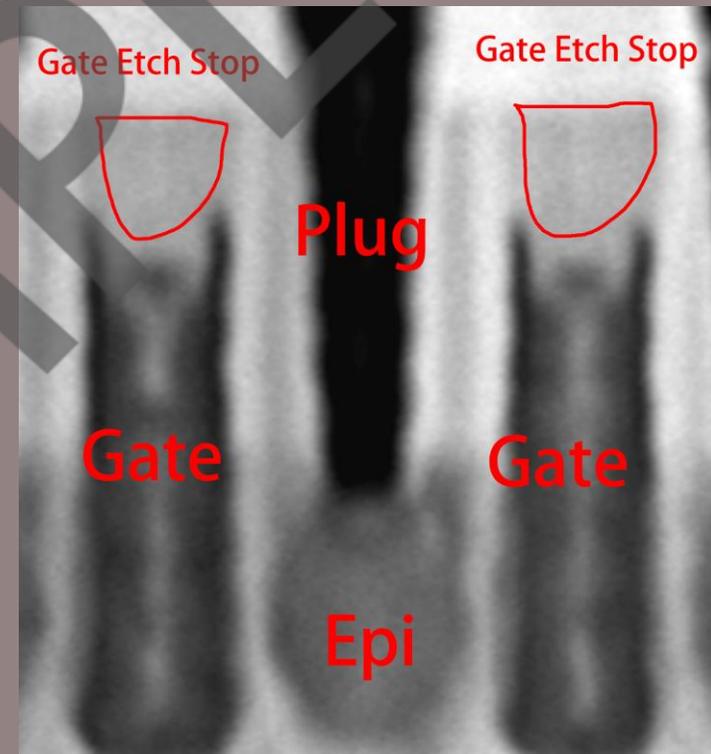


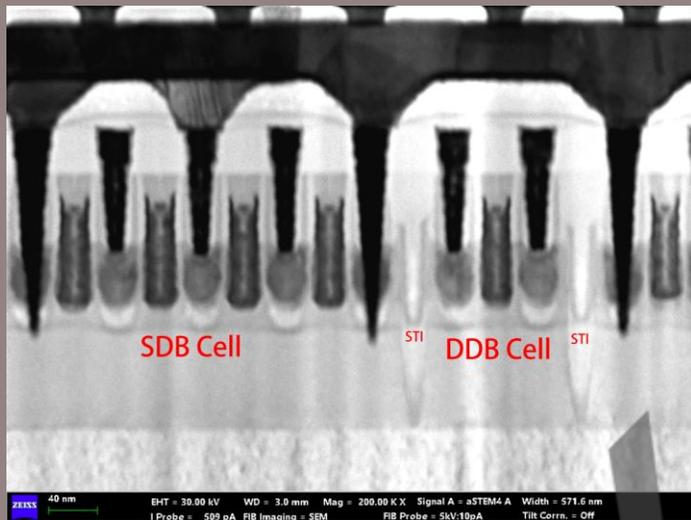
Data From (T239 I-16)

No COAG (contact Over Active Gate)

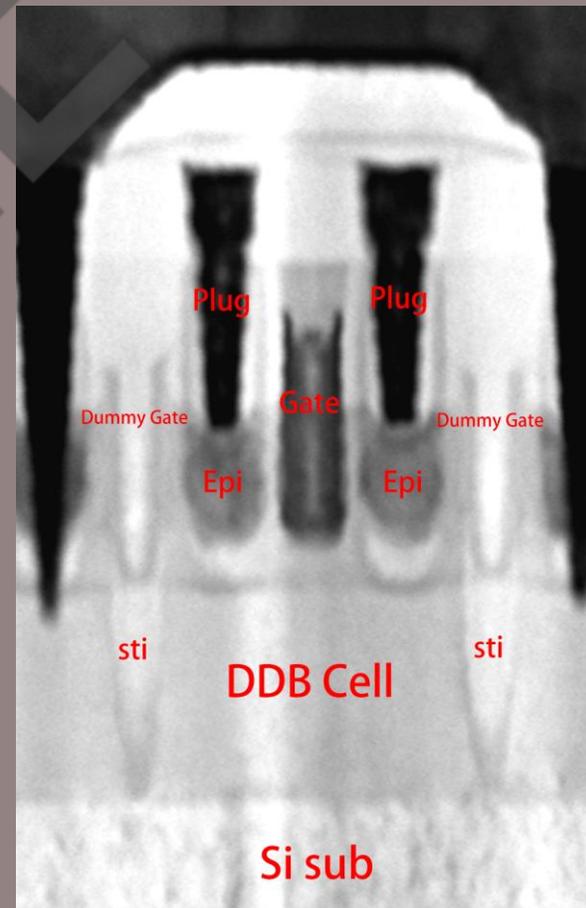
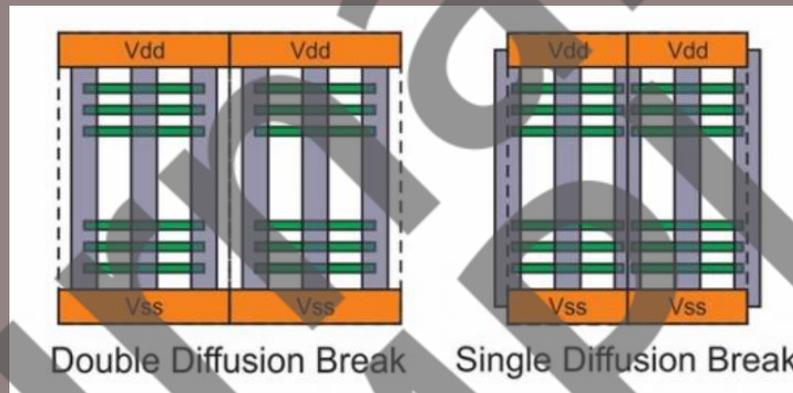


Use Self-Aligned-contact



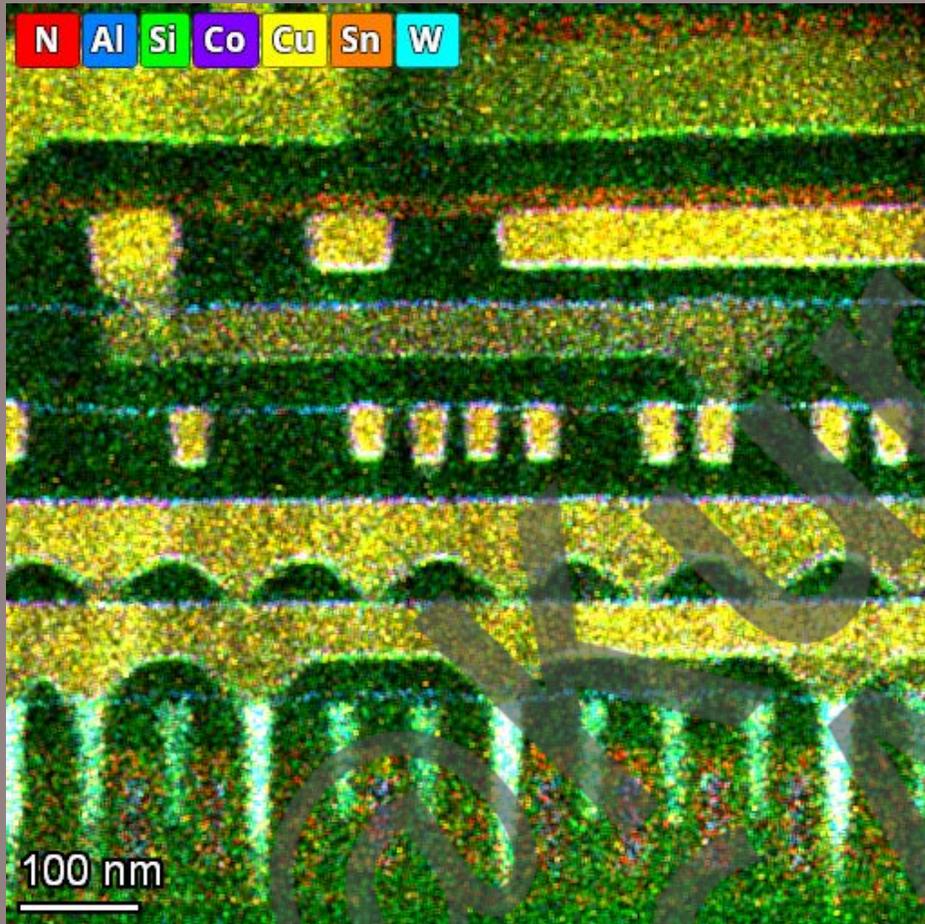


Data From (T239 I-16)

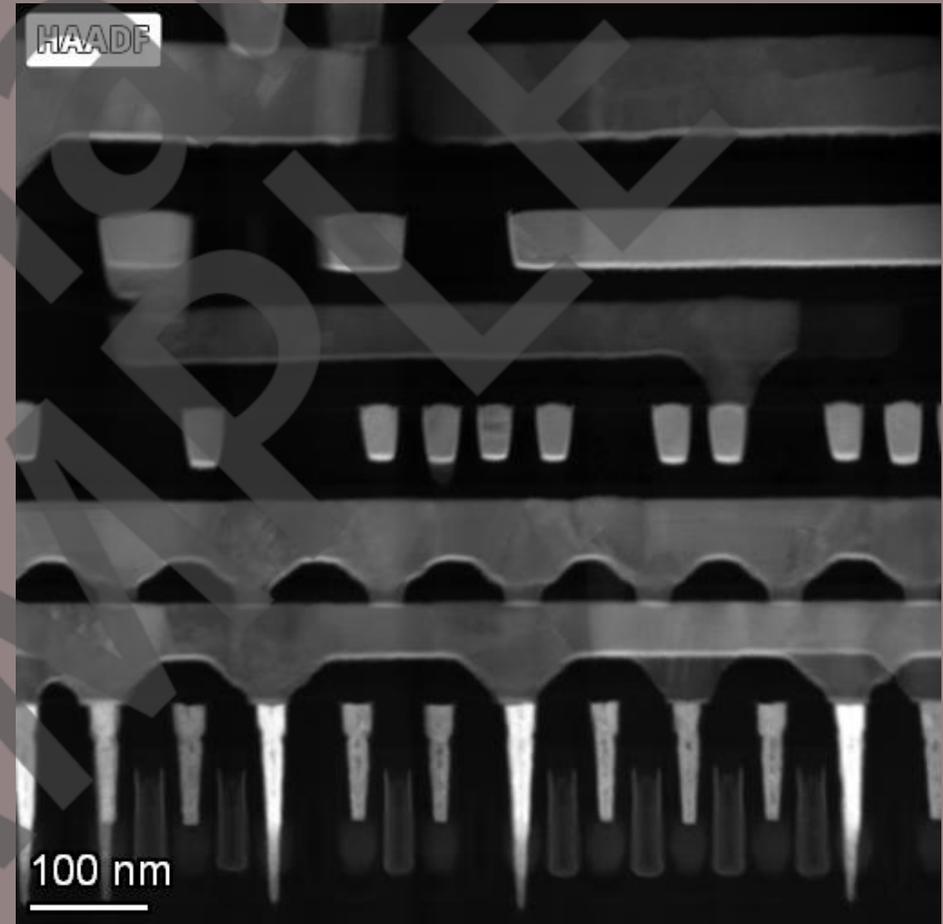


This Process uses MDB(Mixed Diffusion Break)

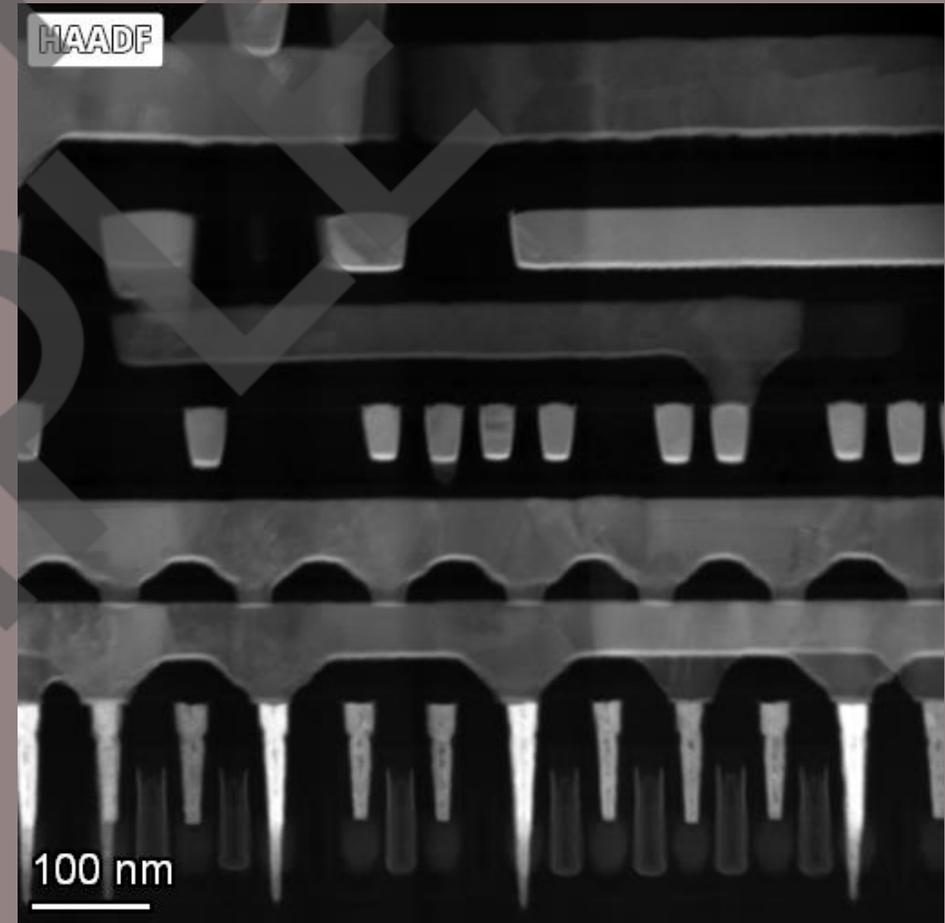
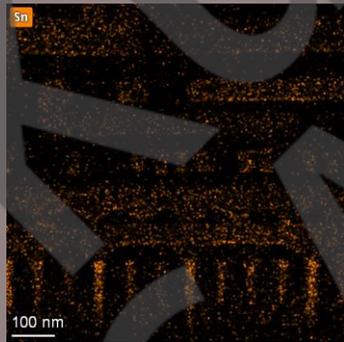
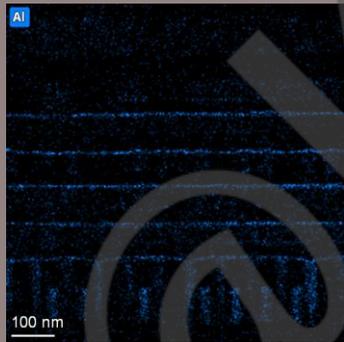
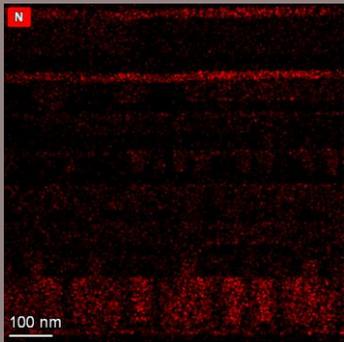
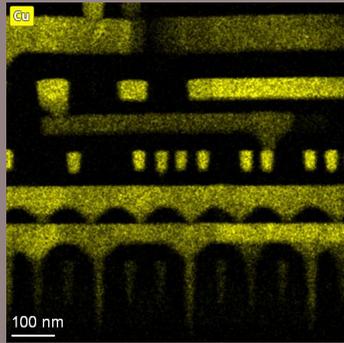
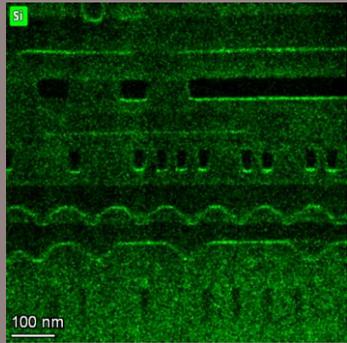
Mixed the DDB and SDB



Data From (T239 EDS X ILA 1008 SI 130 kx ColorMix-net)



Data From (T239 EDS X ILA 1008 SI 130 kx HAADF)

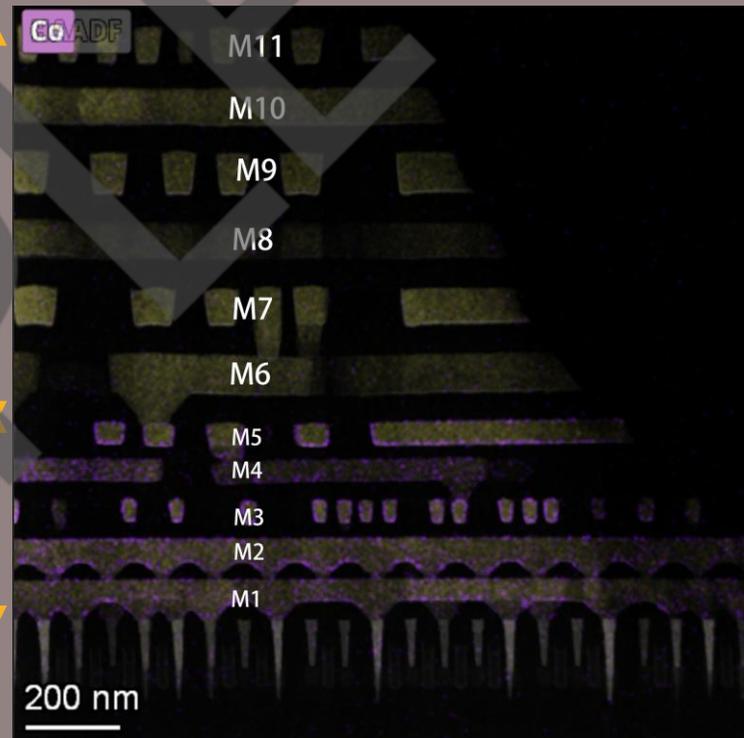
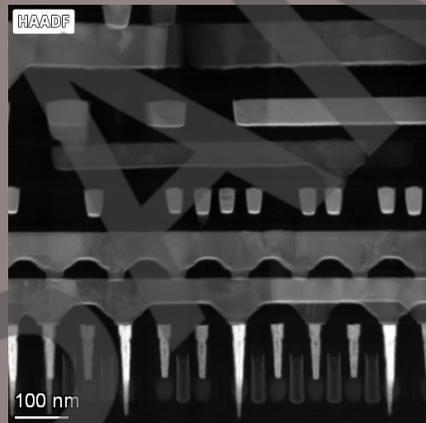
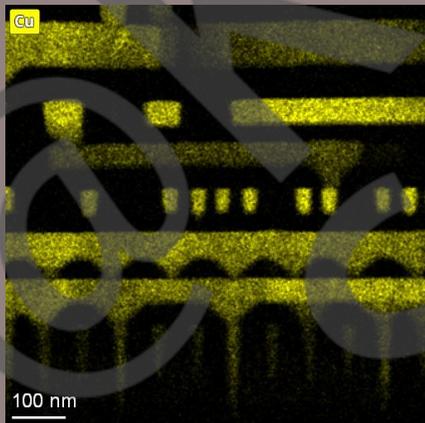
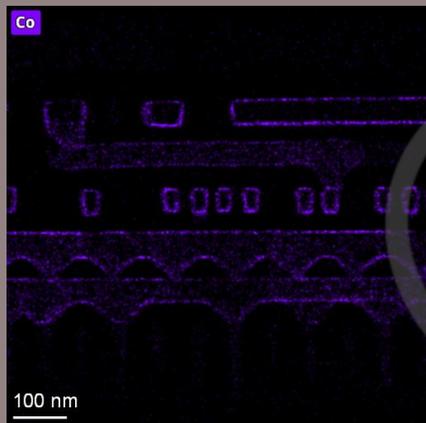
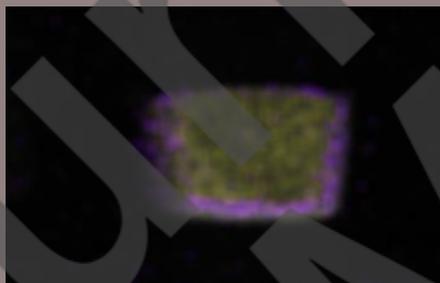


Data From (T239 EDS X ILA 1008 SI 130 kx HAADF)

M6-M12 used the **Pure Cu**

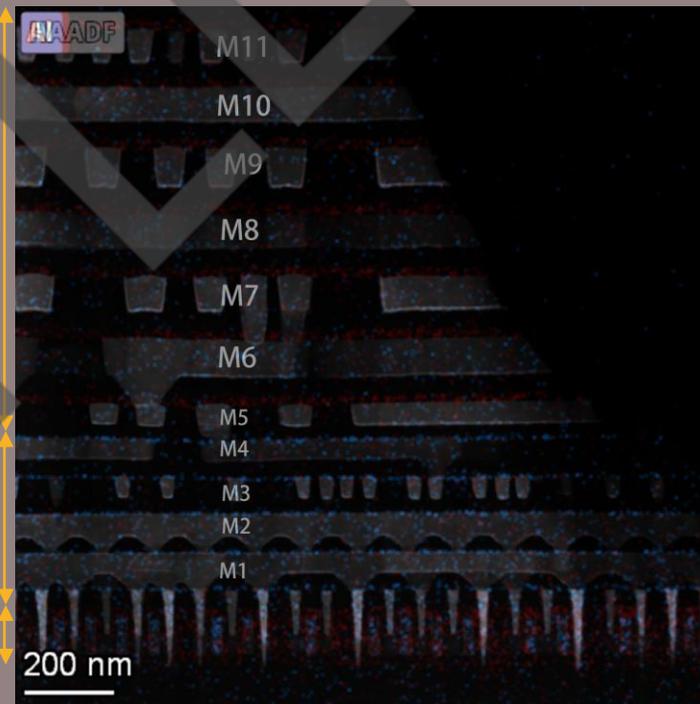
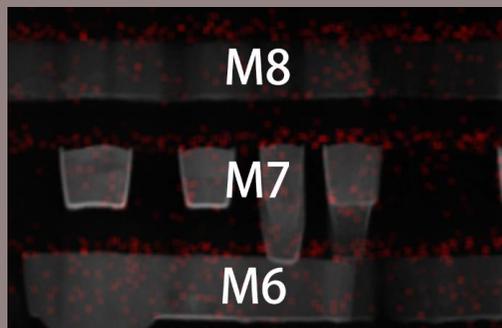


Metal 1 – Metal 5 used the **Enhanced Cu**
Co cladding Cu

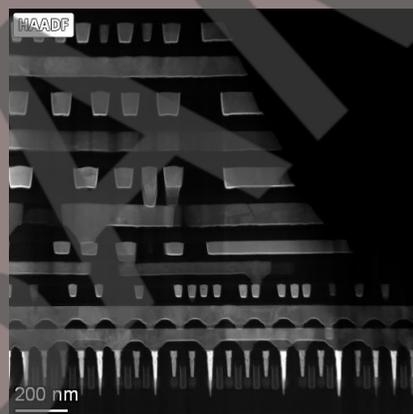
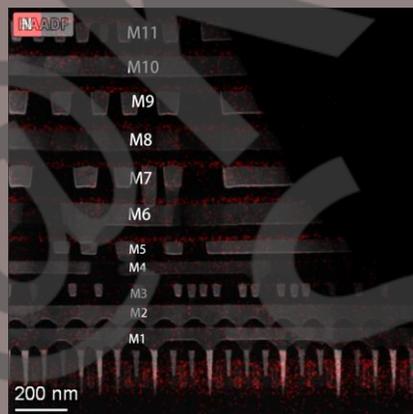
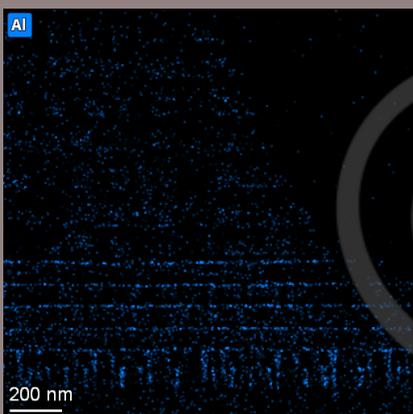


Data From (T239 EDS X 2LA I024 SI 64000 x HAADF)

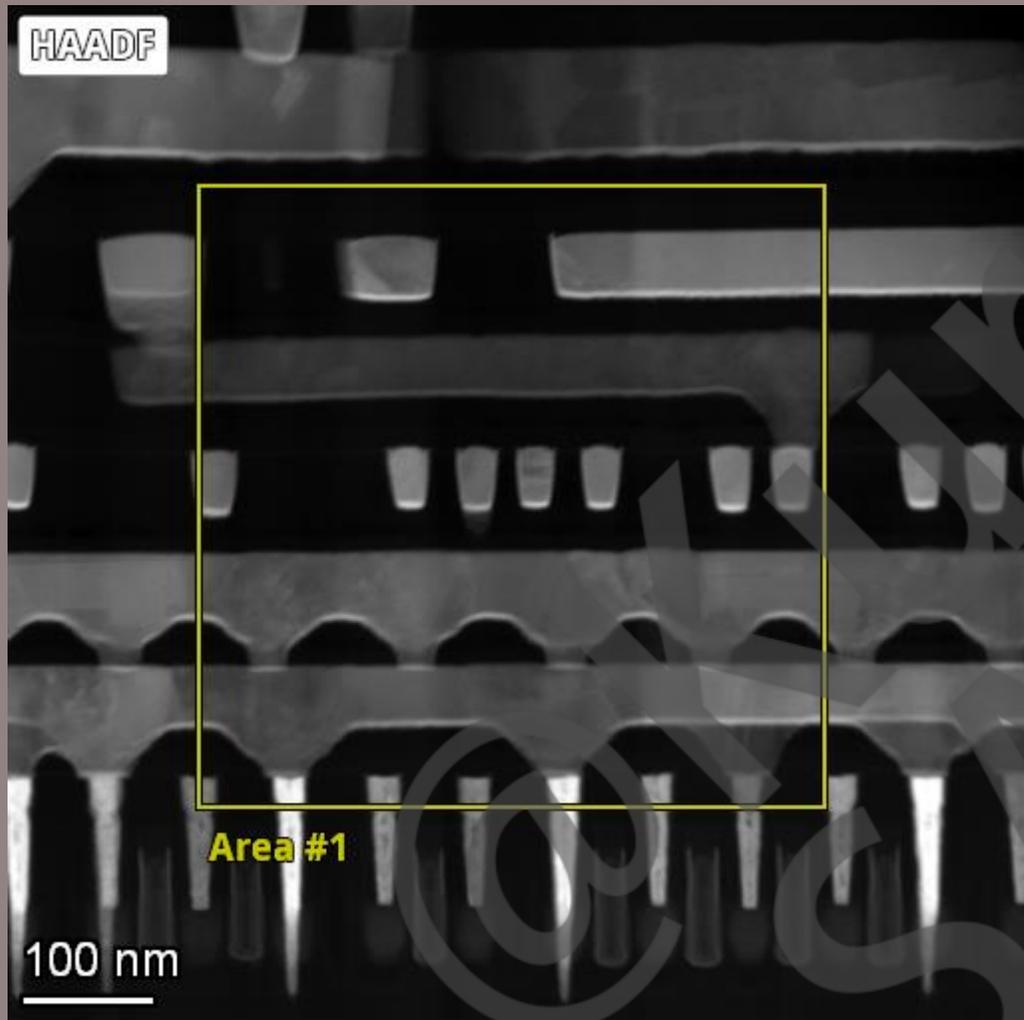
Thin film deposition used From **isolation** From **N** on the **Top** of **M5** to **M12** and **Sub**



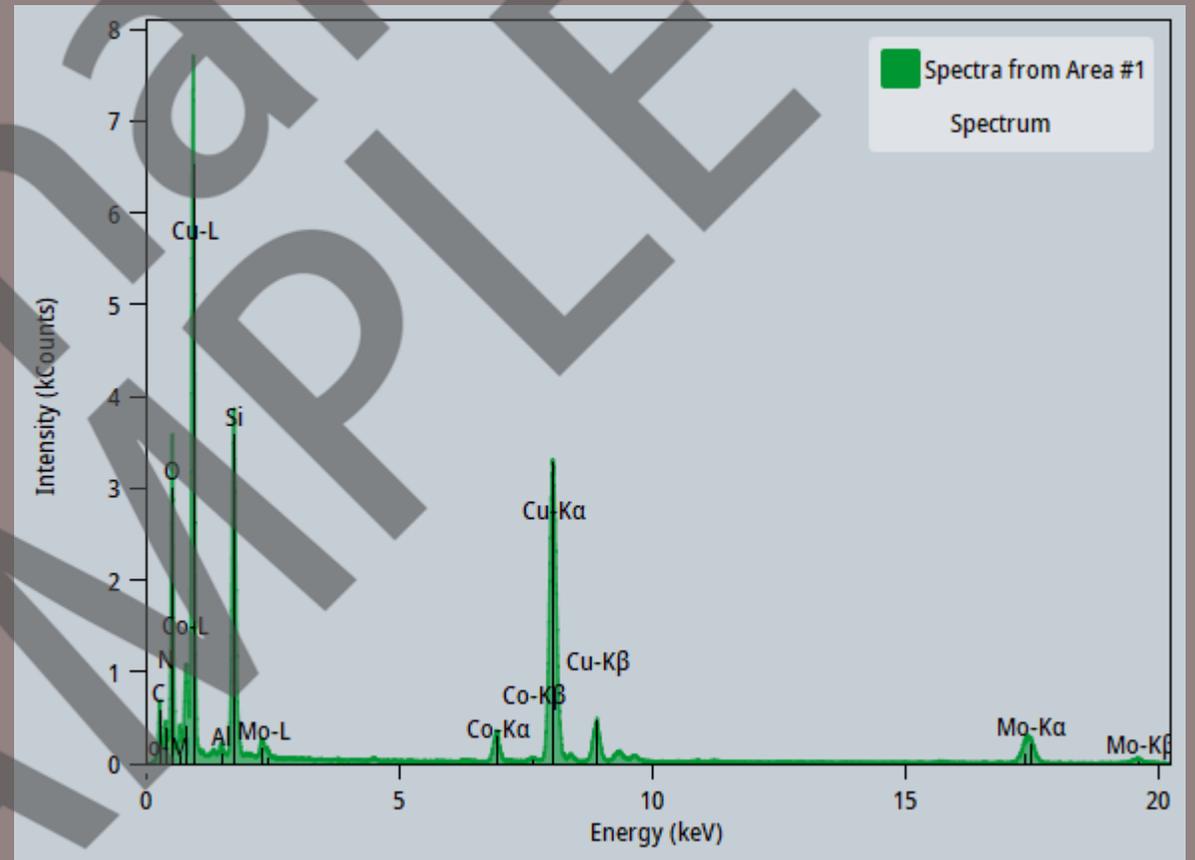
Thin film deposition used From **Al** on the **Top** of **Contact** to **M11**



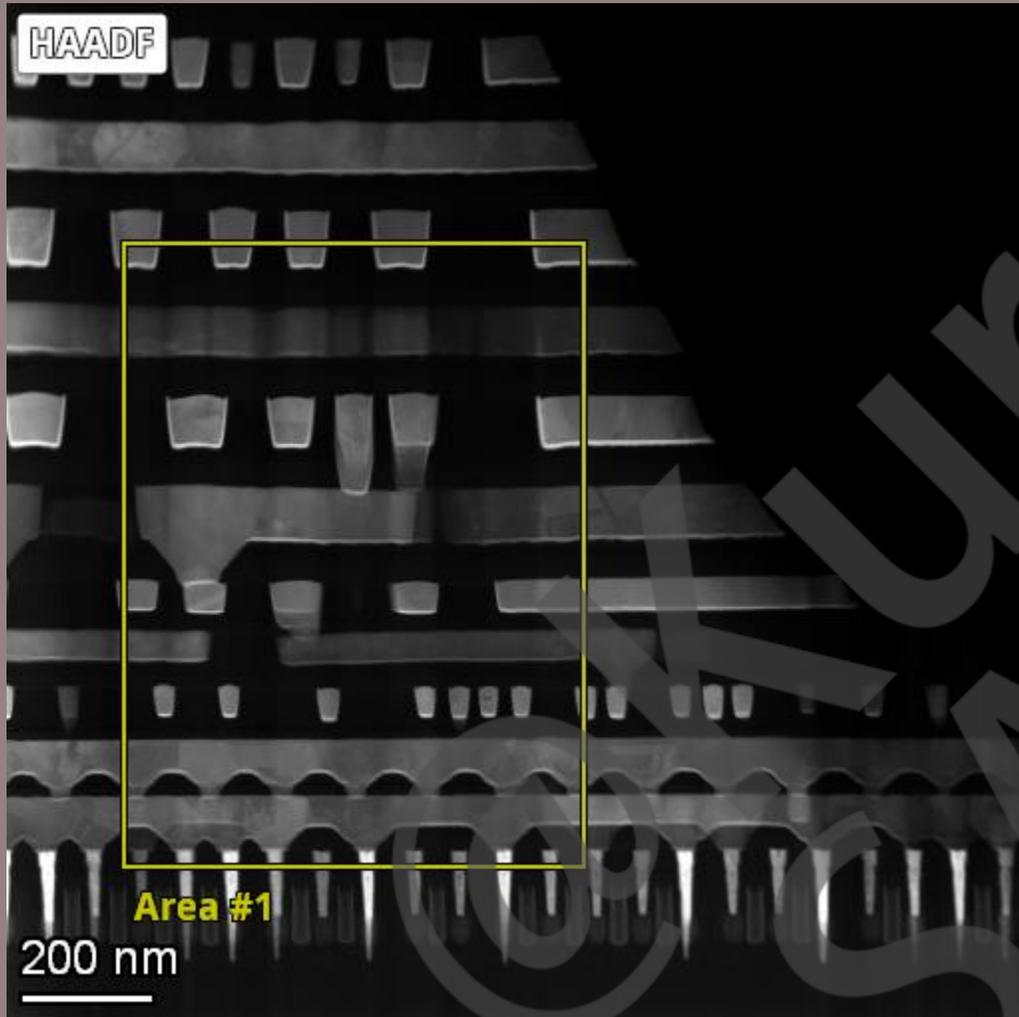
Data From (T239 EDS X ILA 1008 SI 130 kx HAADF)



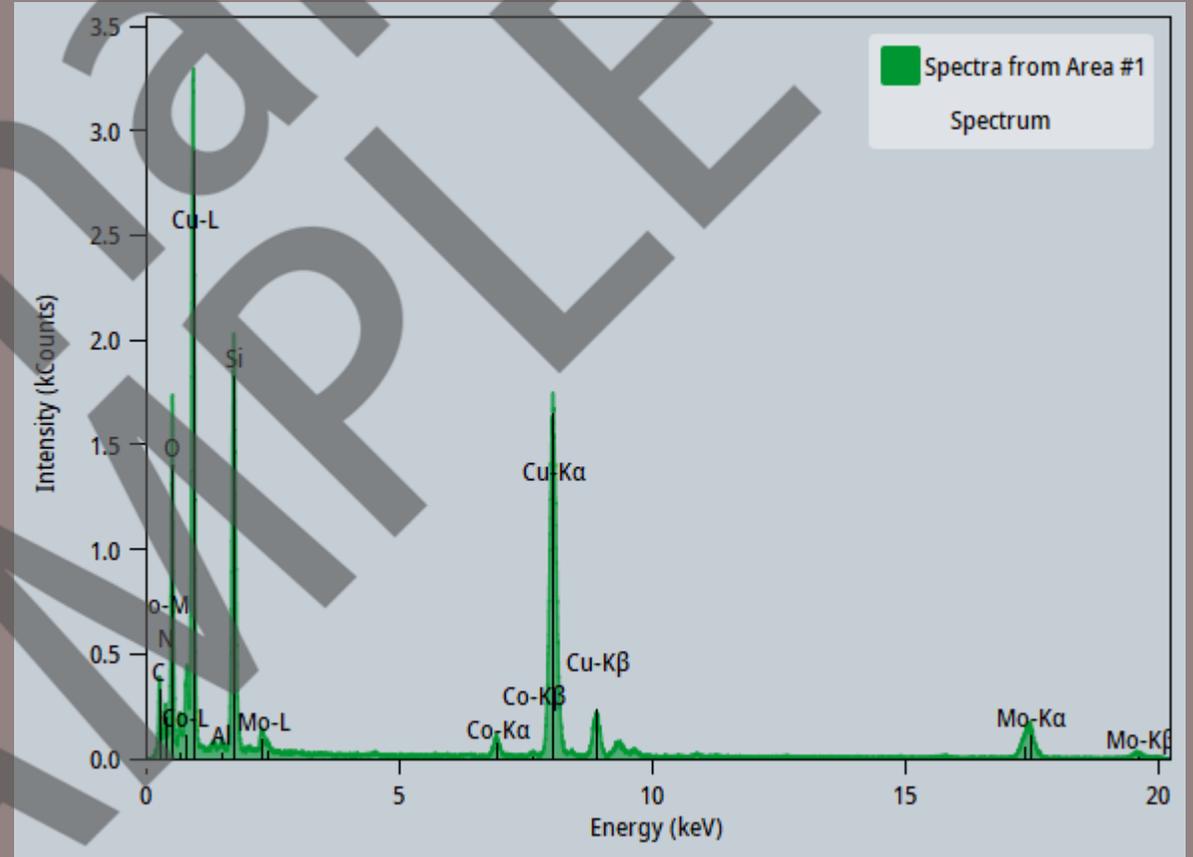
Data From (T239 EDS X ILA 1008 SI 130 kx ColorMix)



Data From (T239 EDS X ILA 1008 SI 130 kx)

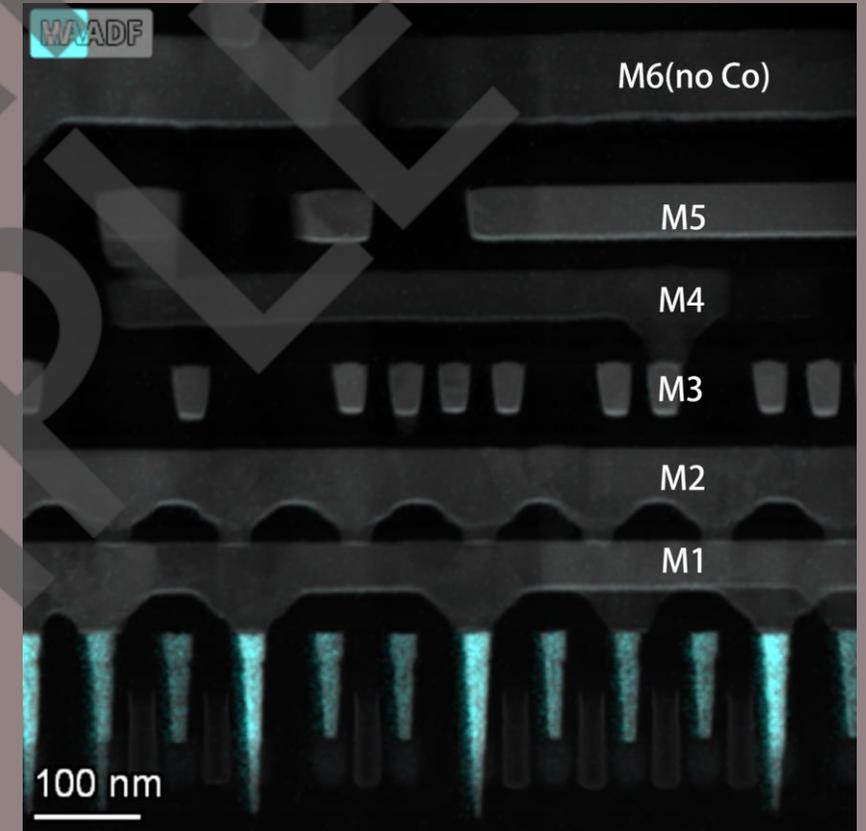
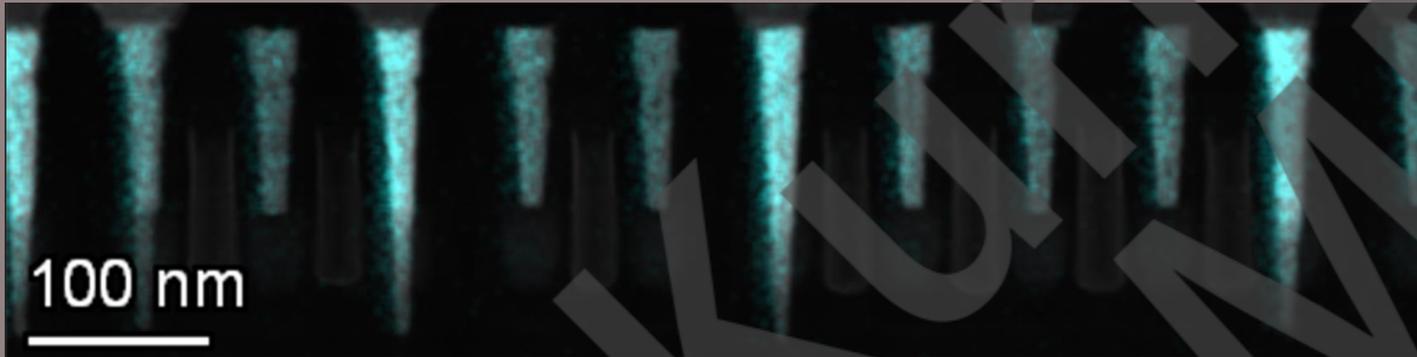


Data From (T239 EDS X 2LA 1024 SI 64000 x ColorMix)



Data From (T239 EDS X 2LA 1024 SI 64000 x)

Uses W to form plugs and contacts



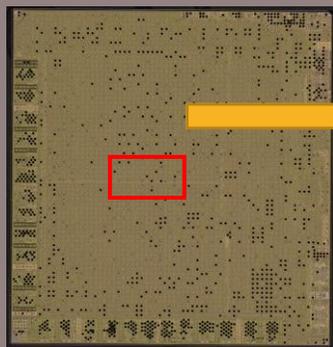
Data From (T239 EDS X ILA 1008 SI 130 kx HAADF)

	Pitch	MMP	Element	Isolation(down)
M1	68nm	Gate Pitch	eCu	Aluminium?
M2	48nm	1x	eCu	Aluminium?
M3	48nm	1x	eCu	Aluminium?
M4	48nm	1x	eCu	Aluminium?
M5	80nm	1.66x	eCu	Aluminium?
M6	80nm	1.66x	Cu	Nitride
M7	80nm	1.66x	Cu	Nitride
M8	80nm	1.66x	Cu	Nitride
M9	80nm	1.66x	Cu	Nitride
M10	80nm	1.66x	Cu	Nitride
M11	80nm	1.66x	Cu	Nitride
M12	80nm	1.66x	Cu	Nitride

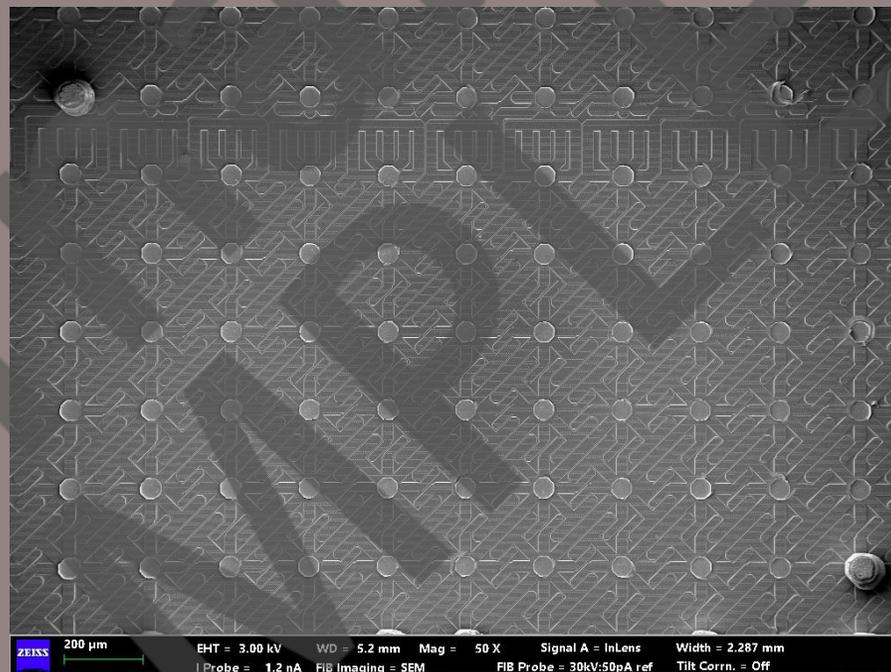
	Data
Fin Pitch	42nm
Fin number	2+2/3+3
Gate Pitch	68nm
Gate Element	HKMG(W)
2+2 Cell Height	413nm
3+3 Cell Height	413nm
Diffusion Break	MDB
Contact	SAC
Contact Element	W

Switch2 soc analyze

Process analyze-**Samsung 8nm(8N)**



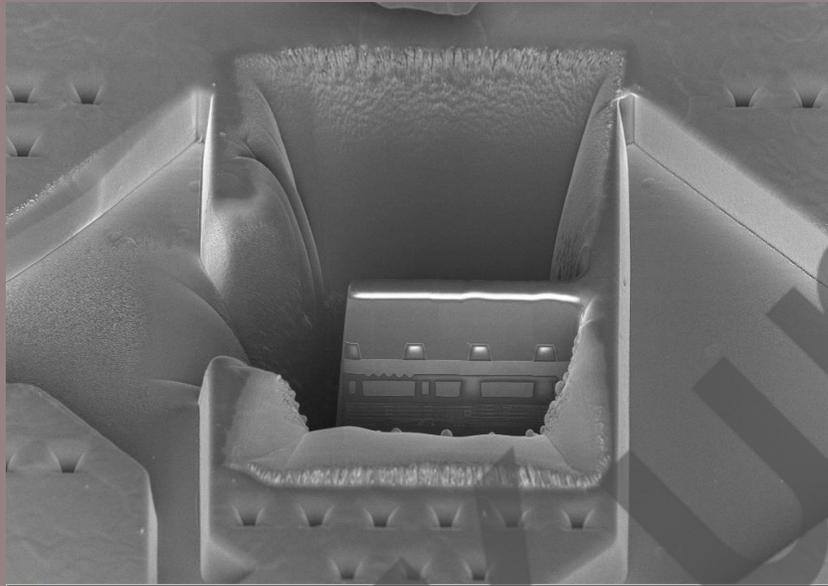
Nvidia GA107 Die photo



Nvidia GA107 Die photo

Using another chip fabricated in **Samsung 8nm (Nvidia GA107)** to analyze the fabrication process.

We chose the **GPU** for process analysis



ZEISS 4 µm EHT = 3.00 kV WD = 5.2 mm Mag = 2.00 K X Signal A = InLens Width = 57.16 µm
I Probe = 1.2 nA FIB Imaging = SEM FIB Probe = 30kV:50pA ref Tilt Corr. = On

Data From (GA107 1-02)

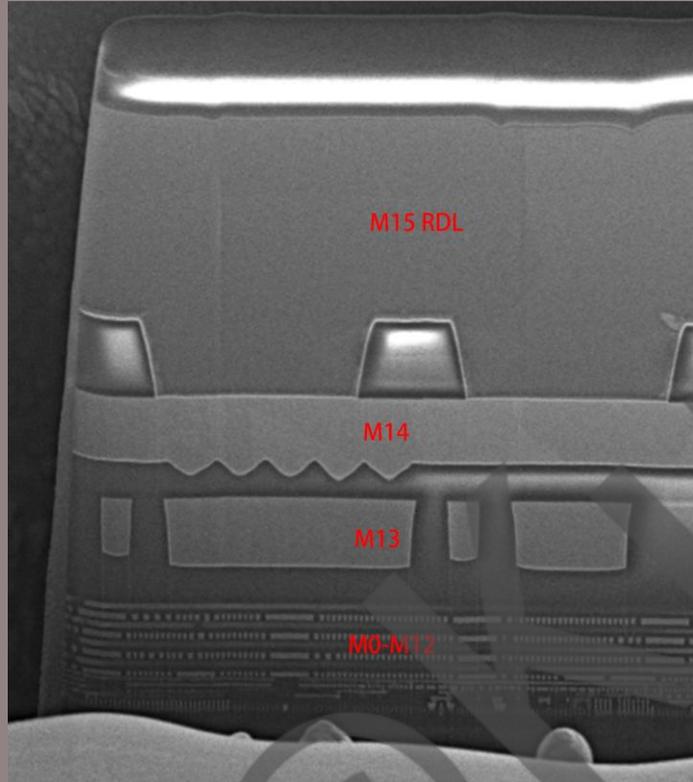
X-Cut(1)



ZEISS 2 µm EHT = 3.00 kV WD = 5.2 mm Mag = 5.00 K X Signal A = InLens Width = 22.87 µm
I Probe = 1.2 nA FIB Imaging = SEM FIB Probe = 30kV:50pA ref Tilt Corr. = On

Data From (GA107 2-02)

Y-Cut(2)

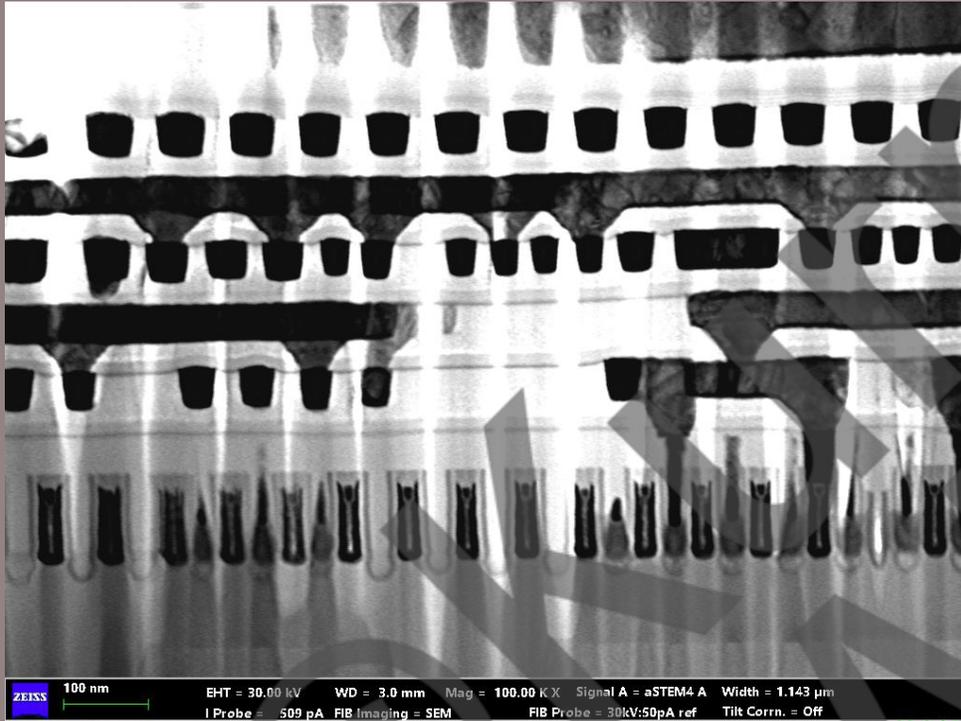


Data From (GA107 I-03)



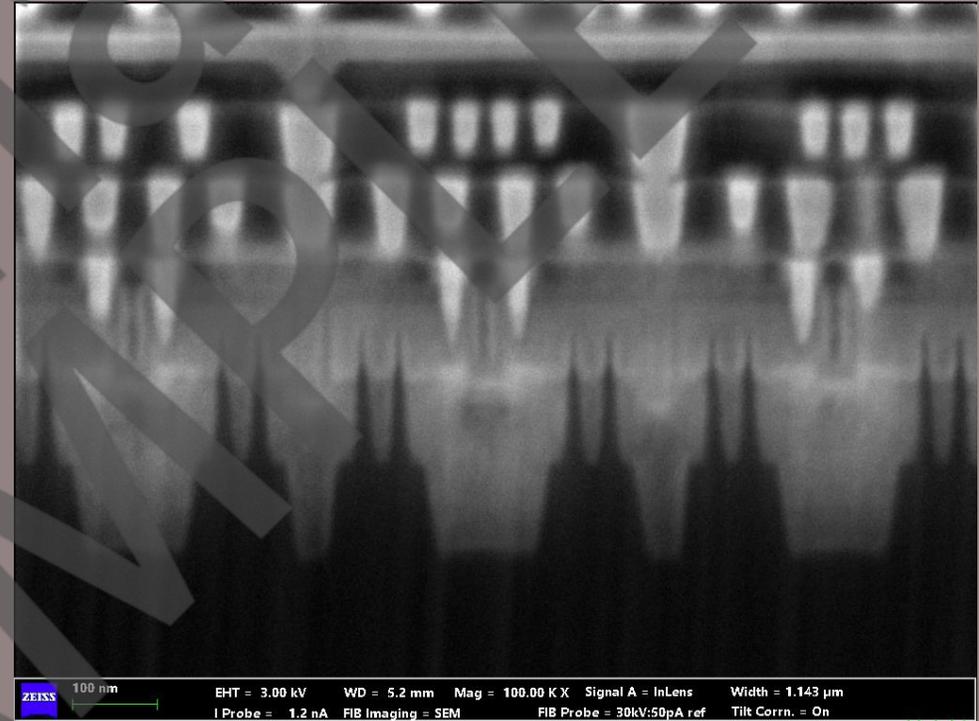
Data From (GA107 EDS-X- 094I Camera 7000 x Ceta)

In total there are 1 Poly 16 Metal (15M+1Rdl)



Data From (GA107 1-18)

Gate Cut

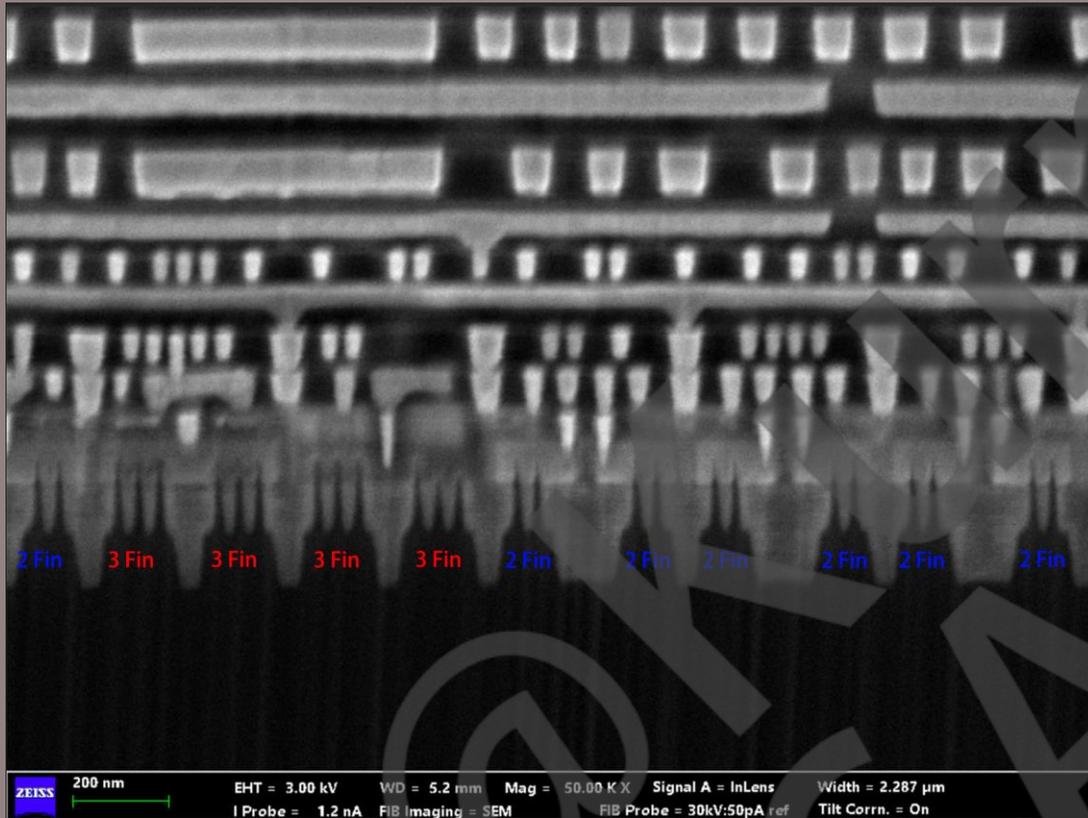


Data From (GA107 2-11)

Fin Cut

Analyze Fin Cut First





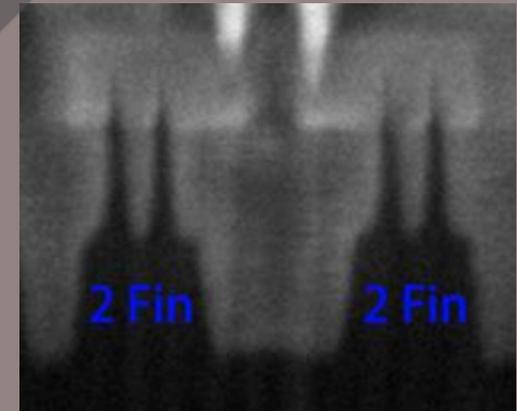
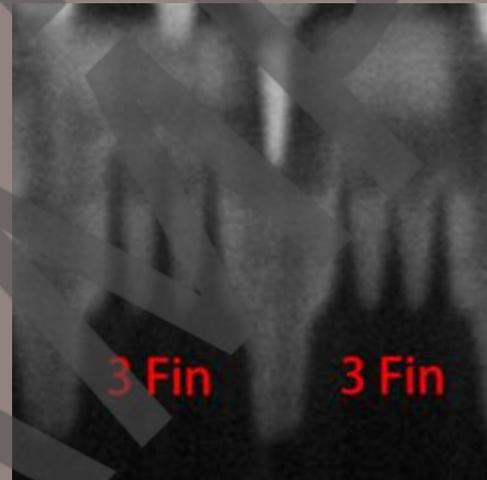
ZEISS 200 nm EHT = 3.00 kV WD = 5.2 mm Mag = 50.00 KX Signal A = InLens Width = 2.287 μm
I Probe = 1.2 nA FIB Imaging = SEM FIB Probe = 30kV:50pA ref Tilt Corr. = On

Data From (GA107 2-10)

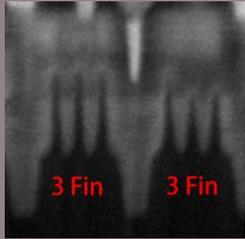
2 types of fin arrangement from different standard cell libraries

3+3 Fin

2+2 Fin

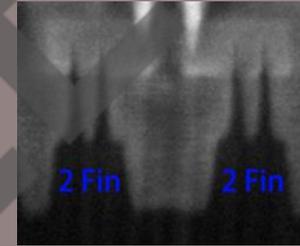


Data From (GA107 2-10)

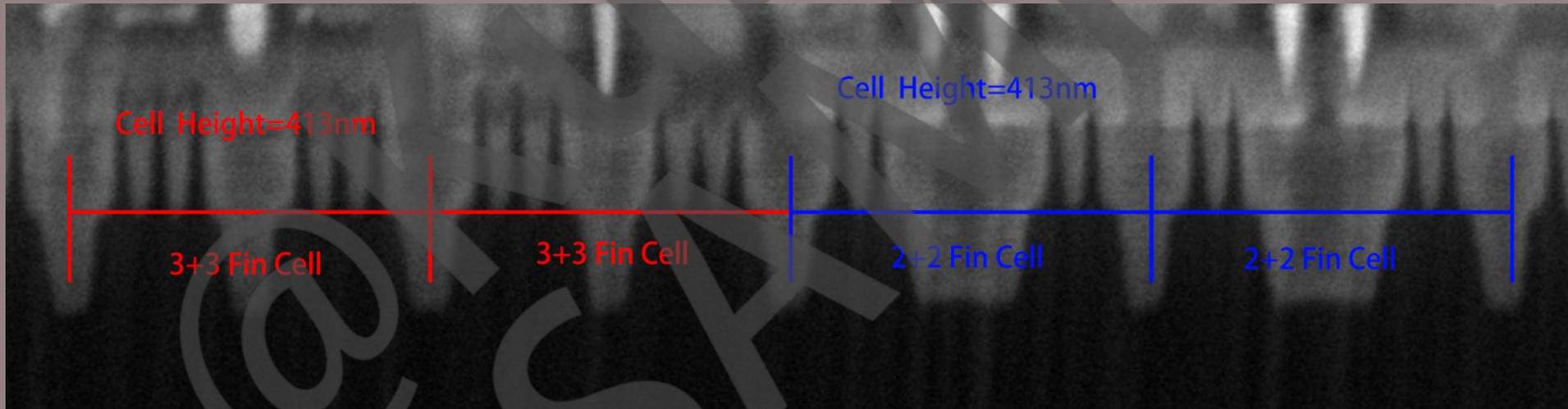


3+3 Fin

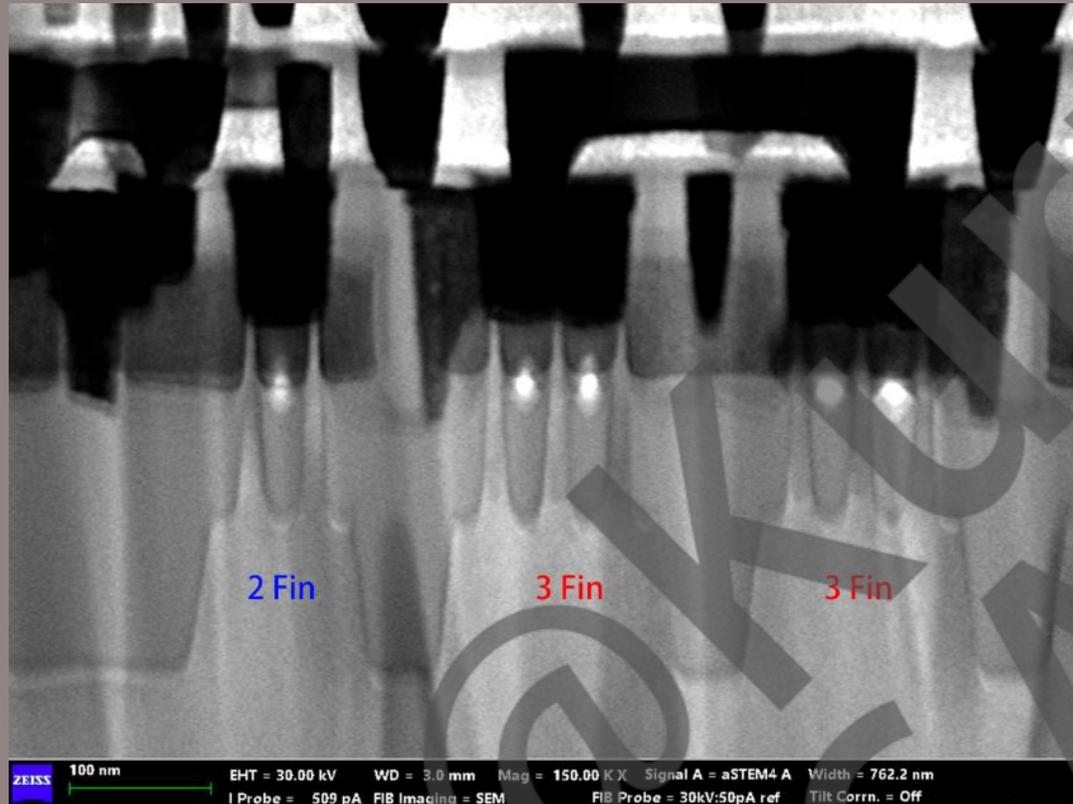
In the **GA107** die, fabricated in the **Samsung 8N** node
Both **3+3** and **2+2** cells share the same **cell height**



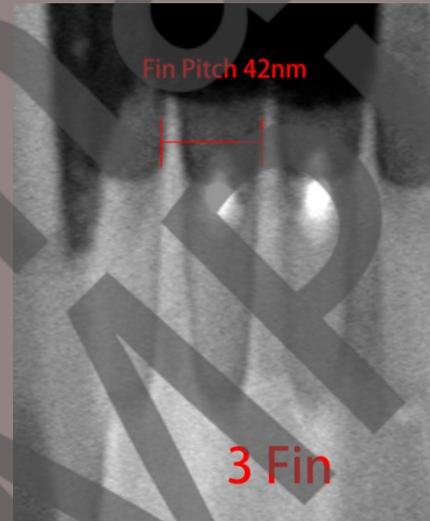
2+2 Fin



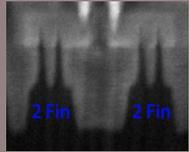
Data From (GA107 2-10)



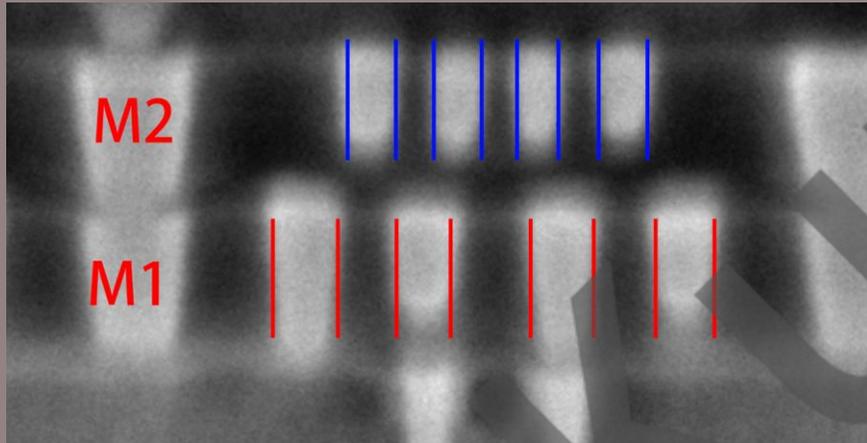
Data From (GA107 2-18)



Both libs share the same fin pitch of 42nm



2+2 Fin area

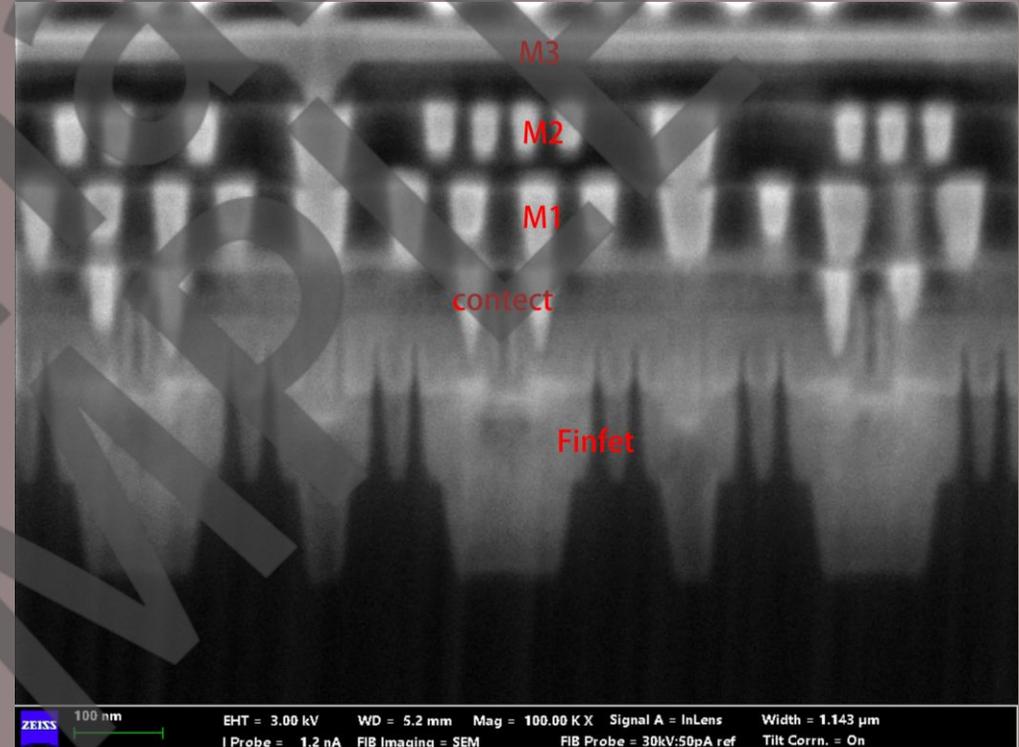


Min Metal Layer From Metal 2

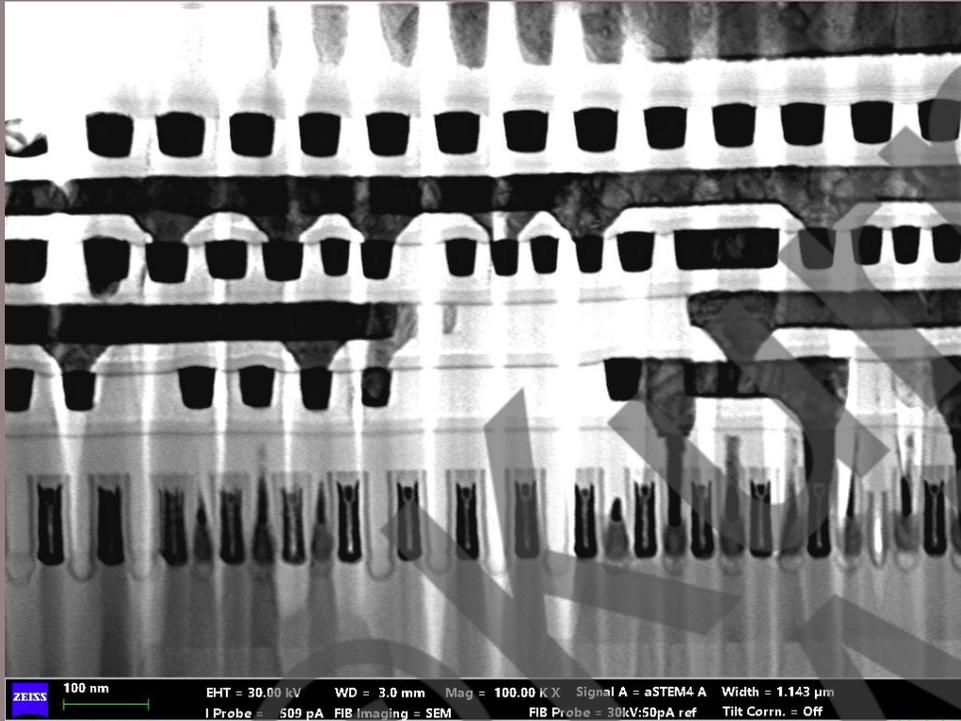
M1 Pitch= 68nm

M2 Pitch= 48nm

contact Pitch=M1 Pitch



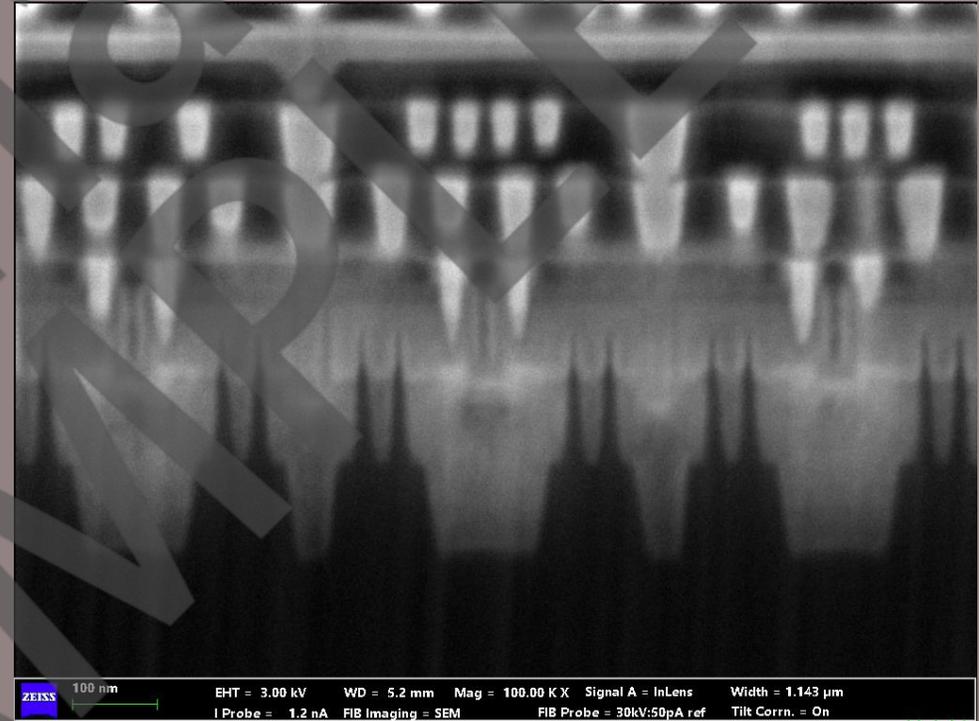
Data From (GAI07 2-11)



Data From (GAI07 1-18)

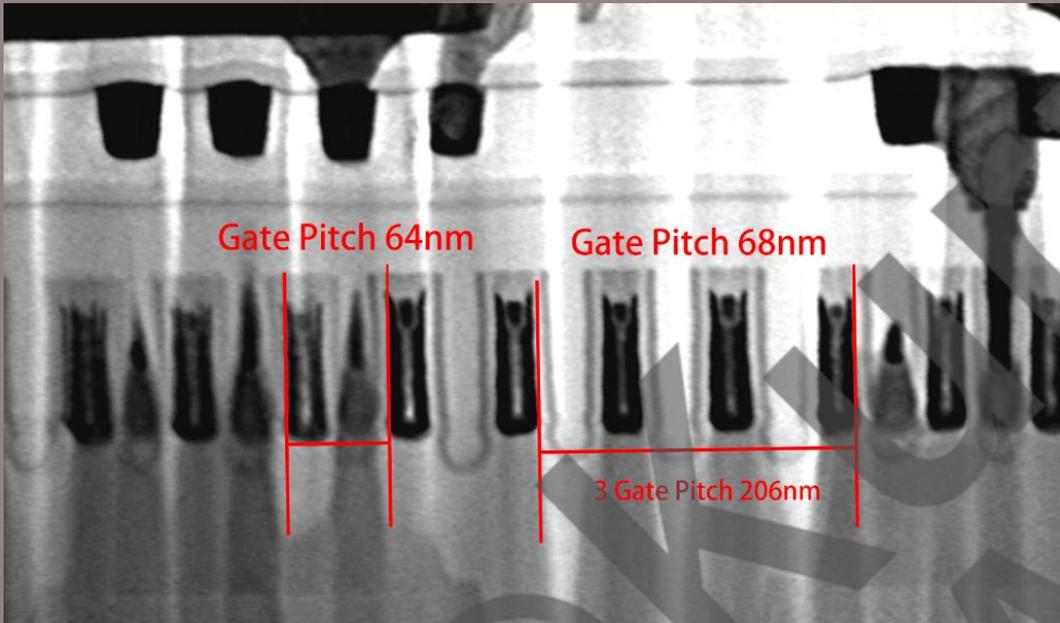
Gate Cut

Analyze Gate Cut

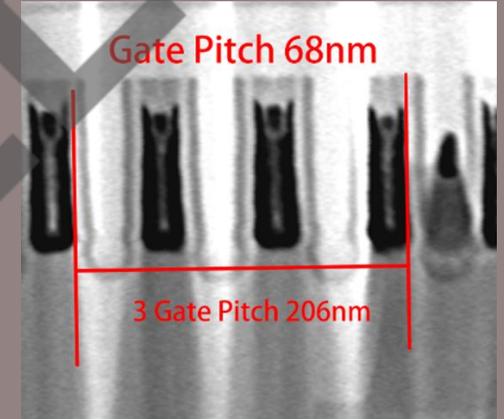
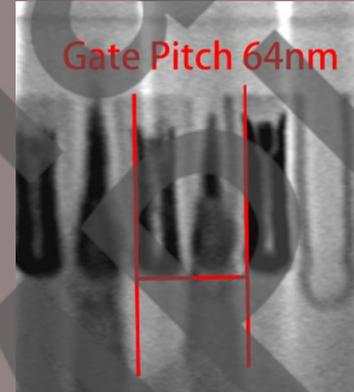


Data From (GAI07 2-11)

Fin Cut

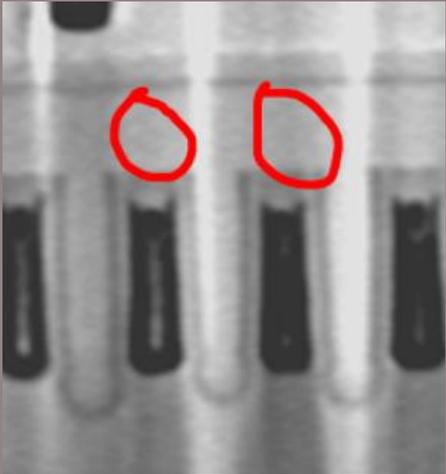


Data From (GAI07 1-18)

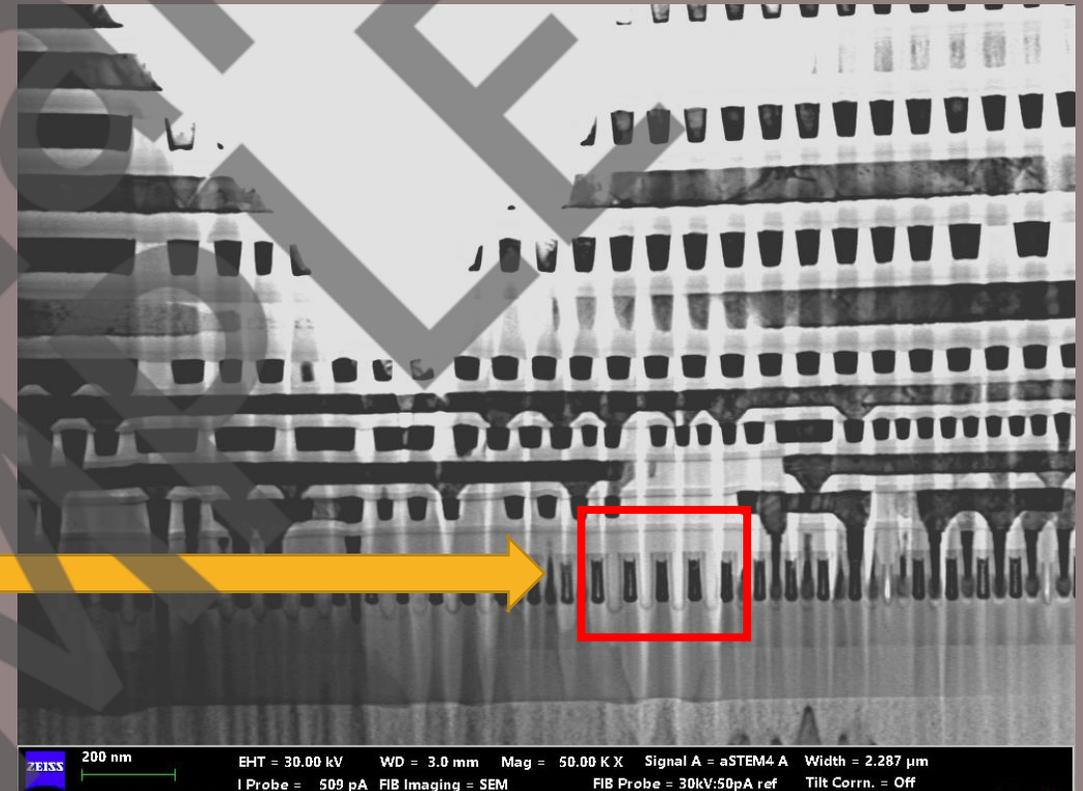


There are two libs with different gate pitches:
CGP 64 and **CGP 68**

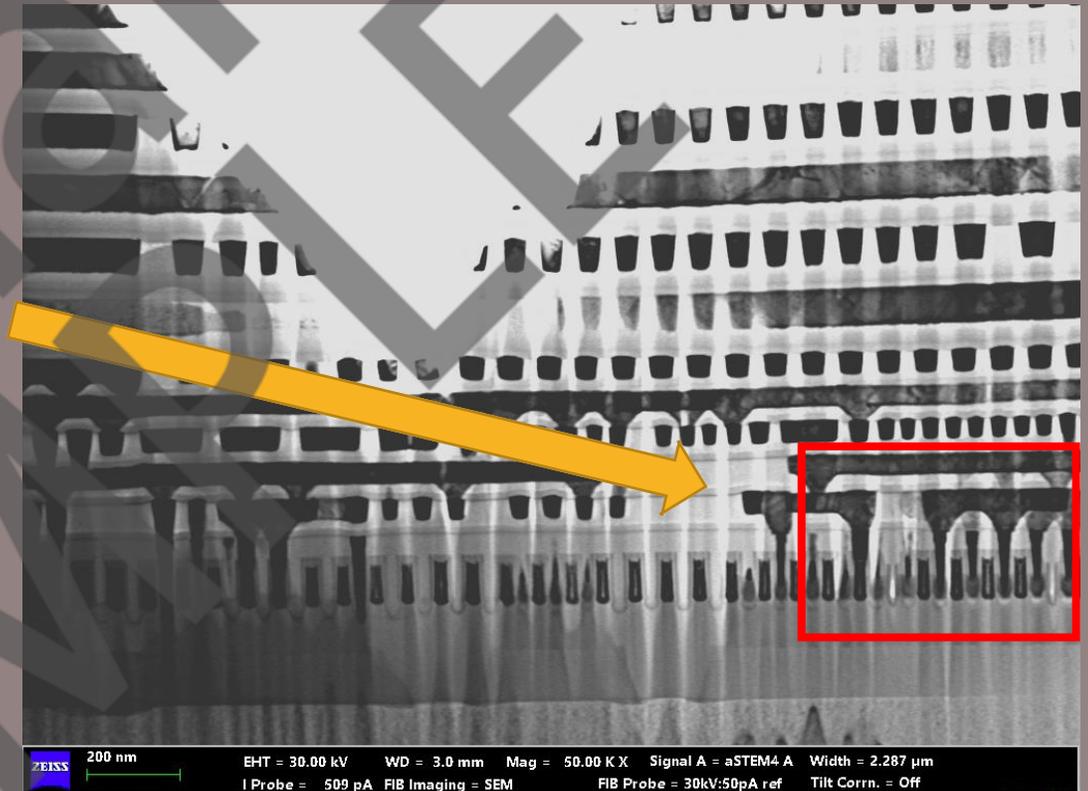
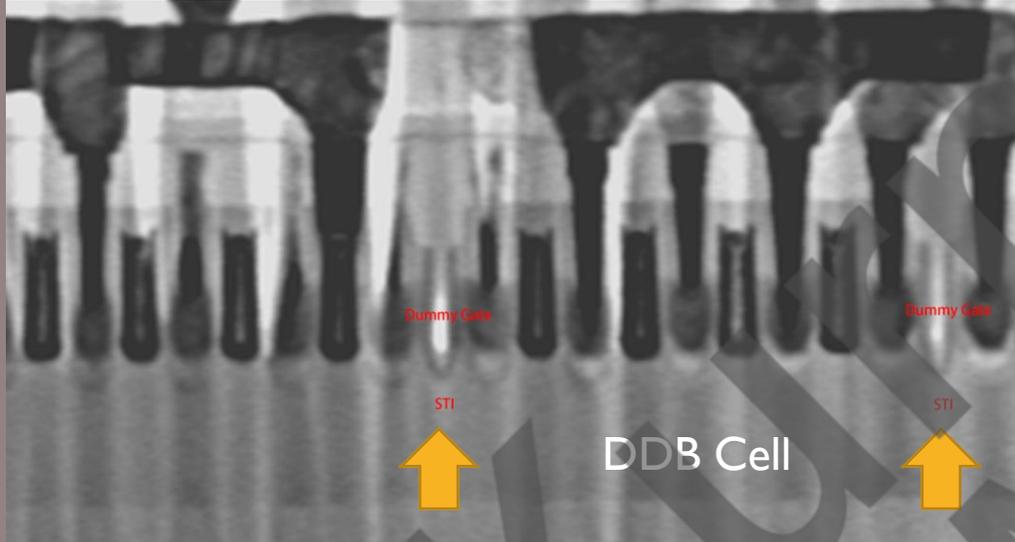
No COAG (contact Over Active Gate)



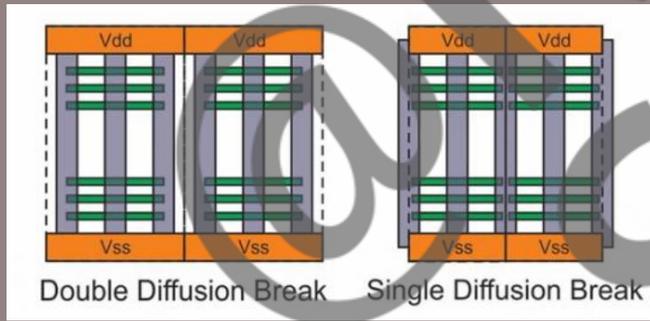
Use Self-Aligned-contact



Data From (GA107 I-17)



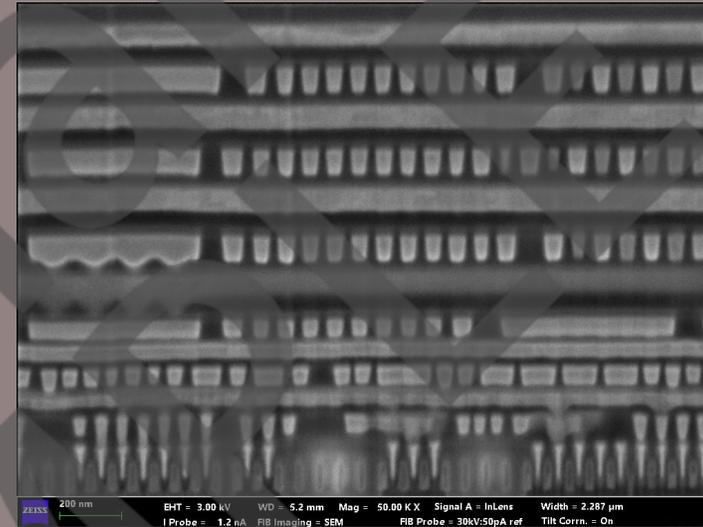
Mixed Diffusion Break



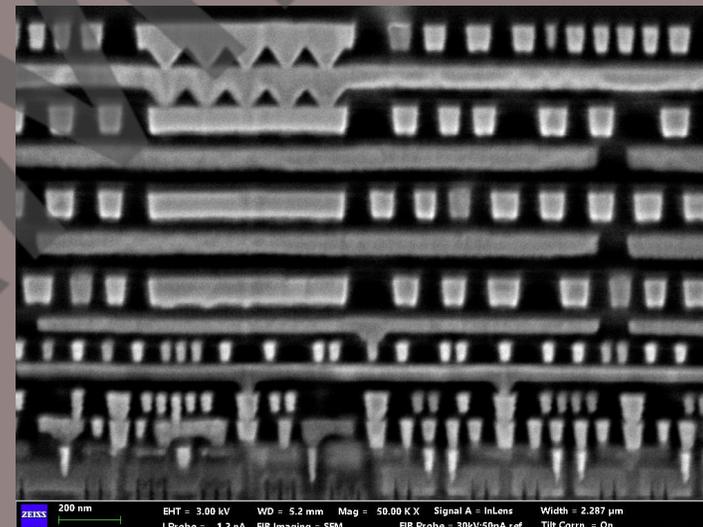
Data From (GA107 I-17)

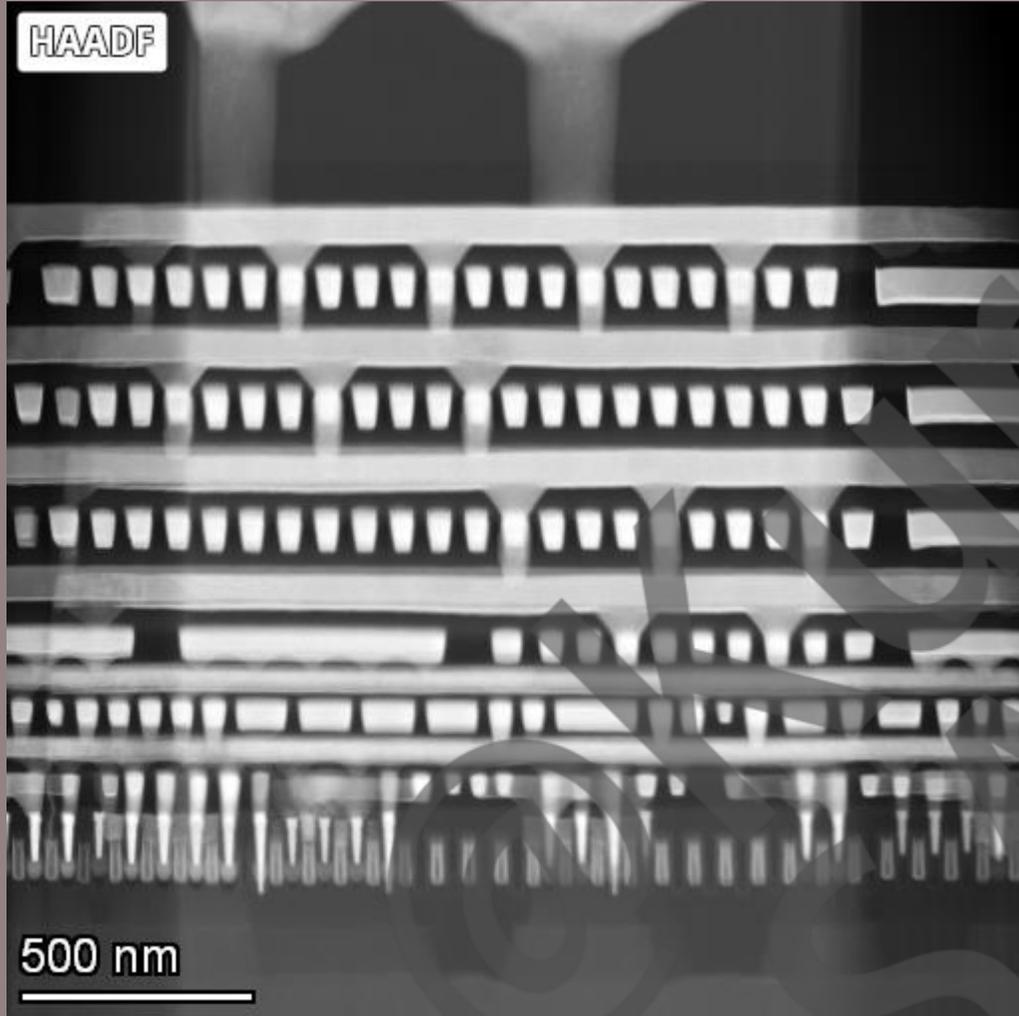
	Pitch	MMP
M1	68nm	Gate Pitch
M2	48nm	1x
M3	48nm	1x
M4	48nm	1x
M5	80nm	1.66x
M6	80nm	1.66x
M7	80nm	1.66x
M8	80nm	1.66x
M9	80nm	1.66x
M10	80nm	1.66x
M11	80nm	1.66x
M12	80nm	1.66x

Data From (GA107 1-09)

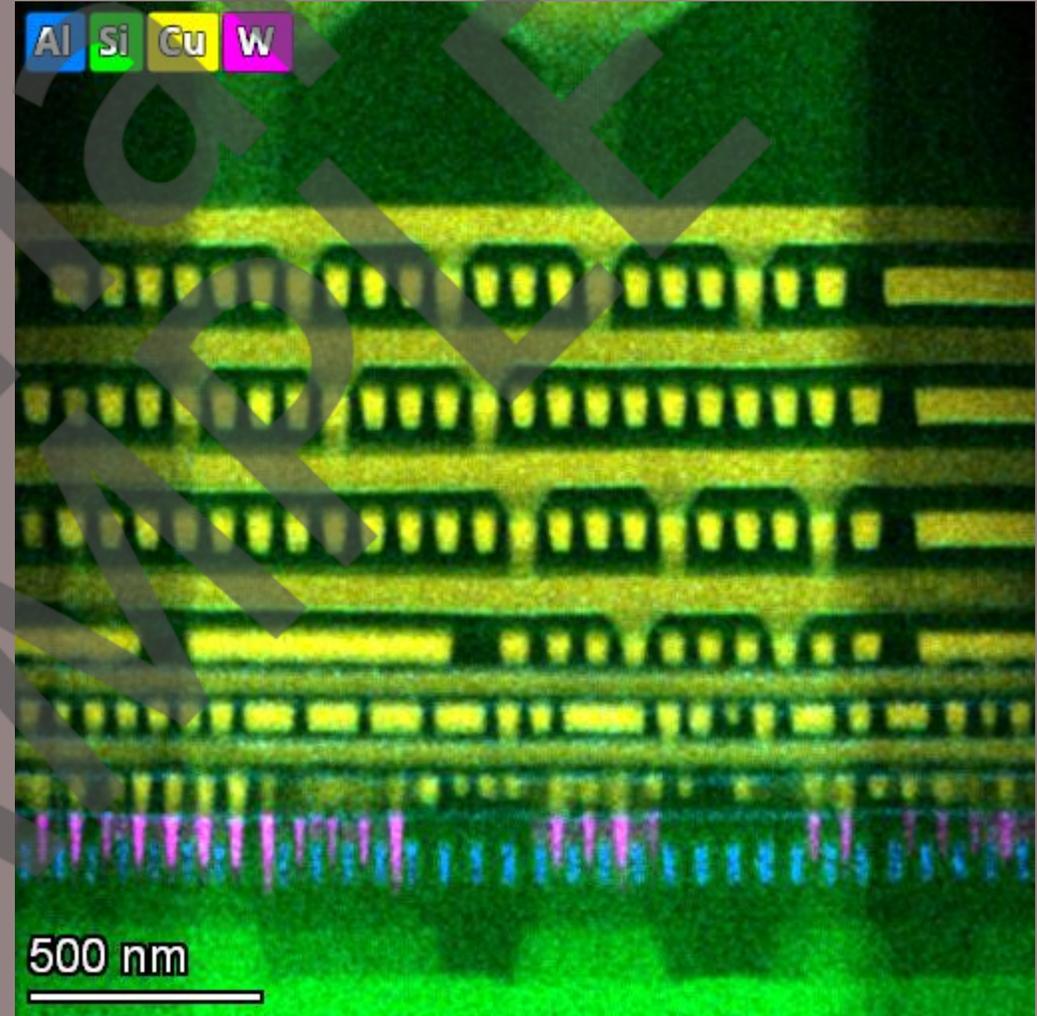


Data From (GA107 2-09)



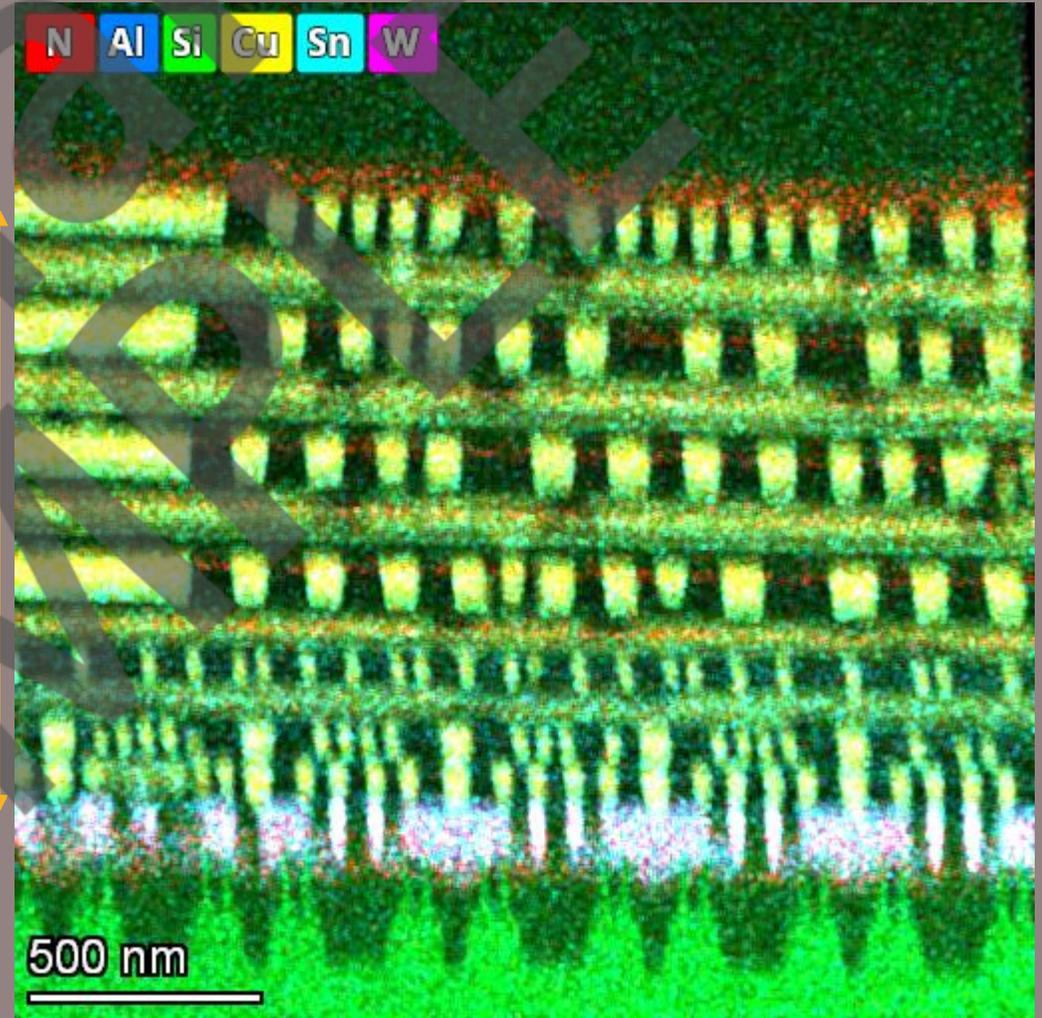
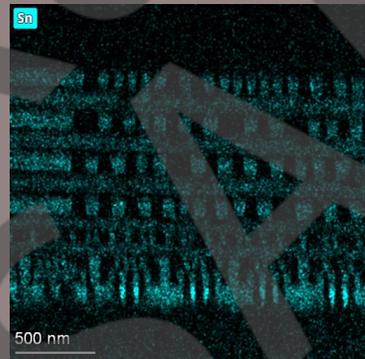
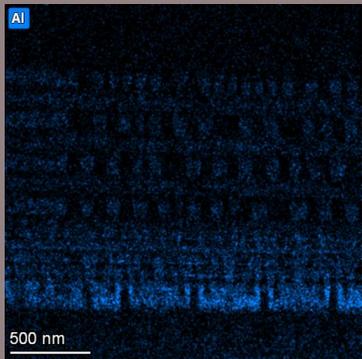
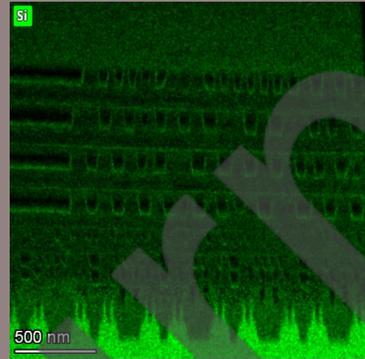
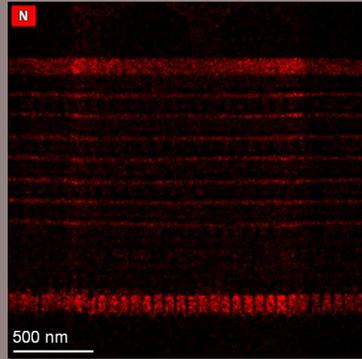
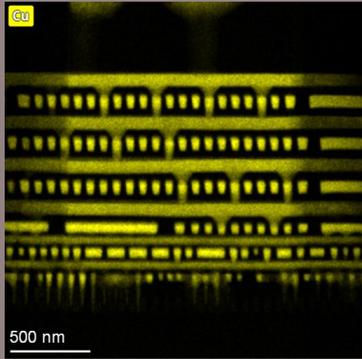


GA107-EDS(0944 SI 45000 x HAADF)



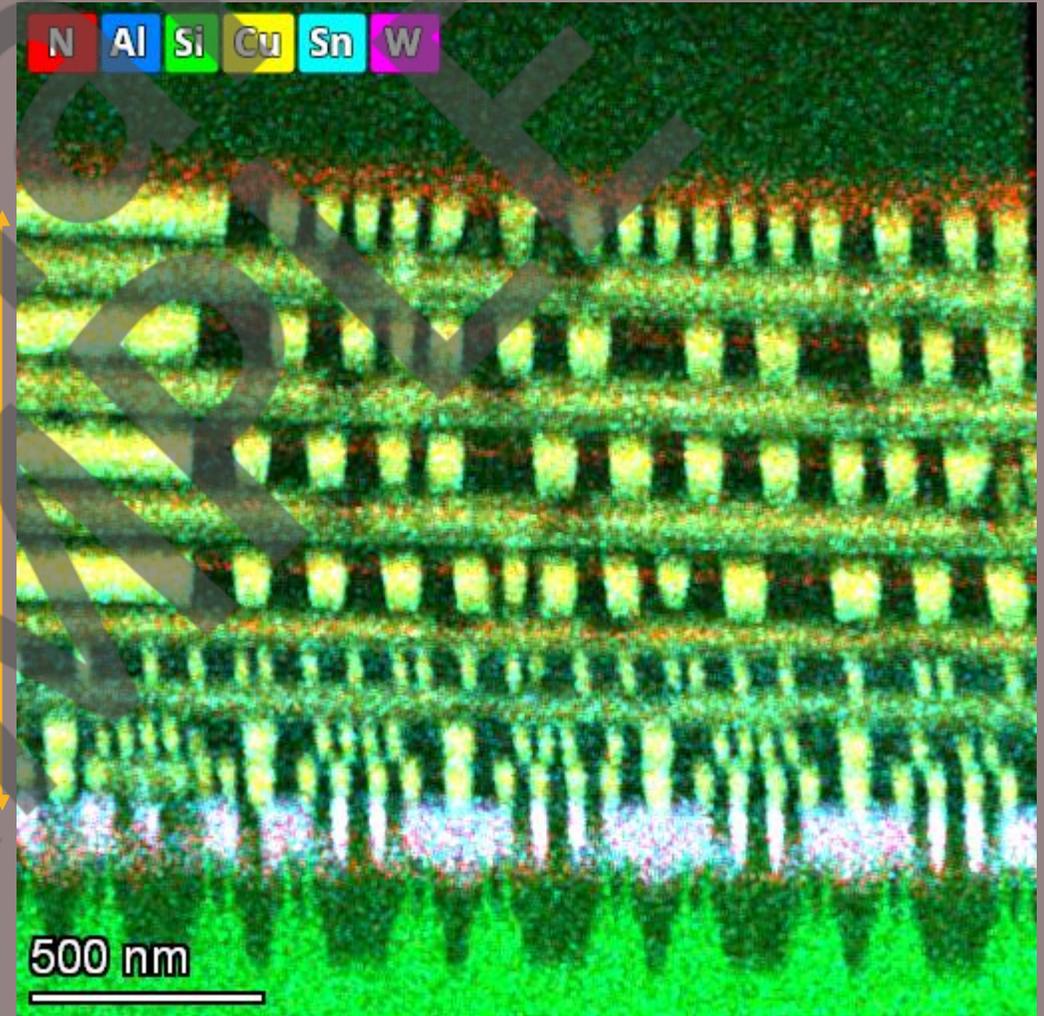
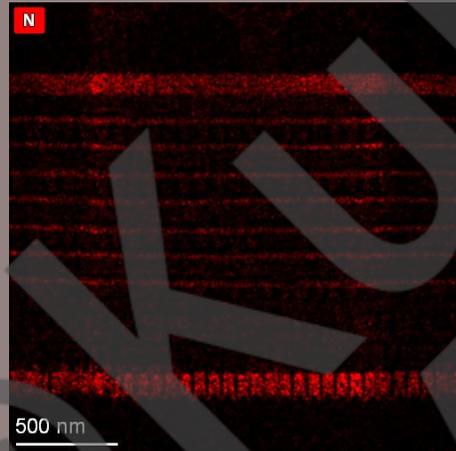
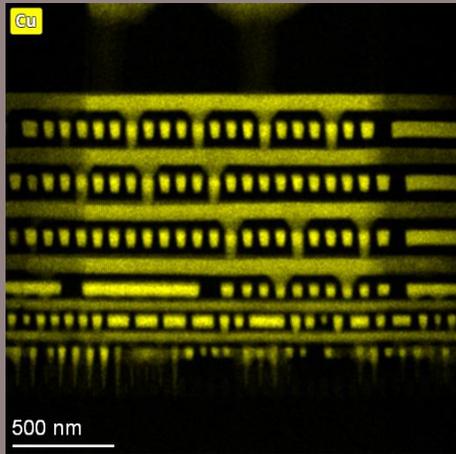
GA107-EDS(0944 SI 45000 x ColorMix-02)

Process analyze-Samsung 8nm-Gate Cut



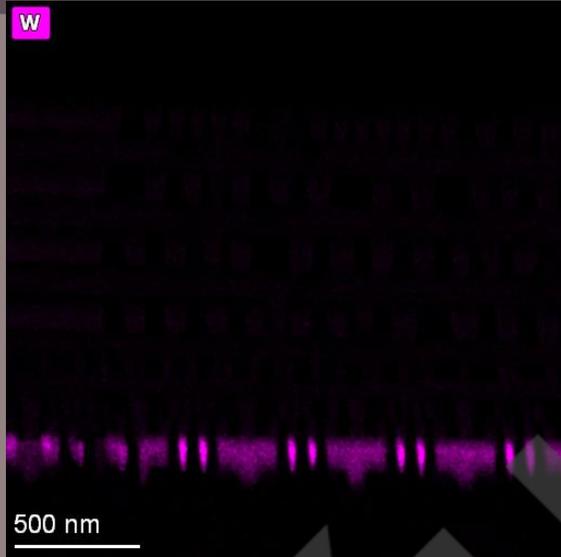
GA107-EDS(0944 SI 45000 x ColorMix-net)

MI-MI2 used the Cu

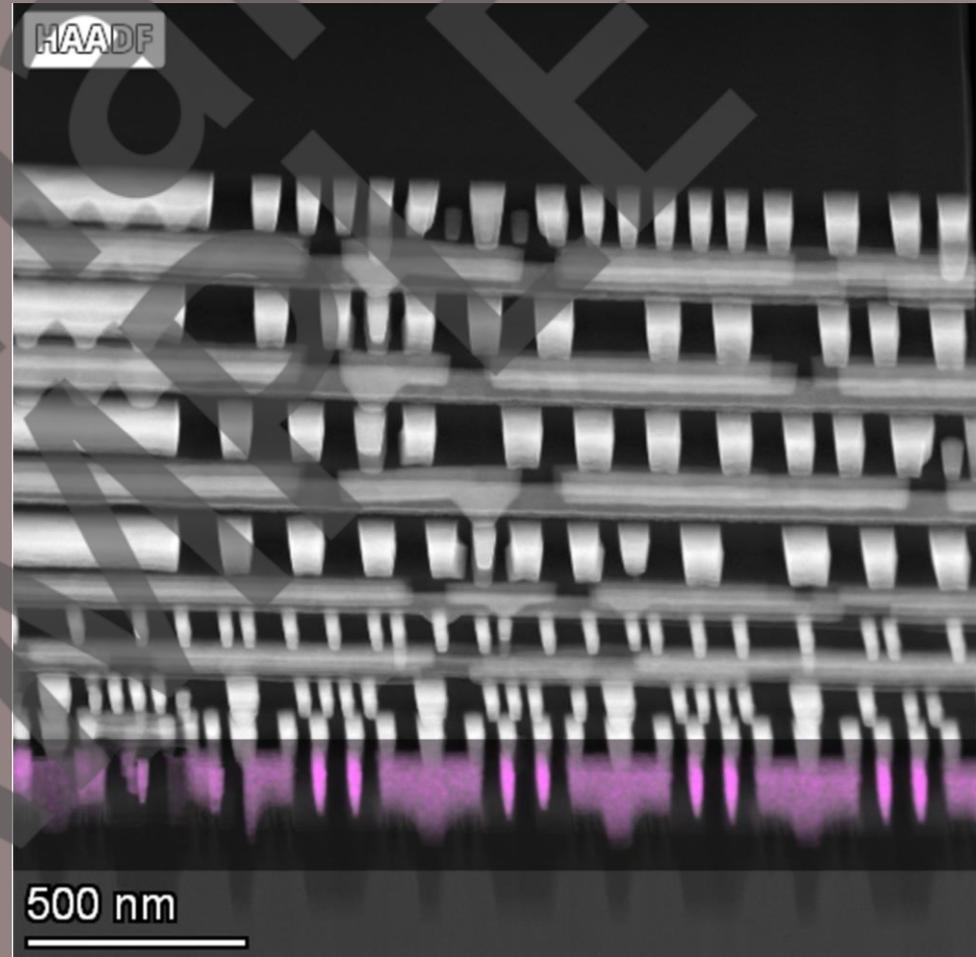
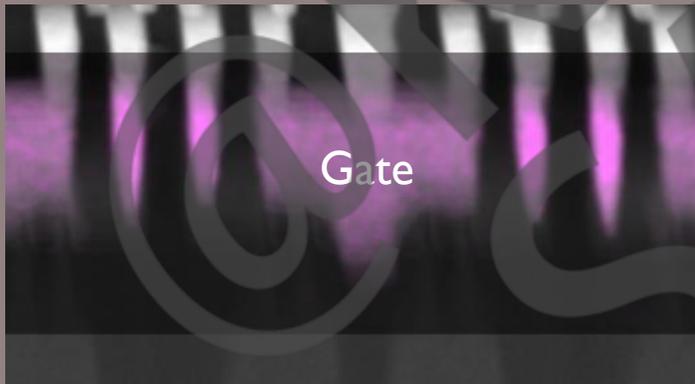


Uses the N to isolation every Layers
(SiN?)

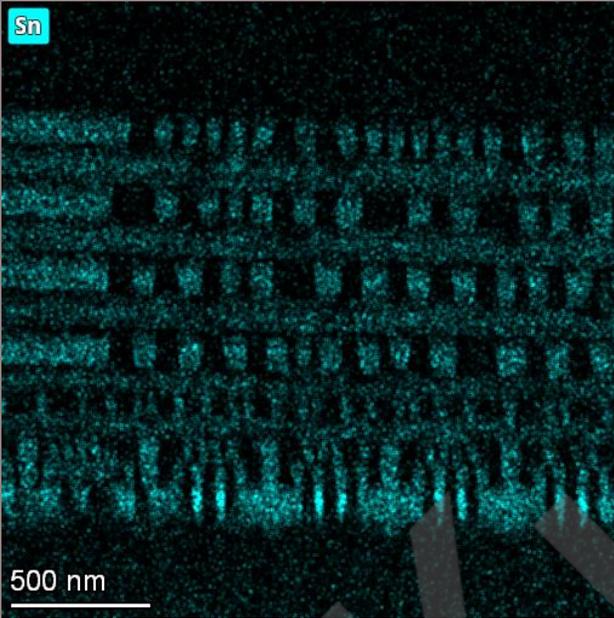
GA107-EDS(0944 SI 45000 x ColorMix-net)



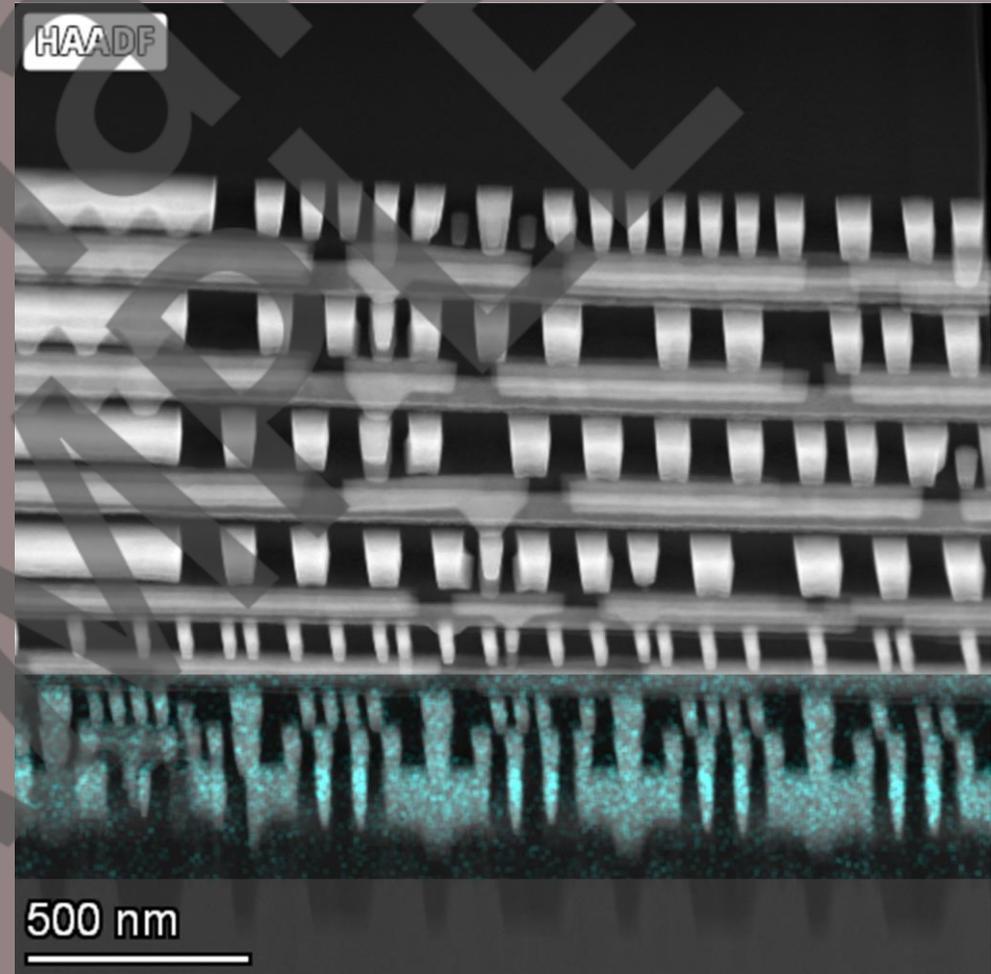
Used the **W Gate** and **contact**
It is **HKMG**(High K Metal Gate)



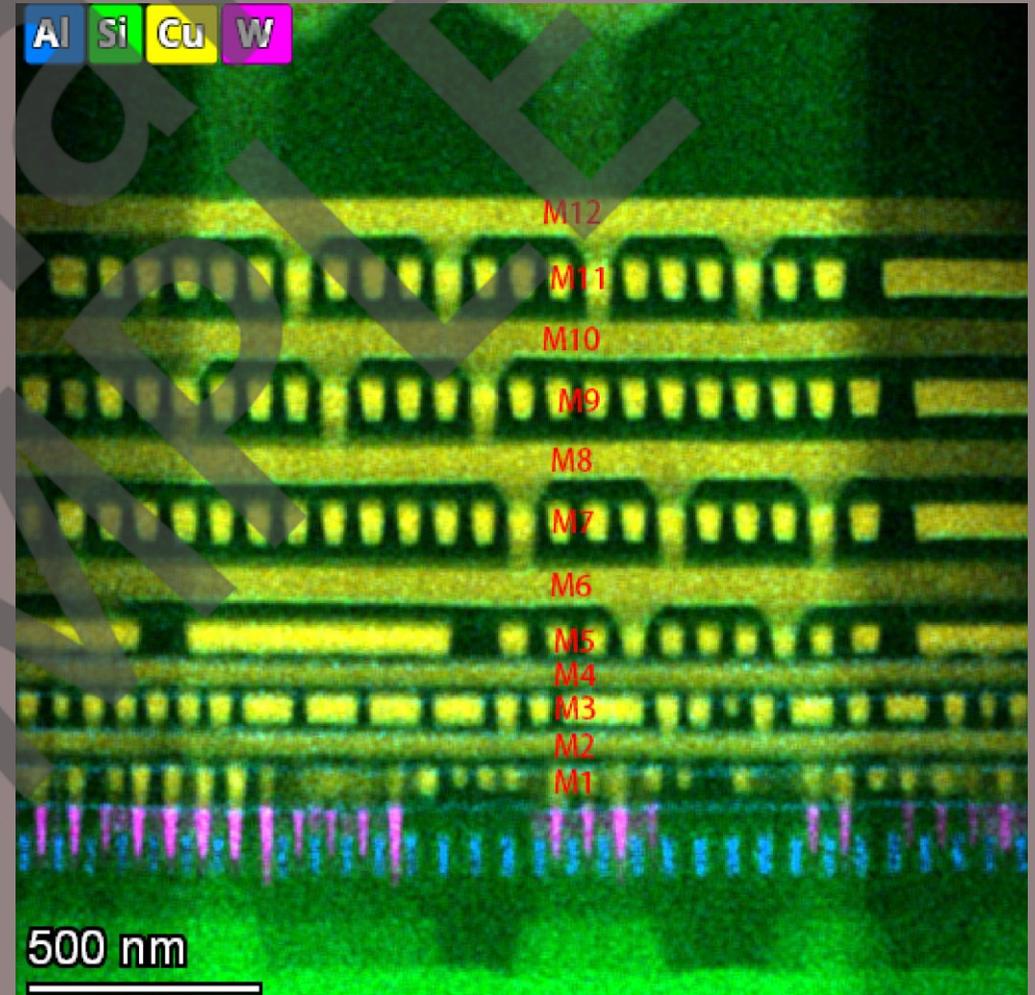
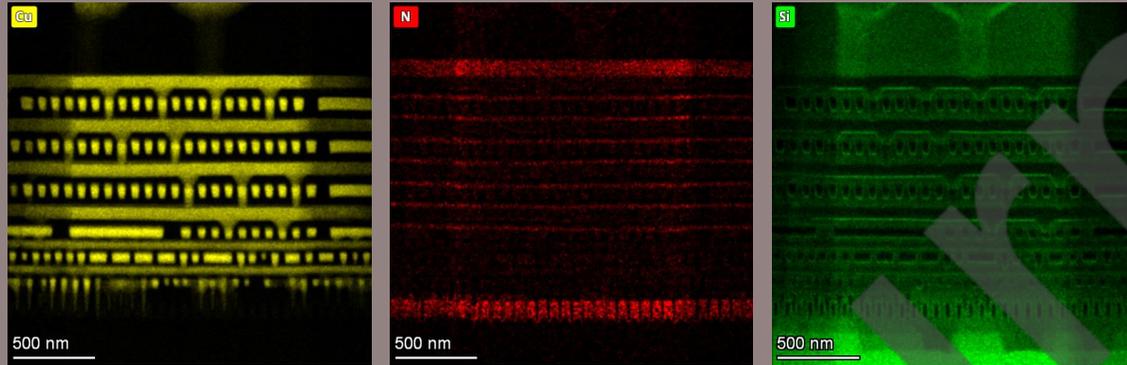
GA107-EDS(0944 SI 45000 x ColorMix-net)



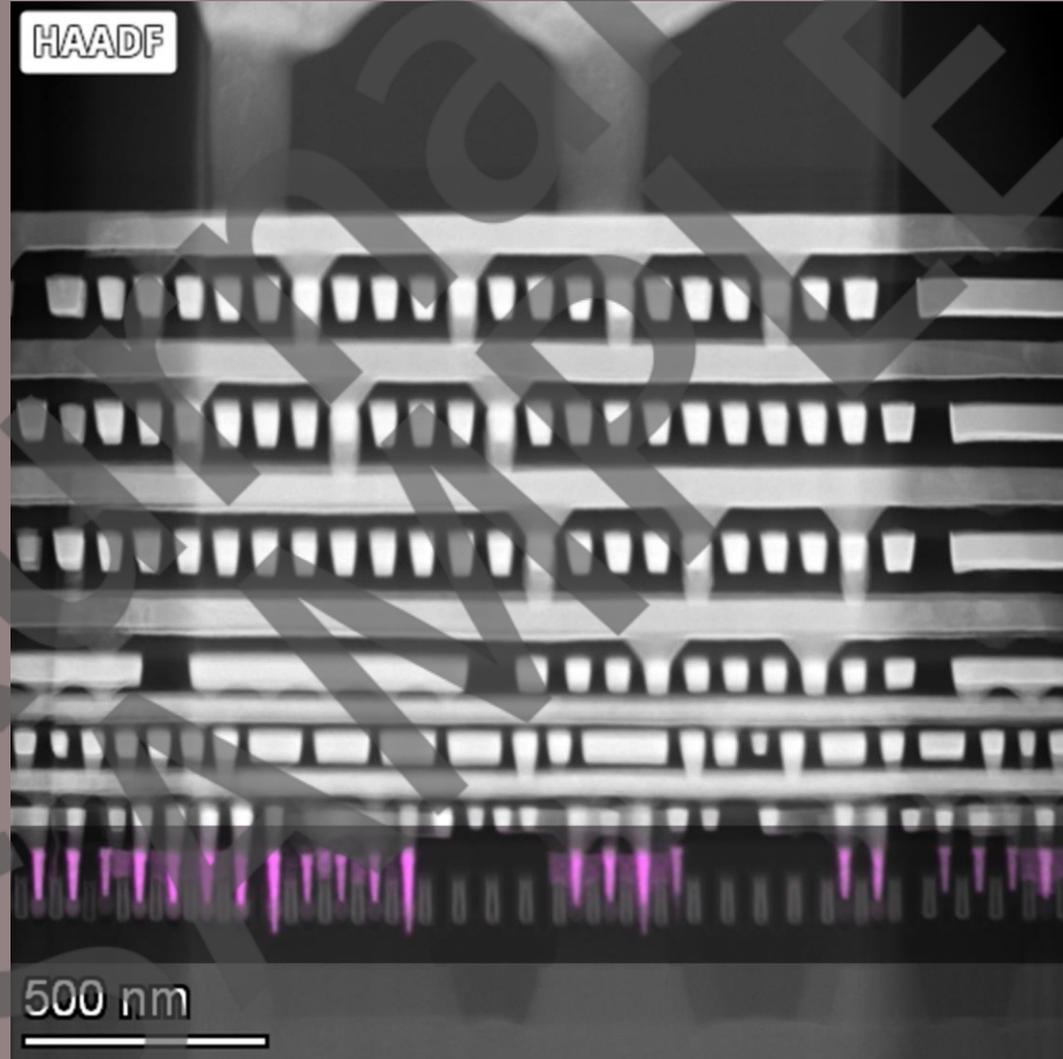
A little bit Sn in the **Contact Via**?



GA107-EDS(0944 SI 45000 x ColorMix-net)



Used the **W** to contact



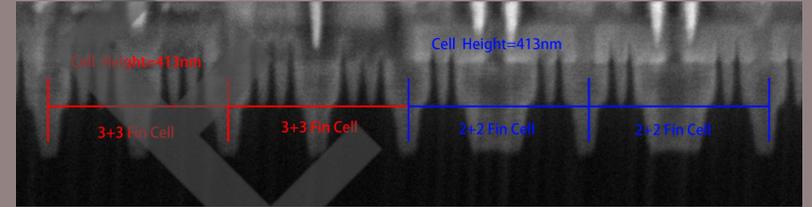
	Pitch	MMP
M1	68nm	Gate Pitch
M2	48nm	1x
M3	48nm	1x
M4	48nm	1x
M5	80nm	1.66x
M6	80nm	1.66x
M7	80nm	1.66x
M8	80nm	1.66x
M9	80nm	1.66x
M10	80nm	1.66x
M11	80nm	1.66x
M12	80nm	1.66x

What we know about Nvidia GA107 (Samsung 8N) so far

Cell Height for 3+3 is 413nm
 Cell Height for 2+2 is 413nm
 M2 Pitch= 48nm
 Cell Track=8.6Track
 Contacted Gate Pitch=64nm/68nm

Used the Mixed Diffusion Break
 Used the Self-Aligned-contact

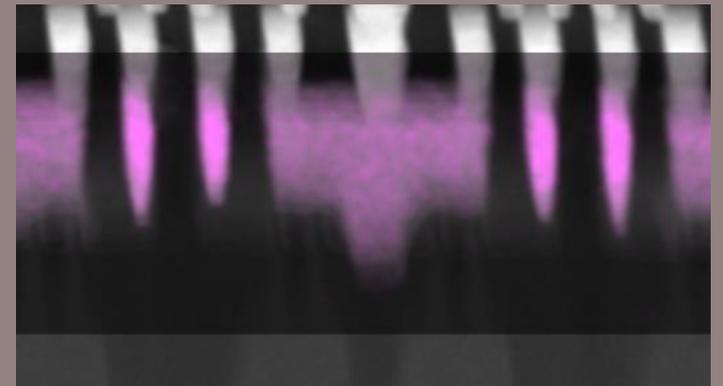
Used the W Gate and contact
 It is HKMG(High K Metal Gate)



Data From (GA107 2-10)

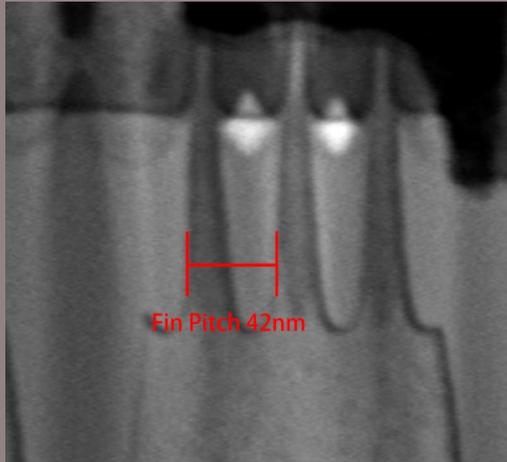


The Cell Track=Cell Height/M2 Pitch
 =413nm/48nm
 =8.603Track



T239 SoC Identification

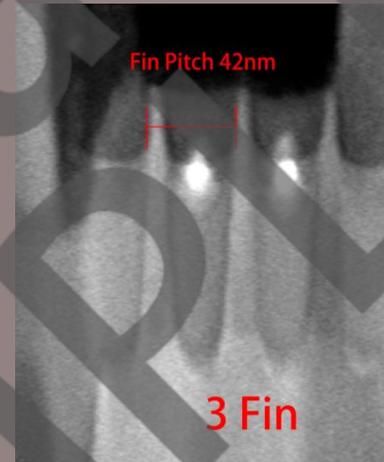
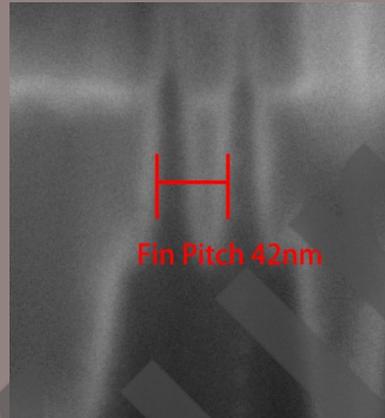
T239 process identical



Data From (T239 2-10)

The 2 libs Fin Pitch both 42nm

T239



Data From (GAI07 2-18)

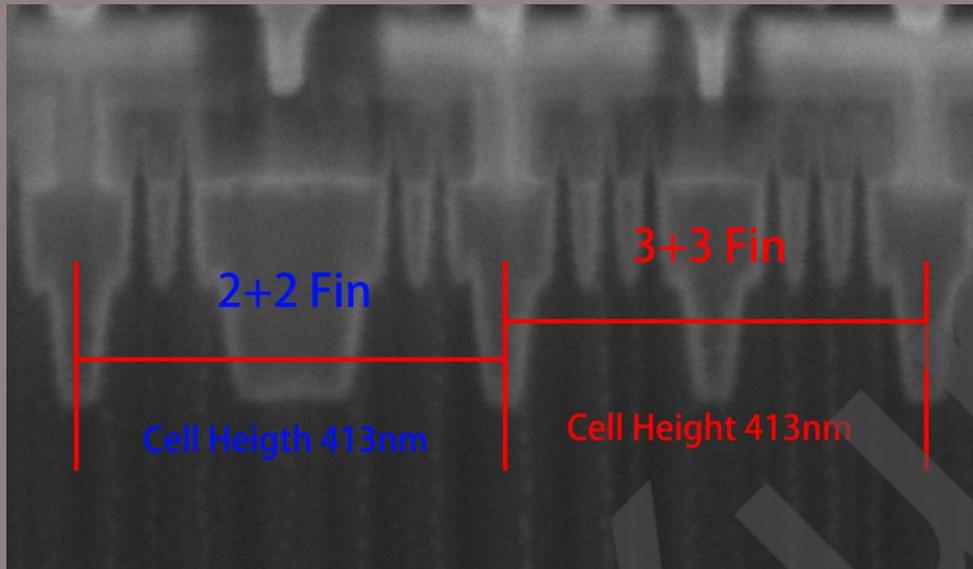
The 2lib Fin pitch both 42nm

GAI07

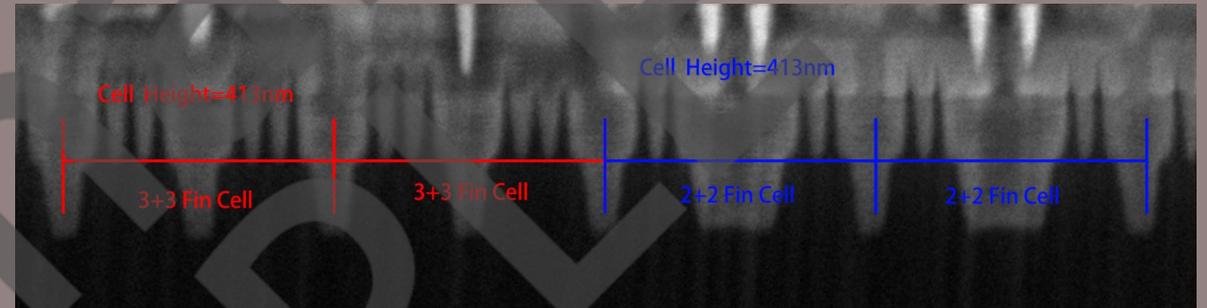


Lib	T239	GAI07
2+2 Fin Pitch	42nm	42nm
3+3 Fin Pitch	42nm	42nm

In the Fin cut, Although GAI07 and T239 are both dual-bank (2Fin/3Fin), the Fin Pitch is same as 42nm.



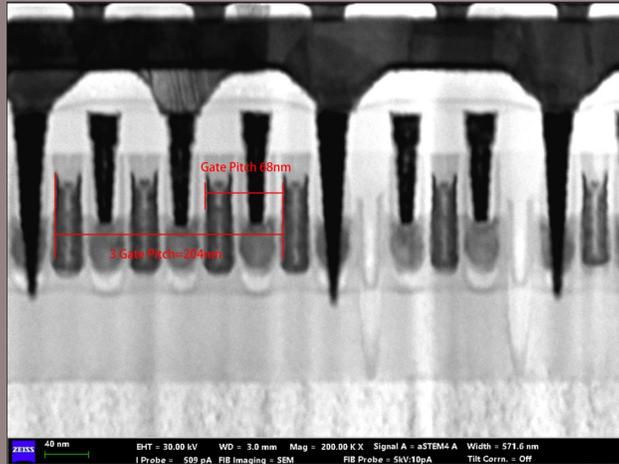
The 2 libs Cell Height both 413nm
T239



The 2 libs Cell Height both 413nm
GAI07

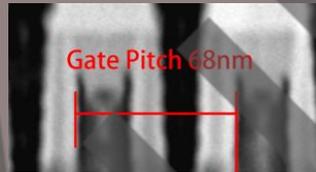
Lib	T239	GAI07
2+2 Cell Height	413nm	413nm
3+3 Cell Height	413nm	413nm

In the Fin cut,
Although GAI07 and T239 are both dual-bank (2Fin/3Fin),
the Cell Height is same as 413nm.

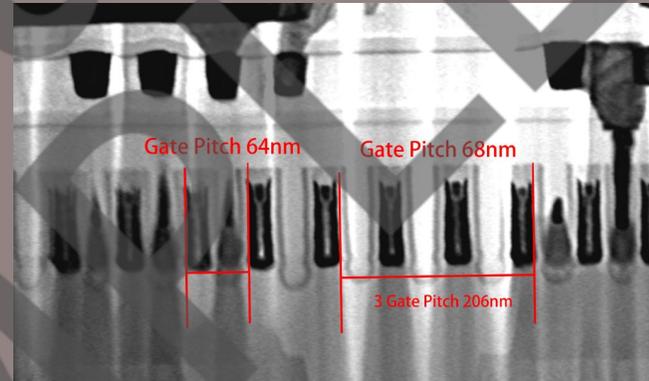


T239

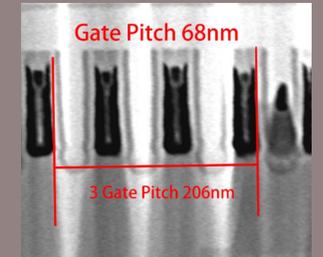
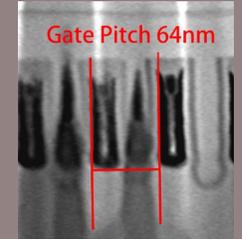
The Gate Pitch= 68nm



The Gate Pitch= 64nm/68nm



GAI07



Lib	T239	GAI07
Gate Pitch	68nm	64nm/68nm

GAI07 and T239 both have the same 68nm Gate Pitch, But GAI07 has an additional 64nm Gate Pitch

T239	Pitch	MMP
M1	68nm	Gate Pitch
M2	48nm	1x
M3	48nm	1x
M4	48nm	1x
M5	80nm	1.66x
M6	80nm	1.66x
M7	80nm	1.66x
M8	80nm	1.66x
M9	80nm	1.66x
M10	80nm	1.66x
M11	80nm	1.66x
M12	80nm	1.66x

T239 Metal Pitch

The **Min Metal Pitch** are all equal to **48nm**
 And the **M2 Pitch** are all equal to **48nm**

GAI07	Pitch	MMP
M1	68nm	Gate Pitch
M2	48nm	1x
M3	48nm	1x
M4	48nm	1x
M5	80nm	1.66x
M6	80nm	1.66x
M7	80nm	1.66x
M8	80nm	1.66x
M9	80nm	1.66x
M10	80nm	1.66x
M11	80nm	1.66x
M12	80nm	1.66x

GAI07 Metal Pitch

T239	Data
Fin Pitch	42nm
Fin number	2+2/3+3
Gate Pitch	68nm
Gate Element	HKMG(W)
2+2 Cell Height	413nm
3+3 Cell Height	413nm
Diffusion Break	MDB
Contact	SAC
Contact Element	W

T239 data

The **Min Metal Pitch** are all equal to **48nm**
 And the **M2 Pitch** are all equal to **48nm**

GAI07	Data
Fin Pitch	42nm
Fin number	2+2/3+3
Gate Pitch	64nm/68nm
Gate Element	HKMG(W)
2+2 Cell Height	413nm
3+3 Cell Height	413nm
Diffusion Break	MDB
Contact	SAC
Contact Element	W

GAI07 Data

Samsung 8N

Samsung	10LPE/LPP	8LPP/LPU	T239	GAI07
Fin/GAA	3 Fin	3+2 Fin	3+2 Fin	3+2 Fin
Track	8.75T	8.59T	8.6T	8.6T
Gate Pitch	68nm	64nm/68nm	68nm	64nm/68nm
Fin Pitch	42nm	42nm	42nm	42nm
Min MP	48nm	44nm	48nm	48nm
M2P	48nm	44nm	48nm	48nm
Cell H (Min)	420nm	378nm	413nm	413nm
SDB/DDB	SDB	SDB	SDB	SDB
CB-RX	SAC	SAC	SAC	SAC
Logic Density (MTr)	51.6Mtr/mm2	60.92/Mtr/mm2	52.47Mtr/mm2	55.75Mtr/mm2

T239 uses the same Samsung 8N process as GAI07.

Samsung 8N is a derivative of Samsung 10LPP

Which includes some of the process features of 8LPP (such as 2+2Fin),

But it is not completely equal to Samsung 8LPP

T239 process identification-summary



Diesize=**207.35 mm²**

In searing area=**202.4mm²**

IO PHY(LPDDR) area **7.2x2=14.4mm²**

IO PHY(PCIe)area=**5.557mm²**

IO PHY USB ...area=**1.085mm²**

Only Logic area=**181.358mm²**

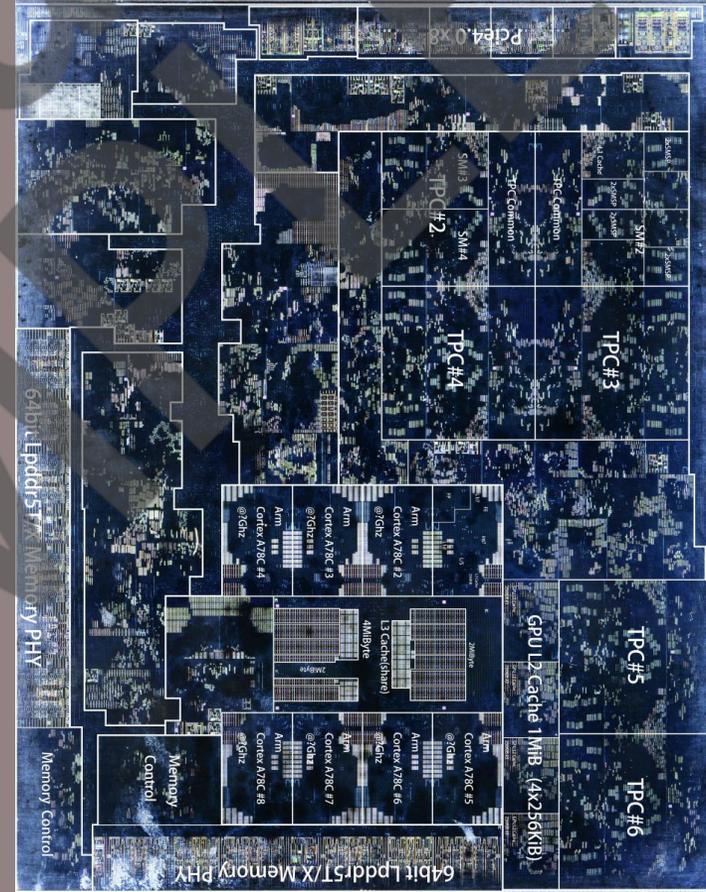
Maximum have: **10.88billion** (108.79亿)Transistors

Minimum have: **9.516Billion** (95.158亿)Transistors

Samsung	T239
Fin/GAA	3+2 Fin
Track	8.6T
Gate Pitch	68nm
Fin Pitch	42nm
Min MP	48nm
M2P	48nm
Cell H (Min)	413nm
SDB/DDB	SDB
CB-RX	SAC
Logic Density (MTr)	52.47Mtr/mm ²

Switch2 soc analyze

Dieshot analyze

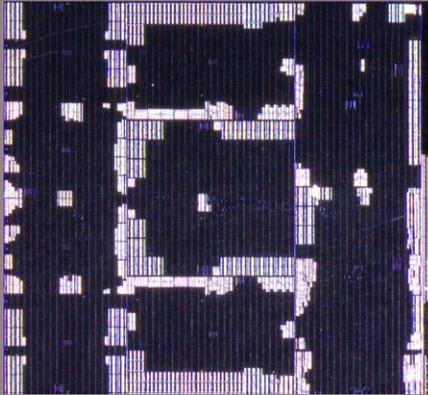




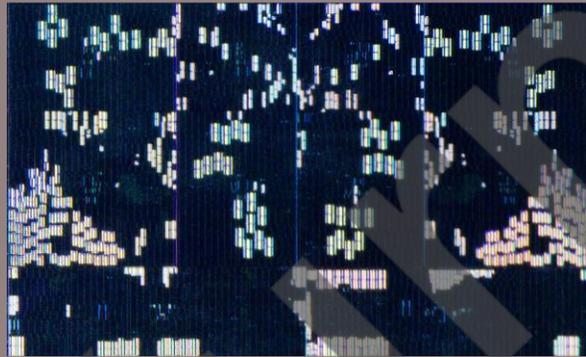


The T239 have **6 TPC** GPU
1 TPC have **2 SM**
1 SM have **128 Cuda** cores

So **T239 GPU** have **1536 Cuda** cores



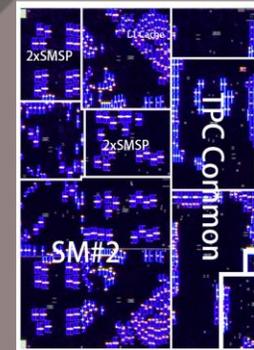
GA102



Orin



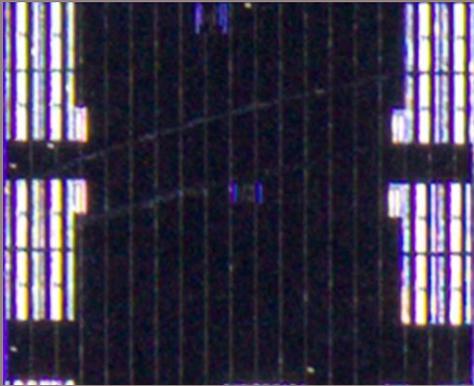
T239



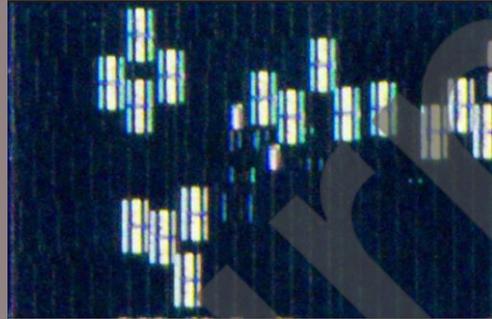
AD102

For **TPC**, although **GA102/Orin/T239** all belong to the Nvidia Ampere family, it is obvious that the layout is inconsistent.

Orin and T239 GPUs are more similar to **Nvidia's Ada** layout



GA102 SMSP



Orin SMSP



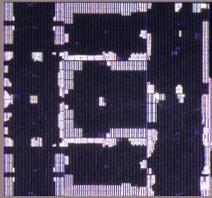
T239 SMSP



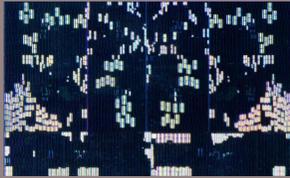
AD102 SMSP

Especially the layout inside **SM**, are more are more similar to **Nvidia's Ada** layout

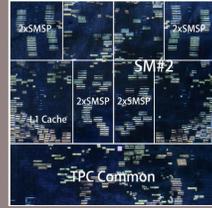
T239 Die shot analyze-GPU



GA102



Orin

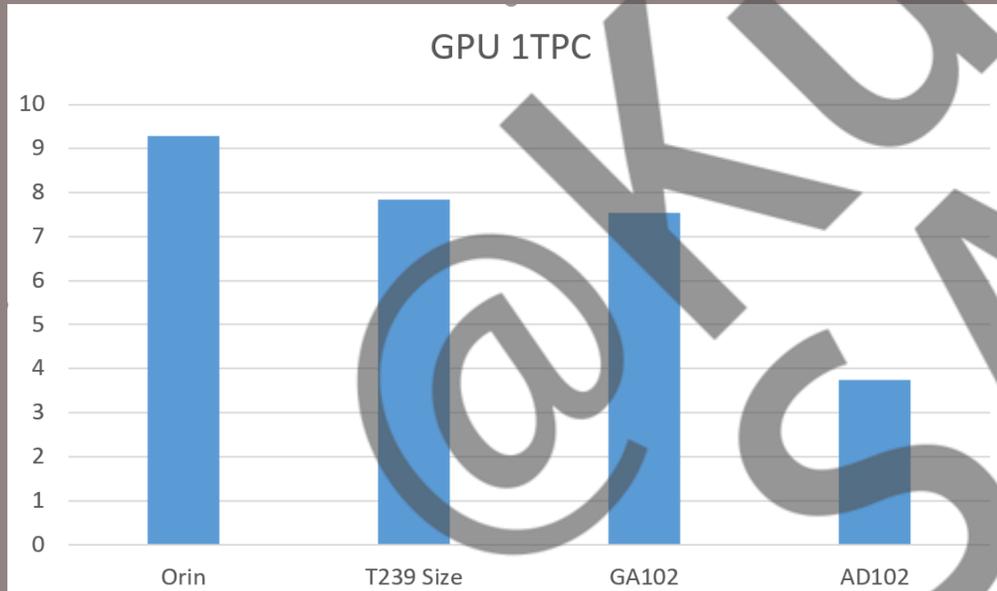


T239



AD102

The three figures on the left are the same architecture (Nvidia Ampere) implemented in the same process (Samsung 8N). The 4th figure shows Nvidia Ada implemented in TSMC N4.



	Orin	T239 Size	GA102	AD102
GPU 1TPC	9.29	7.83	7.542	3.7365
GPU 1SM	3.47	2.71	2.57	1.2

But according to TPC internal mapping data, it is clear that Orin has the largest GPU TPC/SM area, followed from T239, and then GA102.

The area of the AD102 using advanced technology is almost half of that of the GA102.

T239 Die shot analyze-GPU



T239 Size	
GPU All	88.349
GPU 1TPC	7.83
just TPC	46.98
GPU 1SM	2.71
GPU 2XSM	0.592

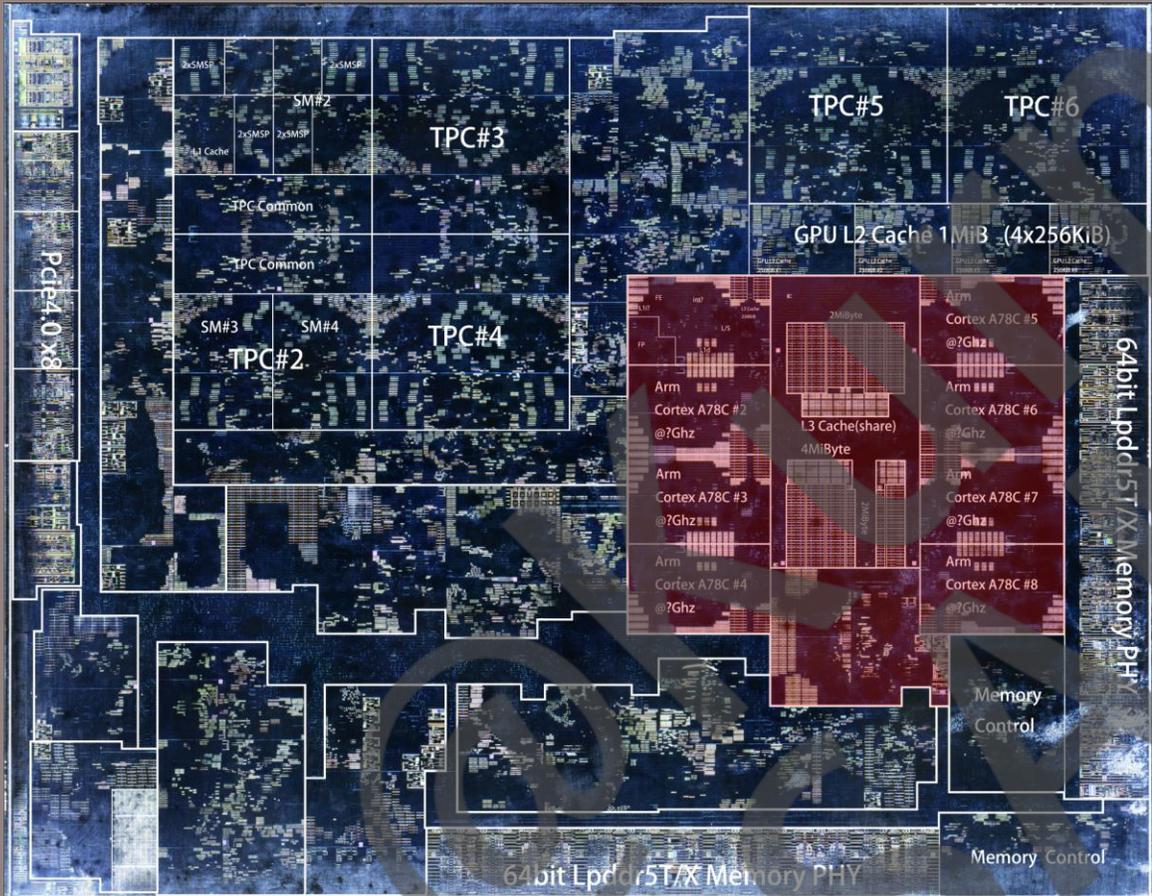
Some size data in this graph



This area is CPU Cluster



Have 8 Arm A78C Core



Nvidia Orin

T239



A78AE

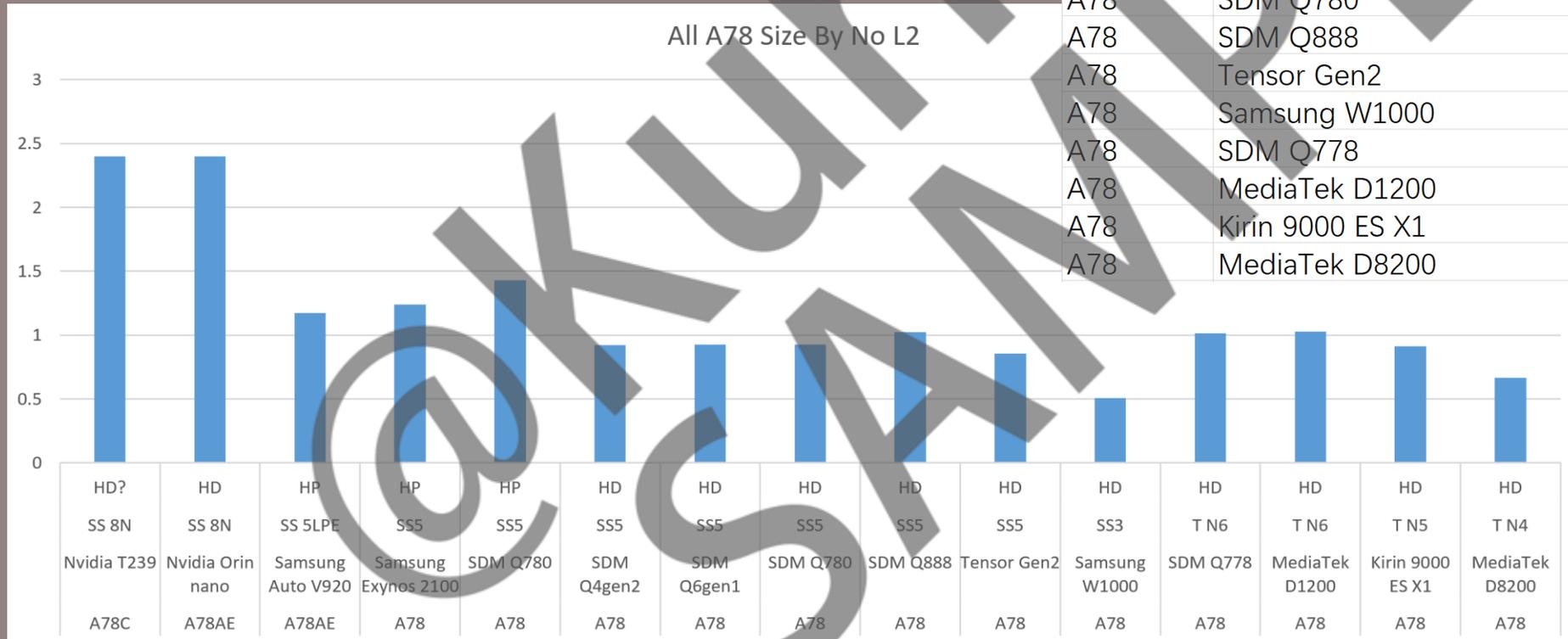
A78C

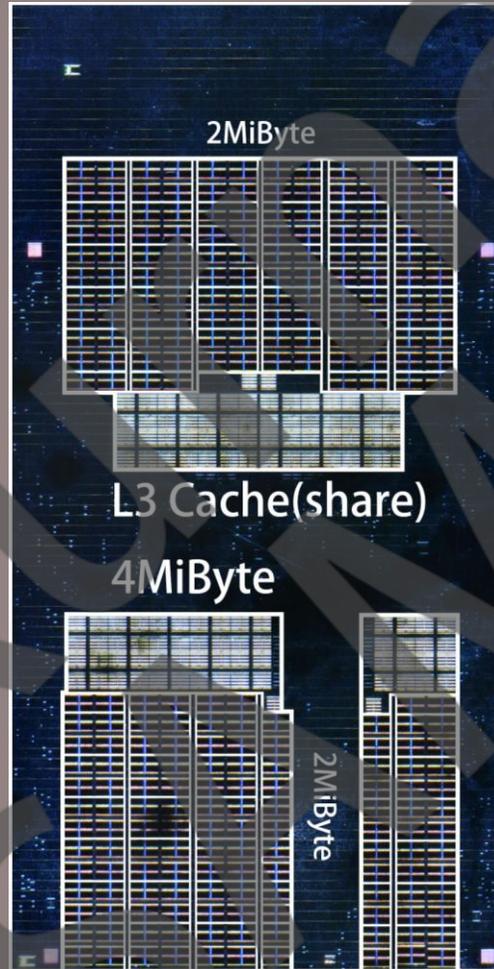
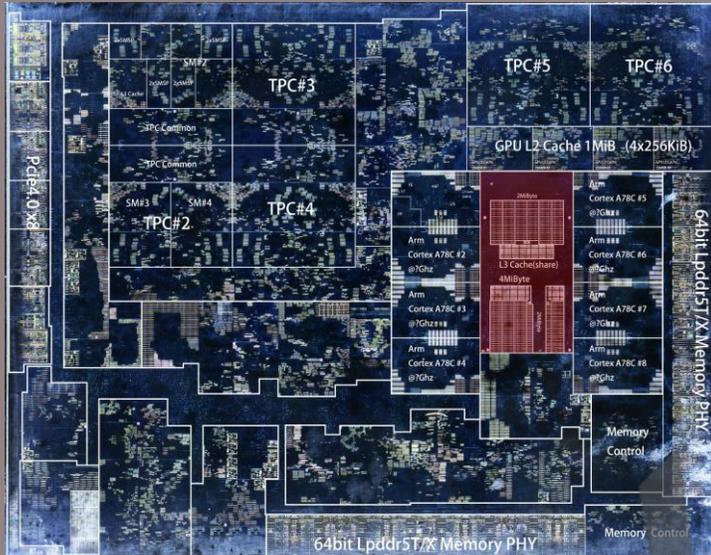
Orin	T239 Size
CPU+L2	2.6 CPU+L2
CPU Only	2.4 CPU Only

The **Orin A78AE** Core size is the **same** as **T239 A78C** Core size

Some A78 sizes in different processes

IP	Name	Process	Lib	size (No L2)
A78C	Nvidia T239	SS 8N	HD?	2.4
A78AE	Nvidia Orin nano	SS 8N	HD	2.4
A78AE	Samsung Auto V920	SS 5LPE	HP	1.174
A78	Samsung Exynos 2100	SS5	HP	1.238
A78	SDM Q780	SS5	HP	1.427
A78	SDM Q4gen2	SS5	HD	0.921
A78	SDM Q6gen1	SS5	HD	0.926
A78	SDM Q780	SS5	HD	0.925
A78	SDM Q888	SS5	HD	1.021
A78	Tensor Gen2	SS5	HD	0.853
A78	Samsung W1000	SS3	HD	0.507
A78	SDM Q778	T N6	HD	1.015
A78	MediaTek D1200	T N6	HD	1.028
A78	Kirin 9000 ES X1	T N5	HD	0.913
A78	MediaTek D8200	T N4	HD	0.667





This area is CPU L3 Cache

In total there are $2 \times 2 \text{MiB} = 4 \text{MiB}$ of L3 cache shared by 8 cores.

Based on the shared L3 design, we can confirm that those CPUs are A78C cores.

- A78: 1-8Core/cluster
- A78AE: 1-4Core/cluser
- A78C: 8Core/Cluster

Chip price and IF line

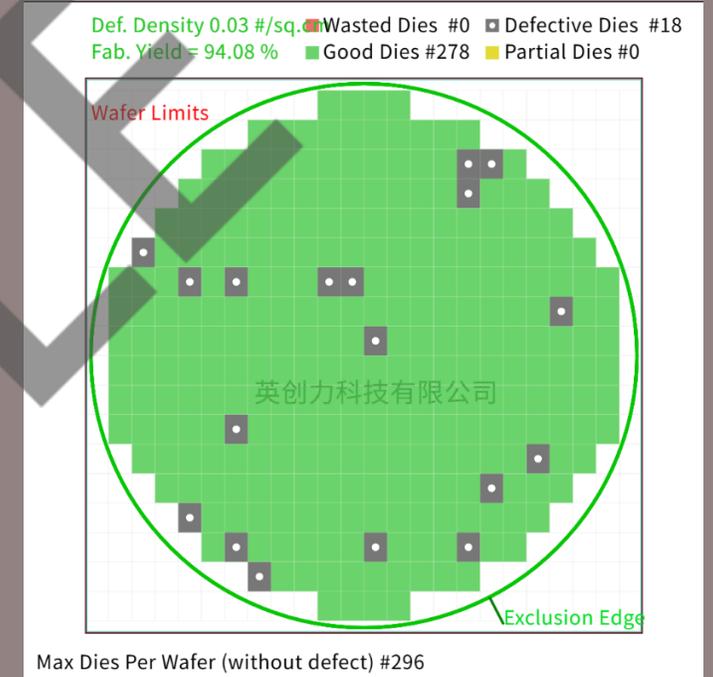
T239 Price with IF Line



Diesize: **207.35mm²**
(12.76mm x 16.25mm)

DPW Nb: **296**

D0(if)=**0.03**
Yield=**94.08%**



We know the Chip Process is **Samsung 8N**
For that, We can know the **Chip Price**

Table 9: Calculation of foundry sale price per chip in 2020 by node

Line	Node (nm)	90	65	40	28	20	16/12	10	7	5
1	Mass production year and quarter ²²⁰	2004 Q4	2006 Q4	2009 Q1	2011 Q4	2014 Q3	2015 Q3	2017 Q2	2018 Q3	2020 Q1
2	Capital investment per wafer processed per year	\$4,649	\$5,456	\$6,404	\$8,144	\$10,356	\$11,220	\$13,169	\$14,267	\$16,746
3	Net capital depreciation at start of 2020 (25.29% / year)	65%	65%	65%	65%	65%	65%	55.1%	35.4%	0.0%
4	Undepreciated capital per wafer processed per year (remaining value at start of 2020)	\$1,627	\$1,910	\$2,241	\$2,850	\$3,625	\$3,927	\$5,907	\$9,213	\$16,746
5	Capital consumed per wafer processed in 2020	\$411	\$483	\$567	\$721	\$917	\$993	\$1,494	\$2,330	\$4,235
6	Other costs and markup per wafer	\$1,293	\$1,454	\$1,707	\$2,171	\$2,760	\$2,990	\$4,498	\$7,016	\$12,753
7	Foundry sale price per wafer	\$1,650	\$1,937	\$2,274	\$2,891	\$3,677	\$3,984	\$5,992	\$9,346	\$16,988
8	Foundry sale price per chip	\$2,433	\$1,428	\$713	\$453	\$399	\$331	\$274	\$283	\$238

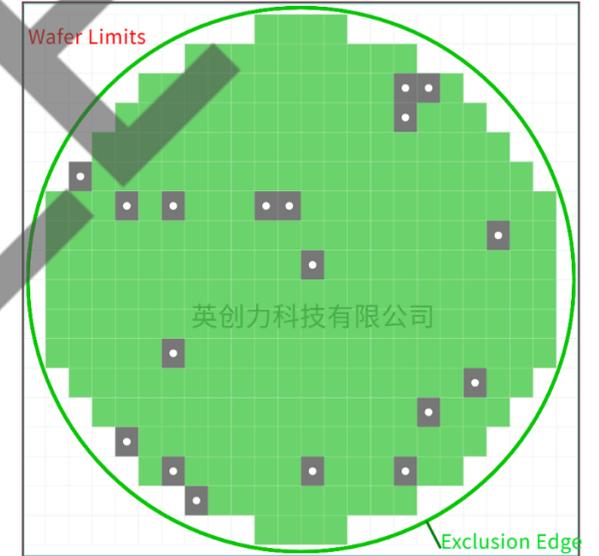
Yield = 94.8%

D0 = 0.03

Wafer Price = 5992 USD

Die price = 21.517 USD

Def. Density 0.03 #/sq. ■ Wasted Dies #0 ■ Defective Dies #18
 Fab. Yield = 94.08 % ■ Good Dies #278 ■ Partial Dies #0



Max Dies Per Wafer (without defect) #296

